

Molecular and carbon-based electronic systems

Lecture 7: Graphene

structure, fabrication, characterization

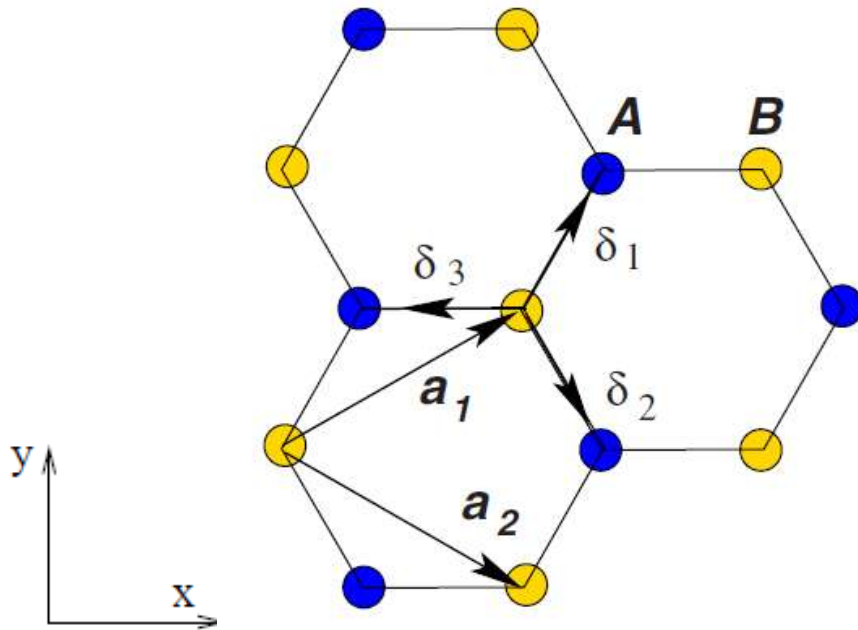
Examples: nanogaps, QHE

- graphene structure
- fabrication and CVD growth
- characterization: Raman spectroscopy

Examples

- graphene electroburning for molecular junctions
- Quantum Hall Effect

graphene structure: honeycomb lattice



vectors connecting a site on the **A sublattice** with a nearest neighbor (nn) on the **B sublattice**
C-C bond: $a \approx 0.142 \text{ nm}$

$$\delta_1 = \frac{a}{2}(1, \sqrt{3}) \quad \delta_2 = \frac{a}{2}(1, -\sqrt{3})$$

$$\delta_3 = -a(1, 0)$$

six second nearest neighbors

$$\delta'_1 = \pm a_1, \quad \delta'_2 = \pm a_2, \quad \delta'_3 = \pm(a_2 - a_1)$$

basis vectors of the triangular Bravais lattice (2 atoms basis)

$$a_1 = \frac{a}{2}(3, \sqrt{3}), \quad a_2 = \frac{a}{2}(3, -\sqrt{3})$$

density of C atoms

$$A_{uc} = \sqrt{3} \cdot 3 \cdot a / 2 = 0.051 \text{ nm}^2$$

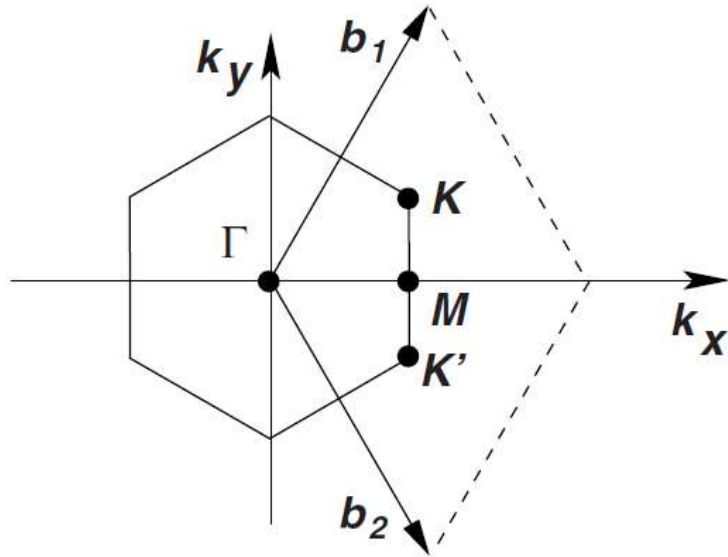
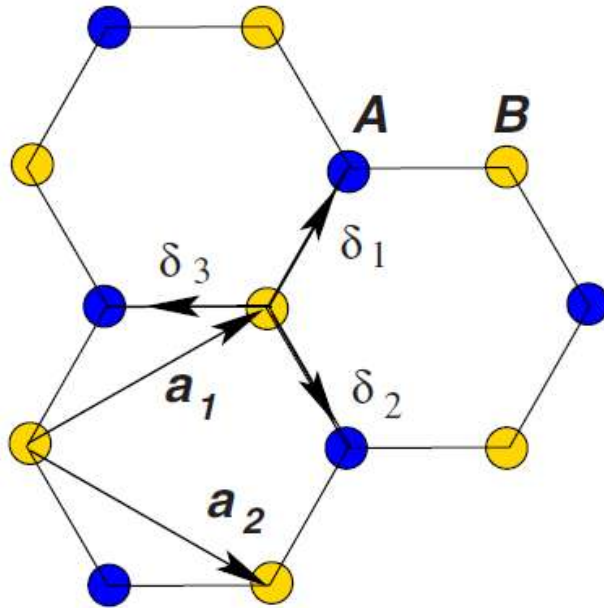
$$n_C = 2 / A_{uc} = 39 \text{ nm}^{-2} = 3.9 \times 10^{15} \text{ cm}^{-2}$$

density of π electrons

1 π e / C atom not involved in σ bond

$$n_\pi = n_C = 3.9 \times 10^{15} \text{ cm}^{-2}$$

graphene structure: reciprocal lattice



Honeycomb lattice and its corresponding Brillouin zone

reciprocal lattice basis vectors

$$\mathbf{b}_1 = \frac{2\pi}{3a}(1, \sqrt{3}) \quad \mathbf{b}_2 = \frac{2\pi}{3a}(1, -\sqrt{3})$$

*corners (6) of 1st BZ: K and K'
(not equivalent), Dirac points*

$$\mathbf{K} = \left(\frac{2\pi}{3a}, \frac{2\pi}{3\sqrt{3}a} \right) \quad \mathbf{K}' = \left(\frac{2\pi}{3a}, -\frac{2\pi}{3\sqrt{3}a} \right)$$

*⇒ important points for electronic
properties (low-energy excitations)*

graphene electronic structure

Tight-binding Hamiltonian for electrons in graphene

$$H = -t \sum_{\langle i,j \rangle, \sigma} (a_{\sigma,i}^\dagger b_{\sigma,j} + \text{H.c.}) - t' \sum_{\langle\langle i,j \rangle\rangle, \sigma} (a_{\sigma,i}^\dagger a_{\sigma,j} + b_{\sigma,i}^\dagger b_{\sigma,j} + \text{H.c.})$$

$a_{i,\sigma}$ ($a_{i,\sigma}^\dagger$) annihilates (creates) an electron with spin σ ($\sigma = \uparrow, \downarrow$) on site \mathbf{R}_i on sublattice **A**
similar def. for sublattice B

t nearest-neighbor hopping energy, $t \approx 2.8\text{eV}$

t' next nearest-neighbor hopping energy, $0.02t < t' < 0.2t$
hopping in the same sublattice

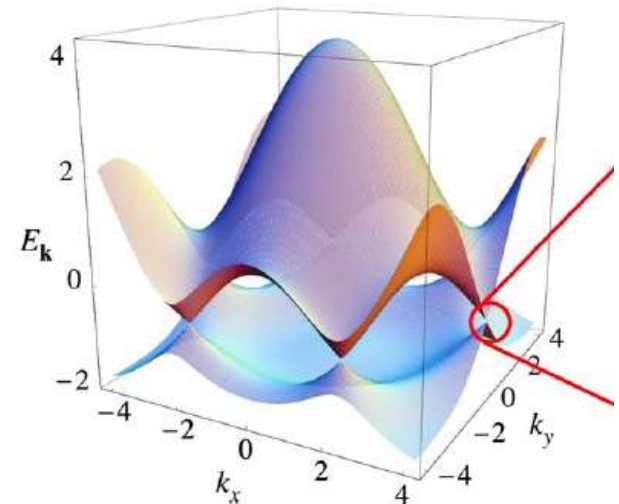
Energy bands (Wallace, 1947)

$$E_{\pm}(\mathbf{k}) = \pm t \sqrt{3 + f(\mathbf{k})} - t' f(\mathbf{k})$$

+ upper band (π^*), - lower band (π)

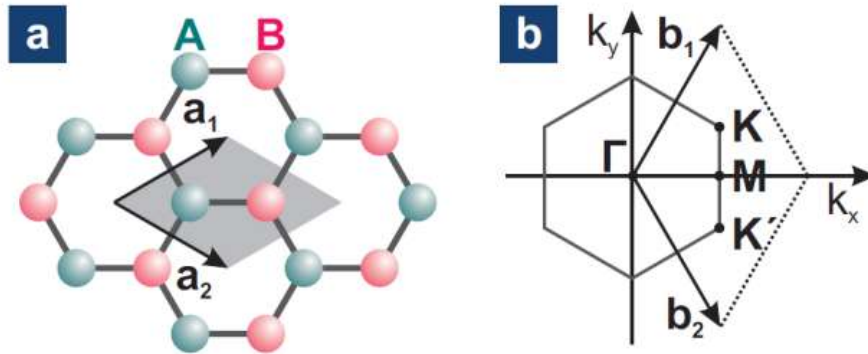
$$f(\mathbf{k}) = 2 \cos(\sqrt{3}k_y a) + 4 \cos\left(\frac{\sqrt{3}}{2}k_y a\right) \cos\left(\frac{3}{2}k_x a\right)$$

- symmetric spectrum if $t' = 0$
- electron-hole symmetry broken for $t' \neq 0$



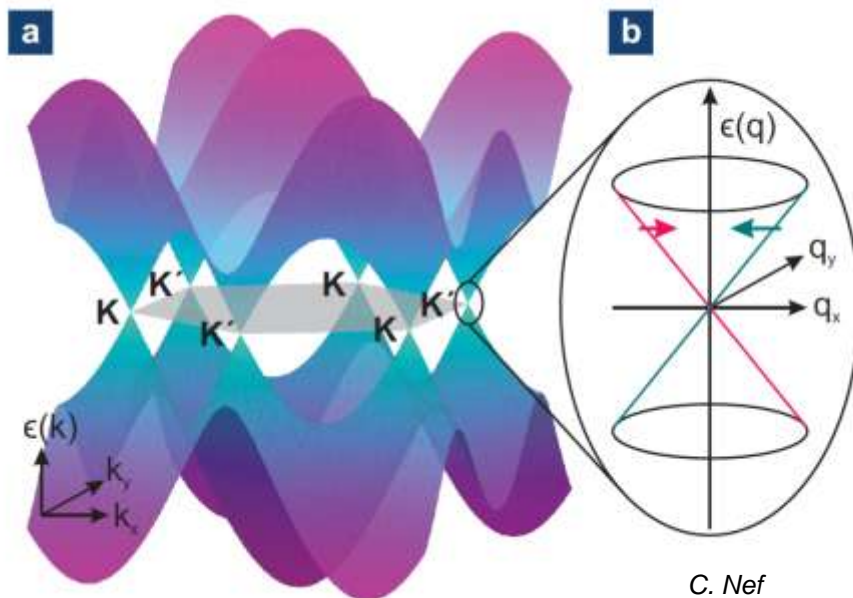
energy spectrum in units of t for finite values of t and t' , with $t = 2.7\text{ eV}$ and $t' = -0.2t$

graphene electronic structure



a) graphene honeycomb lattice with the two triangular sublattices *sublattice A*,

b) graphene Brillouin zone in momentum space



$E_{\pm}(\mathbf{q})$ band structure close to one of the Dirac points (at the K or K' point in the BZ): **linear**

Expand full band structure close to K (or K')
 $\mathbf{k} = \mathbf{K} + \mathbf{q}$, with $|\mathbf{q}| \ll |\mathbf{K}|$

$$E_{\pm}(\mathbf{q}) \approx \pm v_F |\mathbf{q}| + O[(q/K)^2]$$

\mathbf{q} momentum measured relatively to Dirac point

v_F Fermi velocity, $v_F = 3ta/2 \approx 10^6$ m/s

- Valence band filled, fermi energy at $E=0$
- Zero band-gap semiconductor
vanishing DOS metal
- Two non-equivalent 'valleys', K and K', *pseudo-spin*

C. Nef

graphene field-effect device

charge carrier density n

$$[n] = \text{m}^{-2}$$

$$C = \frac{Q}{V_g} = \frac{\epsilon_0 \epsilon A}{d}$$

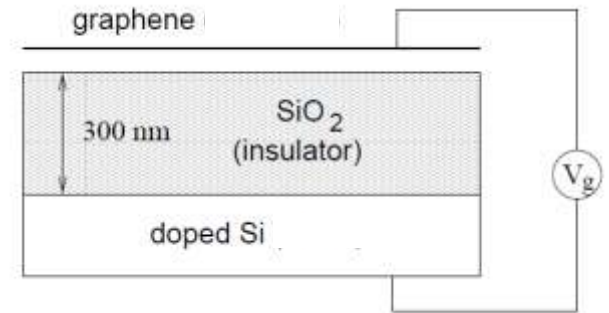
$$n = C_g V_g \frac{1}{e}$$

C_g gate capacitance per surface (F/m^2)

$$n = \alpha V_g \quad \alpha \approx 7.2 \cdot 10^{10} \frac{\text{cm}^{-2}}{\text{V}}$$

typ. SiO₂ wafer $\epsilon = 3.7$

$$d = 300 \text{ nm}$$



field effect mobility

$$\mu_{FET} = \frac{dG}{dV_g} \cdot \frac{L}{W} \cdot \frac{1}{C_g}$$

C_g gate capacitance per surface (F/m^2)

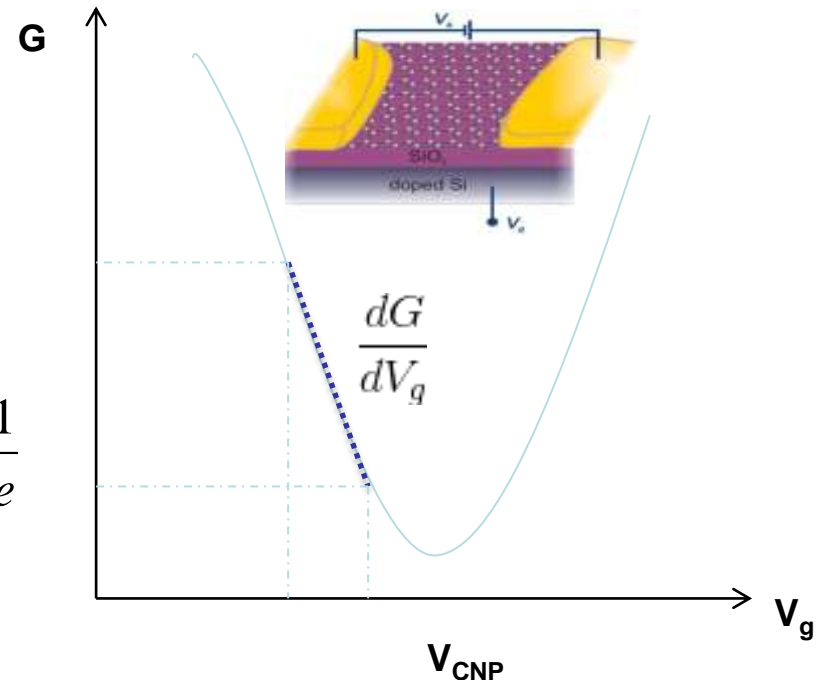
L, W length and width of device

NB

(1) $V_{CNP} \neq 0$ due to residual chemical doping

$$n = C_g (V_g - V_{CNP}) \frac{1}{e}$$

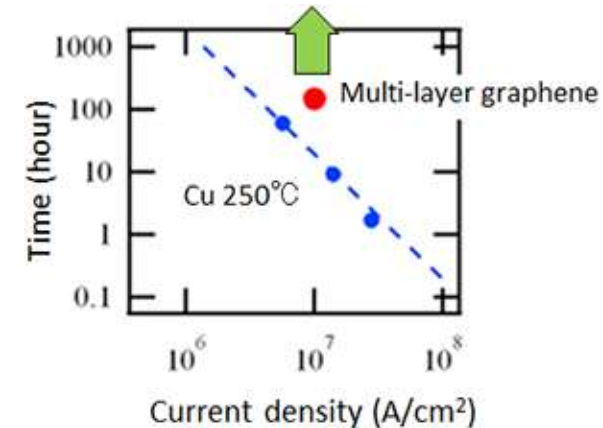
(2) μ reduction due to trapped charged defects at polar insulators interface (e.g.: SiO₂, HfO₂, Al₂O₃)
Other substrates: hBN, Si₃N₄, *in-situ* oxidized Al



graphene-based devices

⇒ interconnects (high-frequency transistors & sensors)

- large current density
see e.g. Pop et al, Nano Lett 2012 (thermal "stewardship": $j > 10^9$ A/cm²)
- recrystallization for control
see e.g. Johnson et al. ACS Nano, 2015
- ballistic transport in nanoribbons, *electron optics*
see e.g. de Heer et al., Nature 2014 (on SiC, $w=40$ nm, $l>10\mu$ m)



**Current density tolerance
at 250 °C.**

Blue: Cu

Red: MLG, no break after 150h

Yokoyama et al., 2013, www.aist.go.jp

⇒ contacts for molecular and organic electronics

- stability (covalent crystal)
- ultimately thin contact electrode (reduced screening)
- *in-situ* junction imaging (STM, HRTEM, LEPS)
- "soft" top electrode (organic electronics)
see e.g. Lee et al., Adv. Mat. 2014

graphene structure: stacking

Graphite = stacked graphene layers

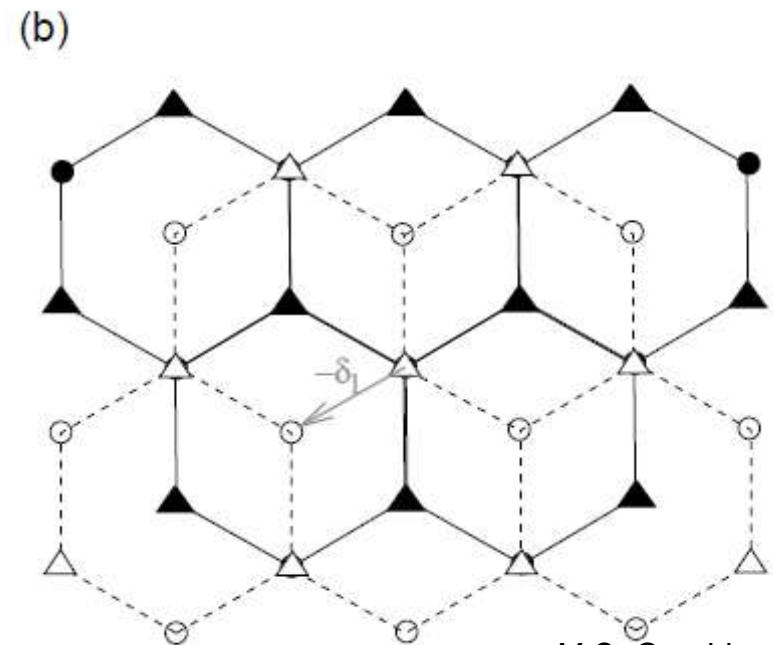
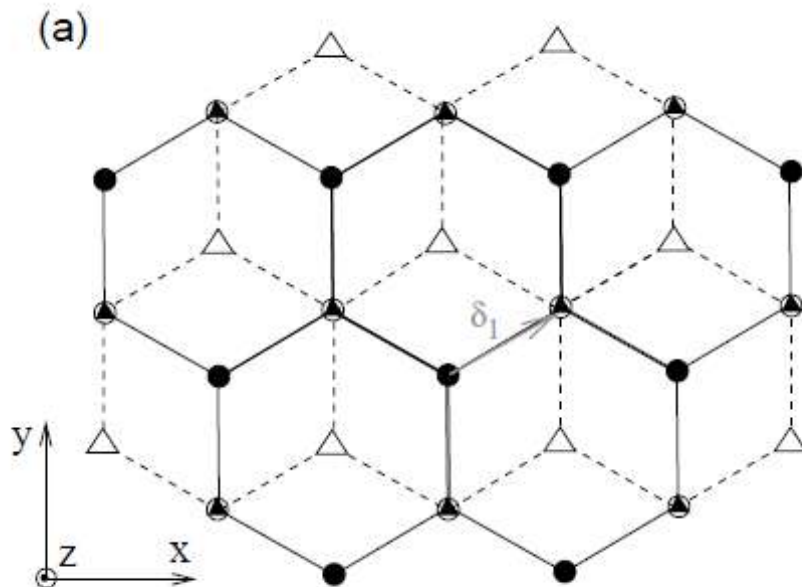
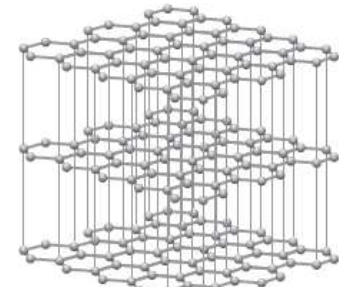
stacking: distance between layers $d = 2.4a = 0.34 \text{ nm}$

ordered graphite: two different basic stacking orders

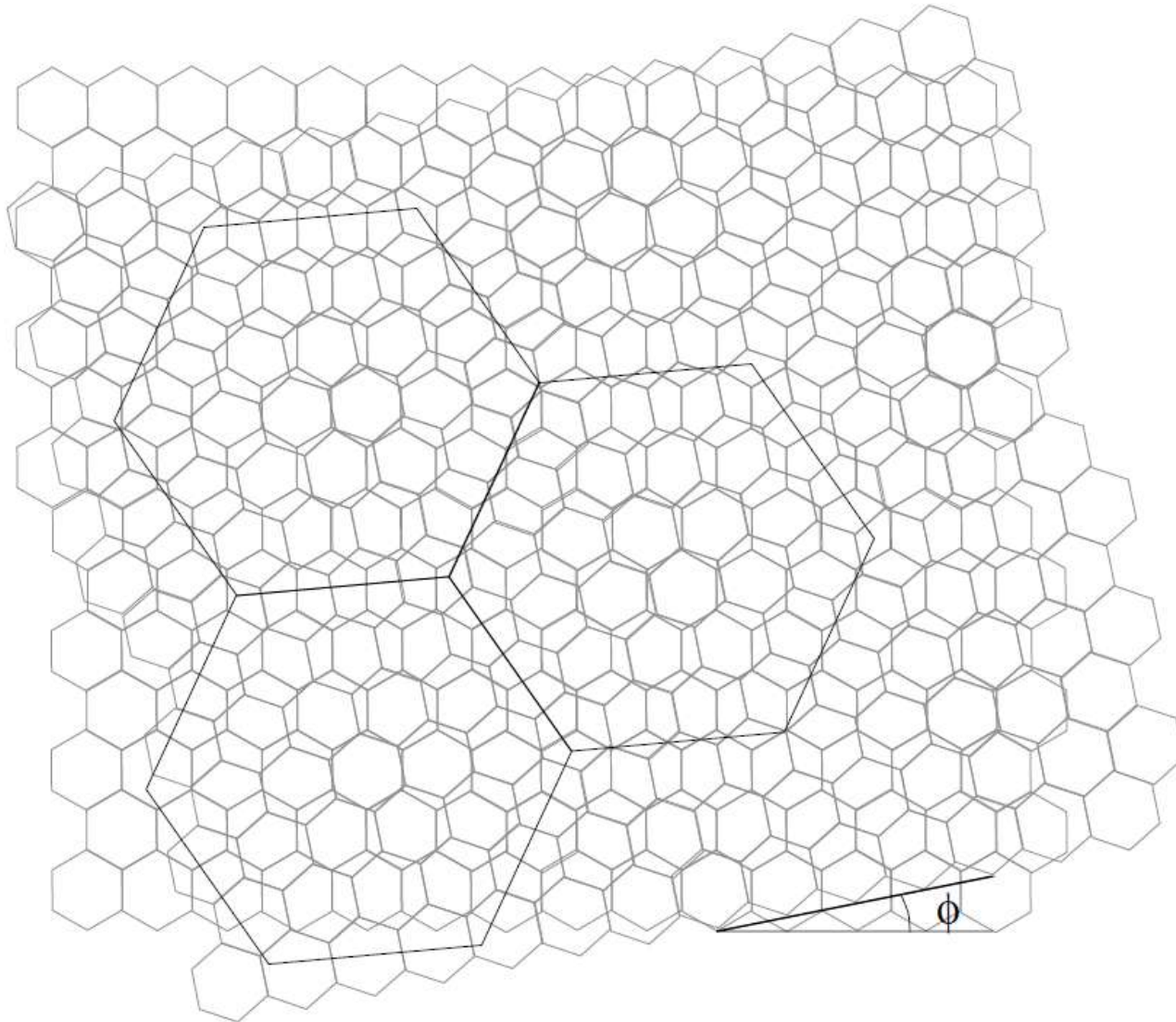
turbostratic graphite: disorder in the stacking



graphite



graphene structure: Moiré

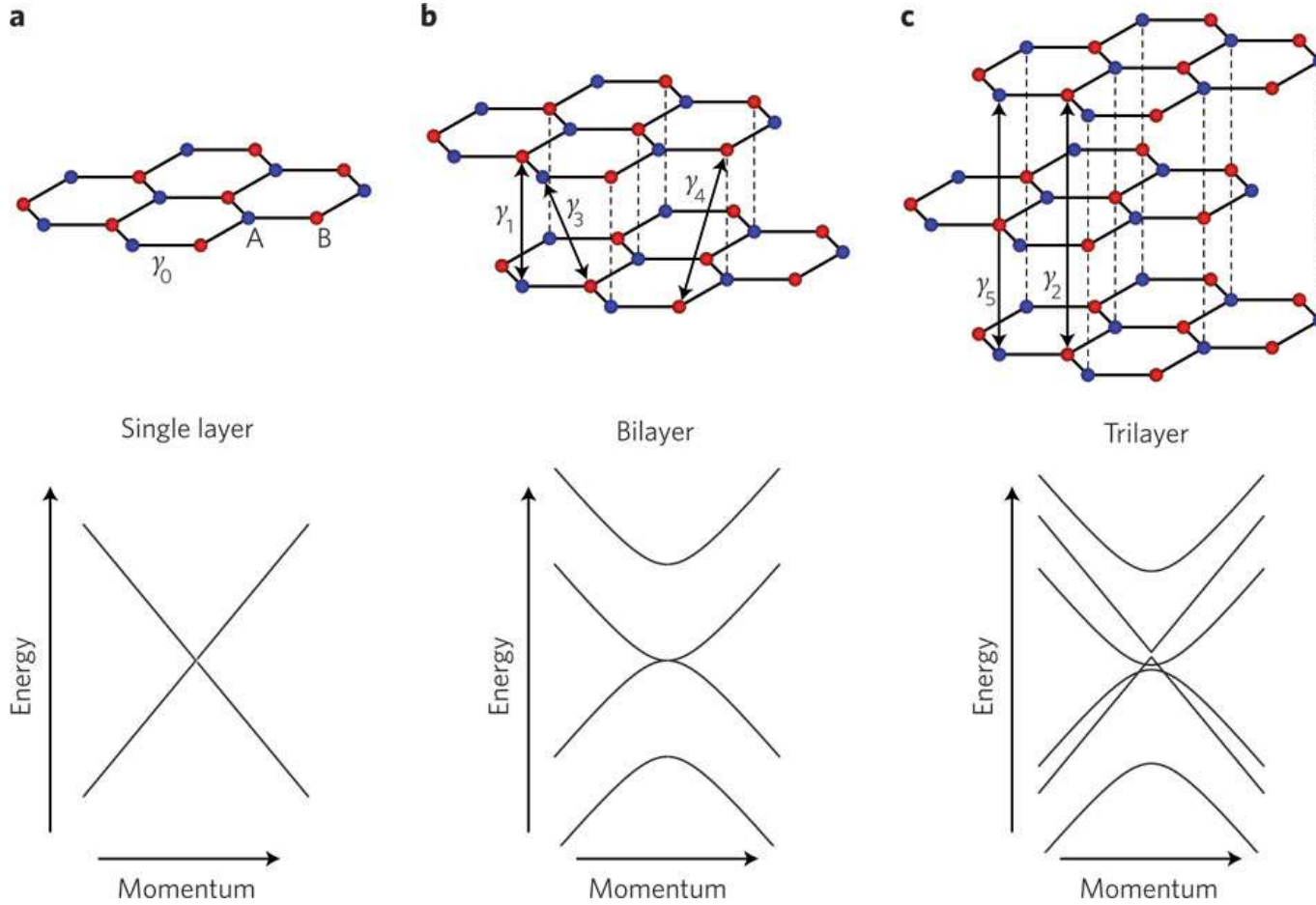


Moiré pattern obtained by stacking two honeycomb lattices (gray) with a relative (chiral) angle ϕ . One obtains a hexagonal superstructure indicated by the black hexagons.

M.O. Goerbig et al.

graphene structure: multilayer

bilayer graphene: two layers shifted with respect to each other, the B atoms of one are situated directly above the A atoms of the other



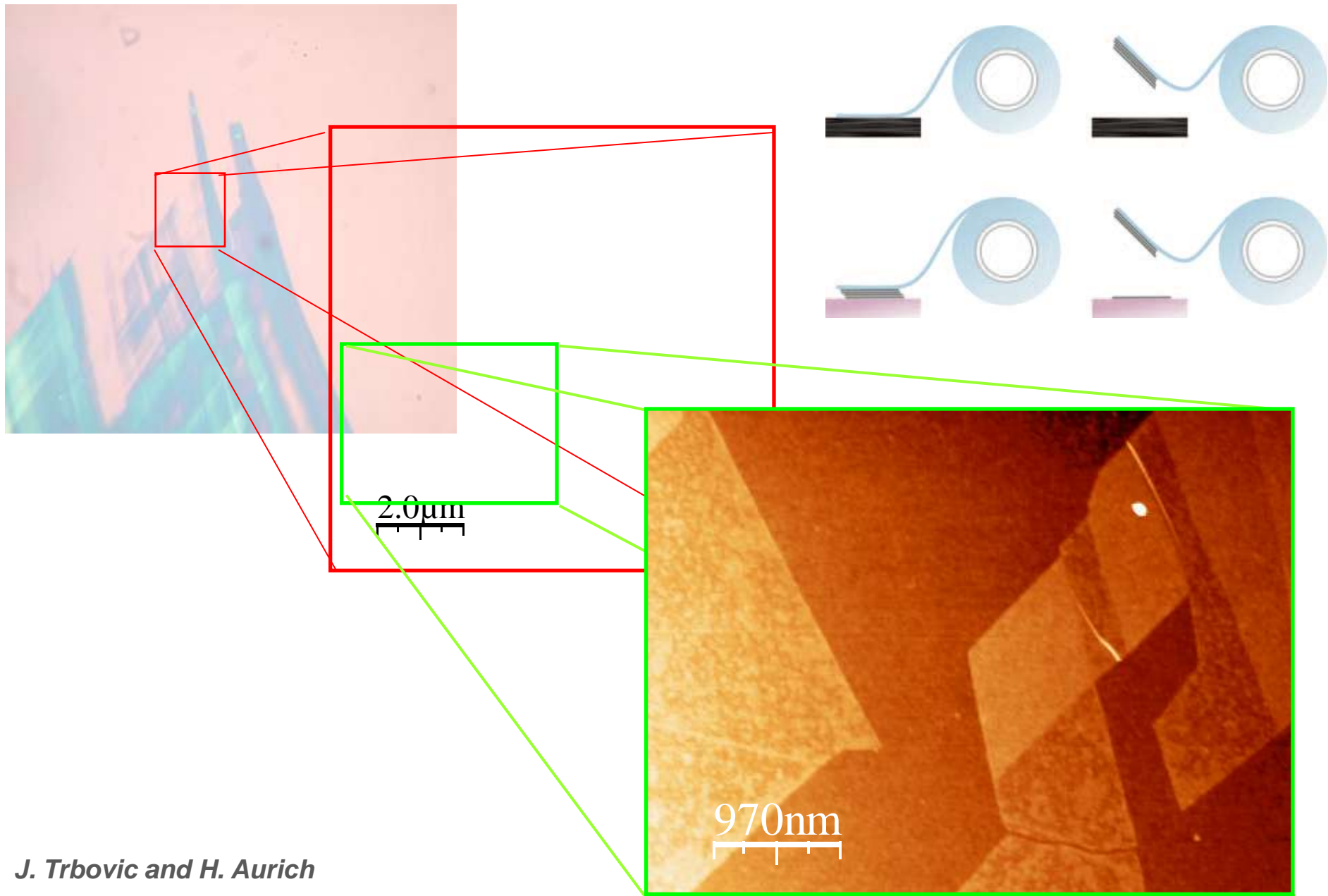
- massive chiral Fermions (no QED equivalent)
- higher energy subbands do not contribute to transport (unless high doping)

- graphene structure
- fabrication and CVD growth
- characterization: Raman spectroscopy

Examples

- graphene electroburning for molecular junctions
- Quantum Hall Effect

Graphene: scotch tape

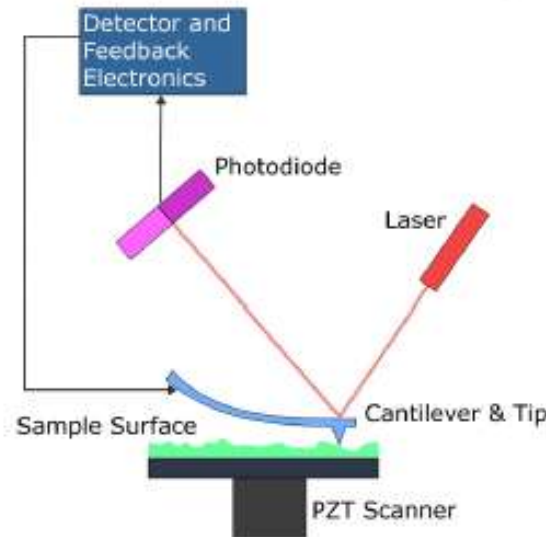


Graphene: scotch tape

Q: How to isolate 2D monolayers?

- Step 1: Prepare a layered crystal with a fresh surface.
- Step 2: Rub the layered crystal against another surface (virtually any solid surface is suitable). This produces a variety of flakes attached to the secondary surface very much as drawing by chalk on a blackboard does.
- Step 3: Use an optical microscope to identify single-layers candidates deposited on top of an oxidized *Si* wafer through the phase contrast induced by the flakes.

A: with an atomic force microscope (AFM)



Q: Why was this simple procedure not used before?

- Monolayers are rare.
- 2D crystal have no clear signatures in transmission electron microscopy.
- Monolayers cannot be seen with an optical microscope on most substrates (glass or metals).
- AFM has very low throughput.
- It was not believed that macroscopic 2D crystals exist (by the Mermin-Wagner theorem).
- The key step was the preliminary identification with an optical microscope of 2D flakes placed on top of an oxide *Si* wafer.

graphene fabrication/synthesis

Single layer

Few layers

Micromechanical cleavage of HOPG

Chemical reduction of exfoliated graphene oxide
(2–6 layers)

CVD on metal surfaces

Epitaxial growth on an insulator (SiC)

Thermal exfoliation of graphite oxide (2–7 layers)

Intercalation of graphite

Aerosol pyrolysis (2–40 layers)

Dispersion of graphite in water, NMP

Reduction of single-layer graphene oxide

Arc discharge in presence of H₂ (2–4 layers)

from Rao et al., Ch.1 in, Graphene: Synthesis, Properties, and Phenomena Wiley (2013)

see also Avouris et al., Mat. Today (2012)

wish list...

- backgate control for electrodes and junction
- no defects, controlled edges
- scalability / parallel fabrication

good candidate: CVD

NB SiC: not self-limiting, charge density tuning a challenge

CVD process & catalyst materials

Graphene (SLG) & few-layer graphene (FLG)

- **gas precursor:** CH_4 (C_2H_2)
- **catalytic** metal surface for gas decomposition; growth kinetics depends on metal
- usually: **polycrystalline** graphene

Lattice constant of graphene: 2.46 Å

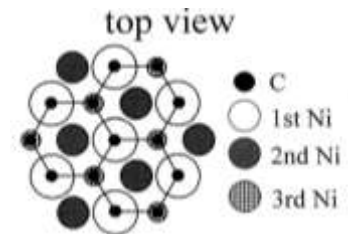
Nickel: ~ 2.49 Å

Copper: ~ 2.55 Å

} low cost, large grain size,
easier to etch

other catalytic surfaces:
Co, Fe, Ir, Pd, Pt, Ru

Bocquet & Witterlin, *Surf. Sci.* (2009)



CVD process & catalyst materials

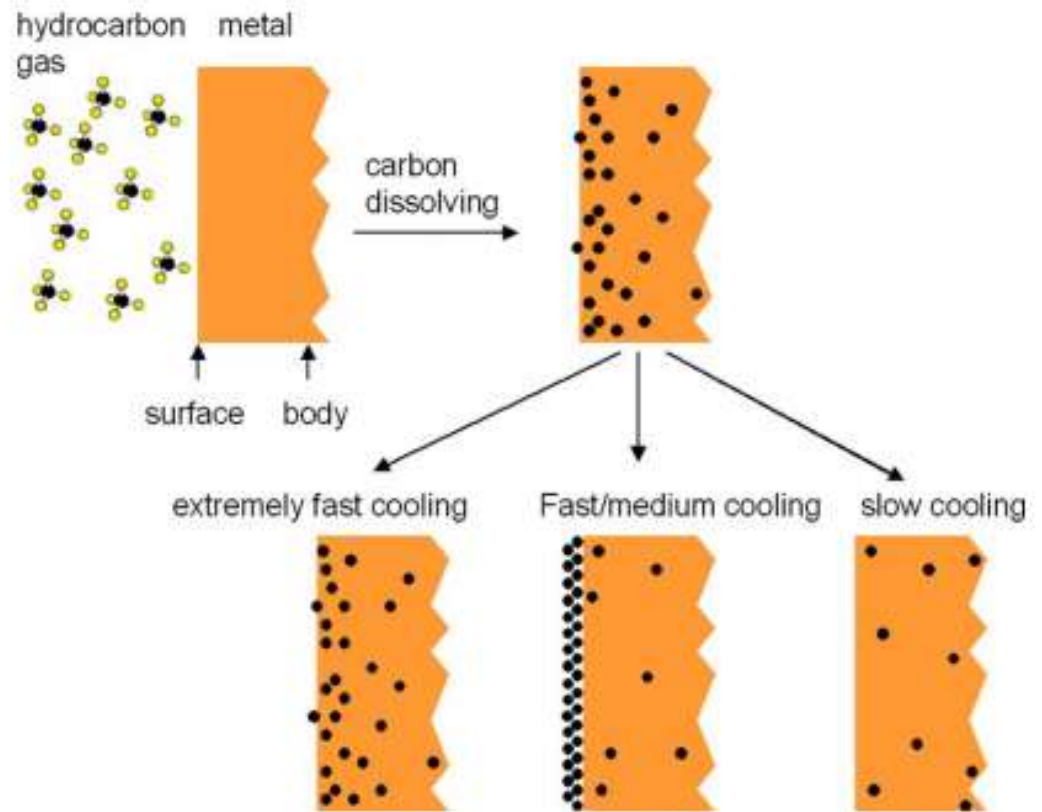
Nickel

- high C solubility in Ni
~ 1 % atoms
- melting point: 1455°C
- surface segregation
- not self-limiting, monolayer control delicate

⇒ **large-scale sheets**

FLG on Ni: Dresselhaus, Kong, Nano Lett. (2009)

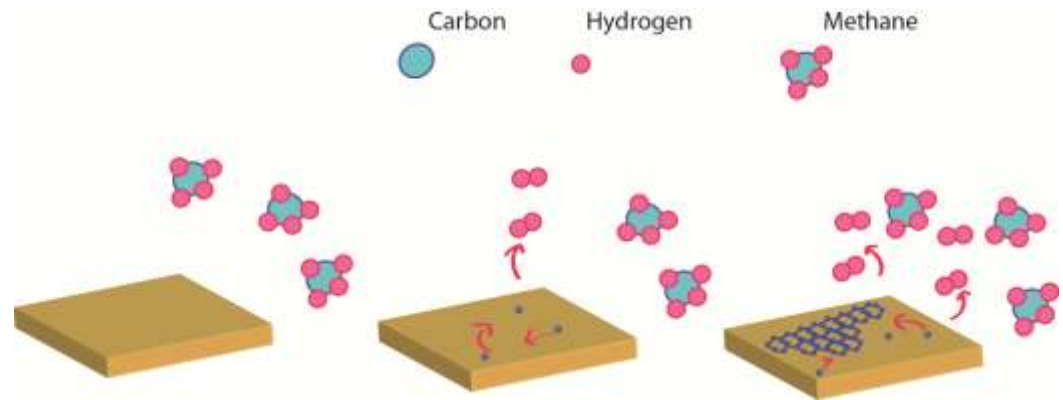
SLG on Ni: Choi, Hong, Kim et al., Nature (2009)



CVD process & catalyst materials

Copper

- very low C solubility in Cu
1000x less than in Ni
- melting point: 1084°C
- surface mediated, self-limiting

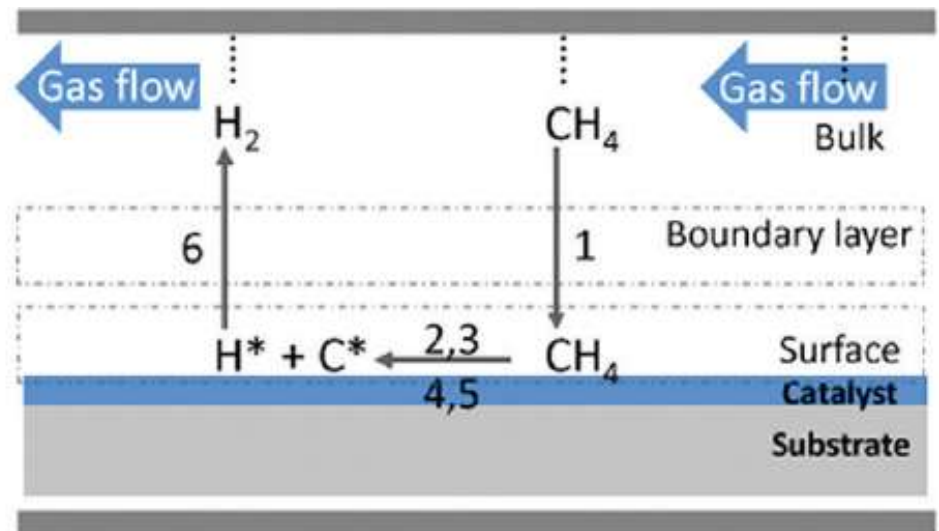


⇒ large-scale sheets

SLG on Cu: Ruoff et al., Science (2009)

NB: **solid** C feedstock possible,
e.g: PMMA, sucrose on Cu
Tour et al., Nature (2010)

**Pressure & Temperature
control the boundary layer**



CVD process & catalyst materials

Graphene (SLG) & few-layer graphene (FLG)

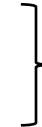
- **gas feedstock:** CH_4 (C_2H_2)
- **catalytic** metal surface for gas decomposition; growth kinetics depends on metal
- usually: **polycrystalline** graphene
- **nucleation** centers/zones and **extension** of domains

*evolution of graphene growth by C isotope labeling: **inhomogeneous** distribution of ^{12}C and ^{13}C identified by Raman spectroscopy*

Lattice constant of graphene: 2.46 Å

Nickel: $\sim 2.49 \text{ Å}$

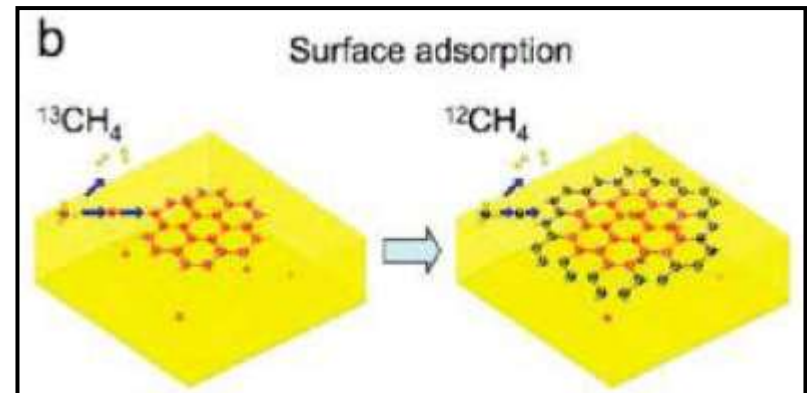
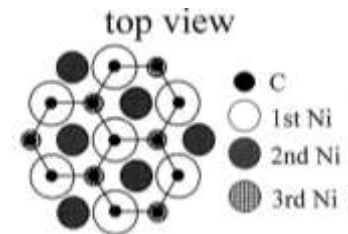
Copper: $\sim 2.55 \text{ Å}$



low cost, large grain size, easier to etch

other catalytic surfaces:
Co, Fe, Ir, Pd, Pt, Ru

Bocquet & Witterlin, *Surf. Sci.* (2009)



growth mechanism

Evolution of Graphene Growth on Ni and Cu by Carbon Isotope Labeling

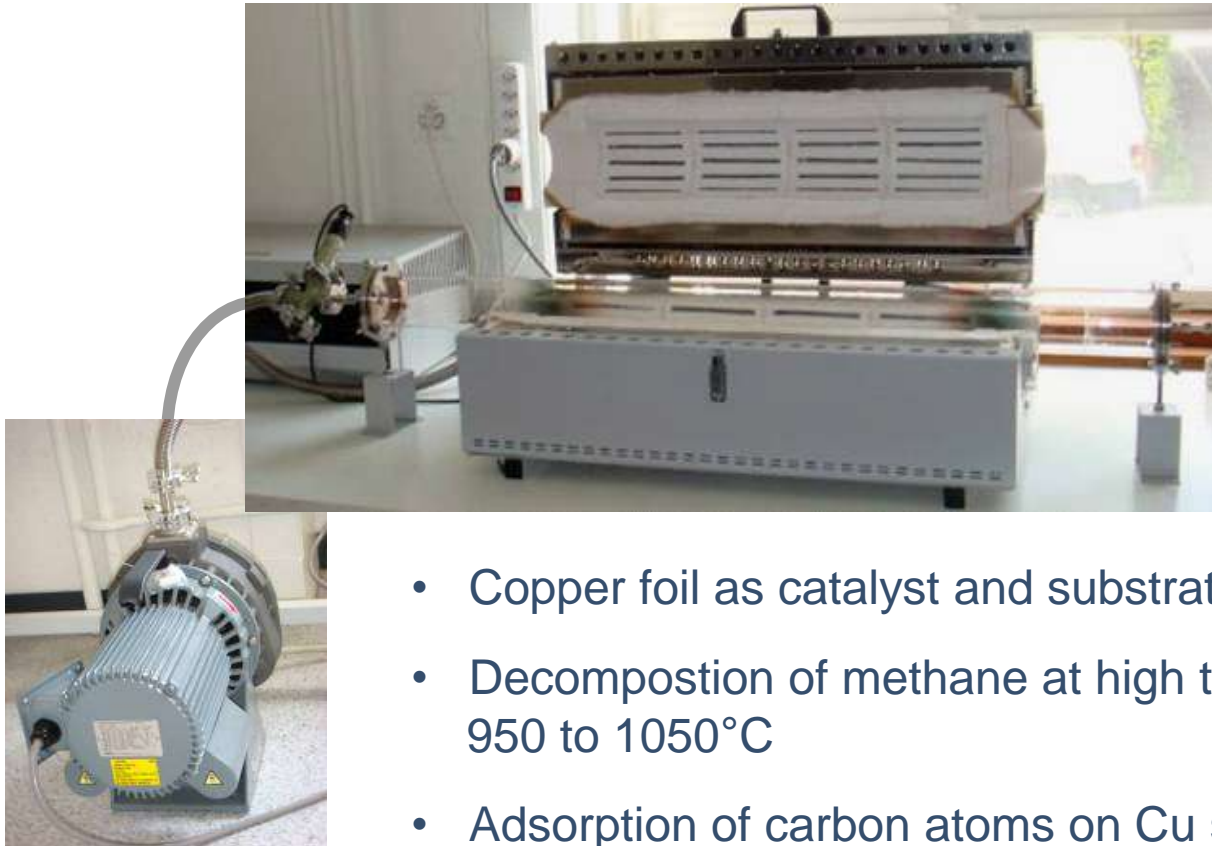
trick: separation of the ^{12}C and ^{13}C Raman modes

Frequency of Raman modes are given by:

$$\omega = \omega_{12} \sqrt{\frac{m_{12}}{n_{12}m_{12} + n_{13}m_{13}}}$$

if the atoms are randomly mixed and the bond force constants are assumed to be equal

CVD growth



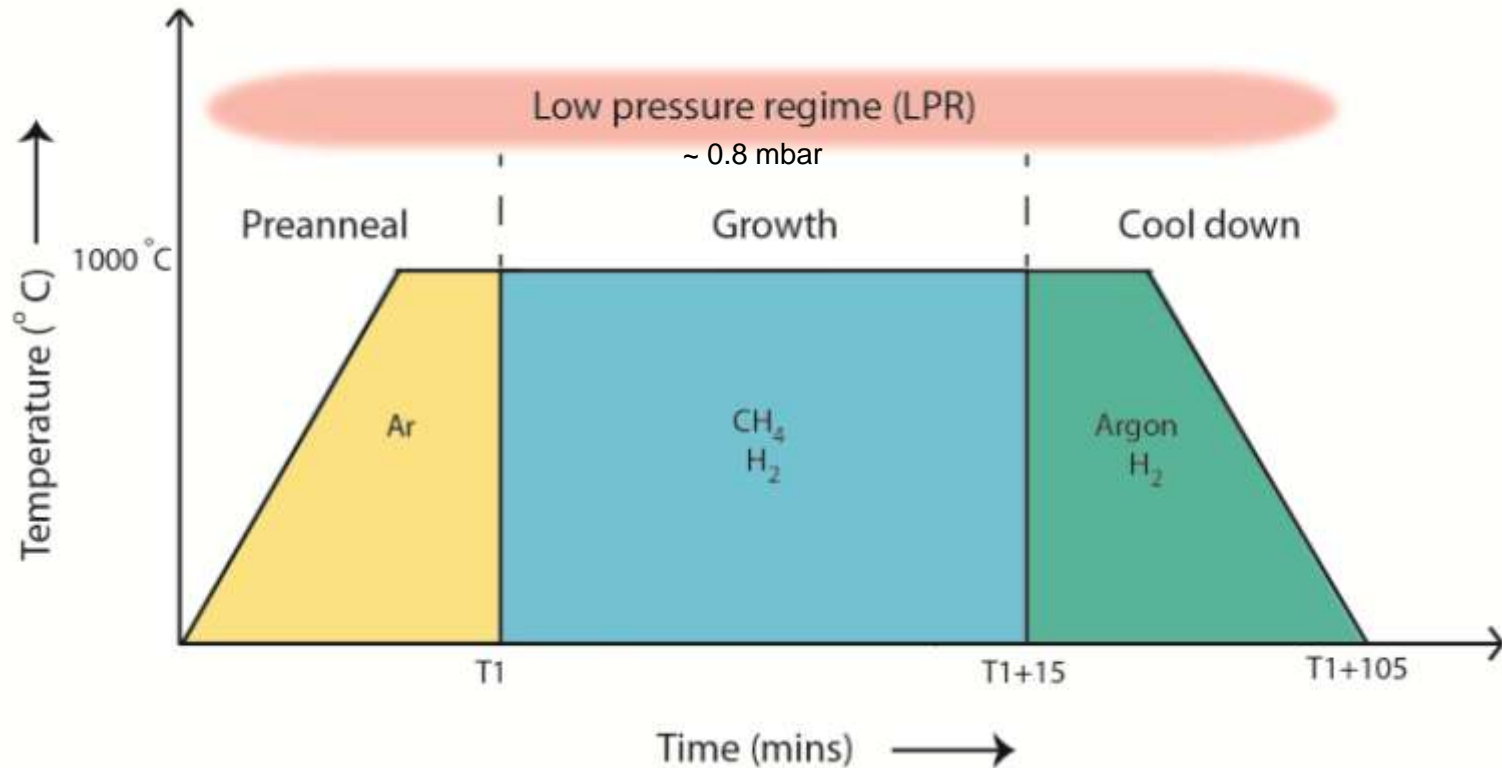
0.05 mbar
1000°C

10 sccm H₂
25 sccm
CH₄

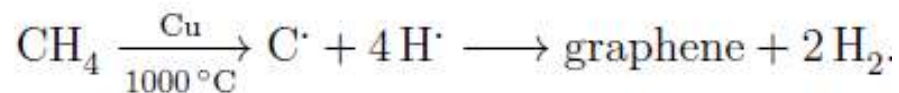


- Copper foil as catalyst and substrate
- Decomposition of methane at high temperatures 950 to 1050°C
- Adsorption of carbon atoms on Cu surface
- Graphene growth at different nucleation zones

CVD growth

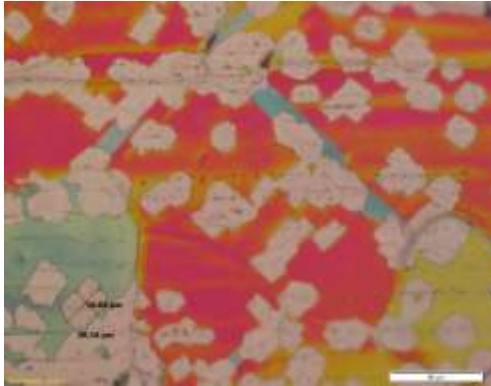


CVD Graphene growth. A Copper foil is annealed in H₂ flow for time T1 (annealing time ~ 2 hours) followed by graphene growth for 15 mins to hours and subsequent cool down to room temperature.

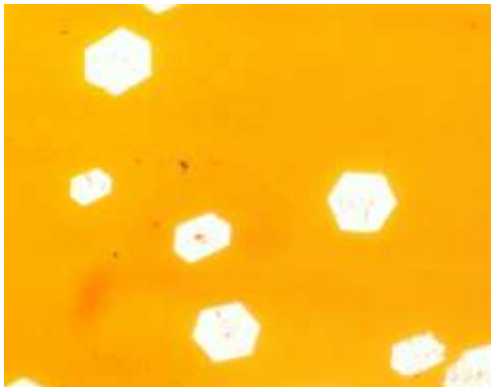


CVD growth: a few results

Growth at different boundary layer conditions: p, T, gas flow

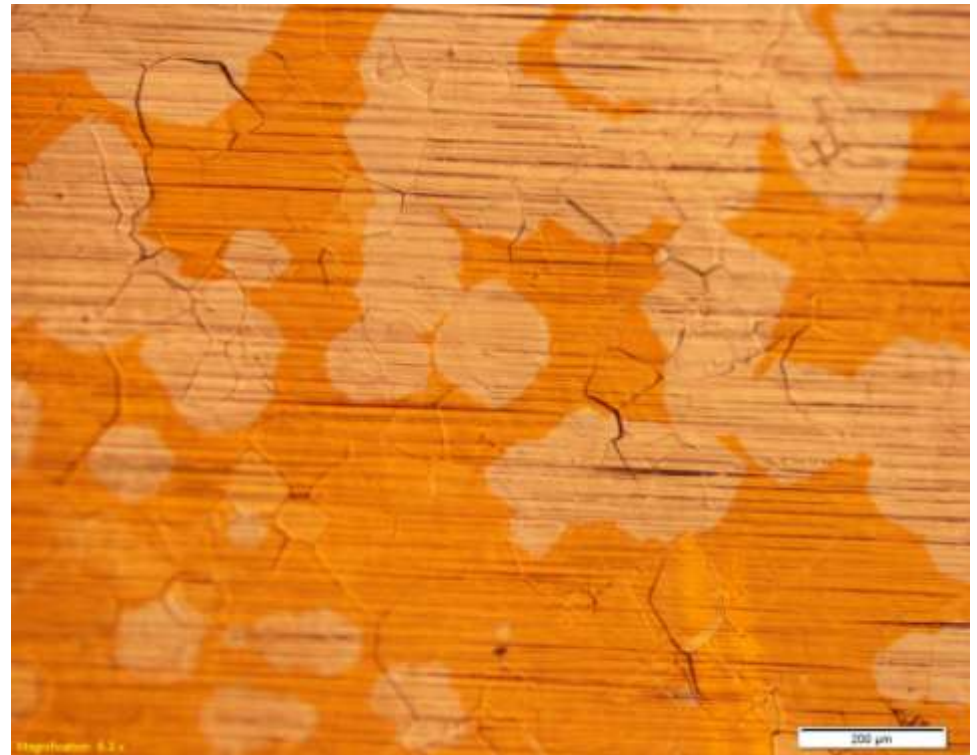


Condition 1: Low Pressure. (LP) Scale bar 50 μm



Condition 2: HP. Scale bar 20 μm.

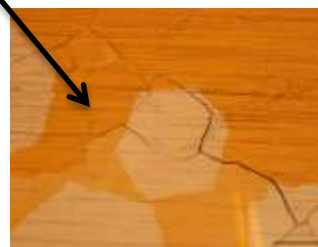
Coalescing grains of CVD graphene



Condition 3: HP. Scale bar 200 μm.

controlling growth parameters

Flow rate (sccm)	SG 11 1000 C	SG 12 1000 C	SG 16 1000 C	SG 25 1000 C	SG 30 1000 C	SG 40 1020 C	SG 55 1065 C
Ar + (200ppm)CH ₄ , H ₂	200 100	200 100	200 20	200 5	30 10	30 5	~60 20
Pre anneal	H ₂ 500	H ₂ 500	Ar 100	Ar 100	Ar 200	Ar 200 H ₂ 5	Ar 200
Comments	PA: 3 GT: 6 ~20um ~ 5 mbar	PA: 3 GT: 3 ~20um ~ 100mbar	PA: 1 GT: 6 ~200um ~150 mbar	PA: 12 GT: 5 Full coverage ~200 mbar	PA: 0.5 GT: 6 ~200mbar No nucleation	PA: 0.5 GT: 4 ~0.7mbar Square shaped islands	PA: 12 GT: 2 ~1000um ~ 200 mbar

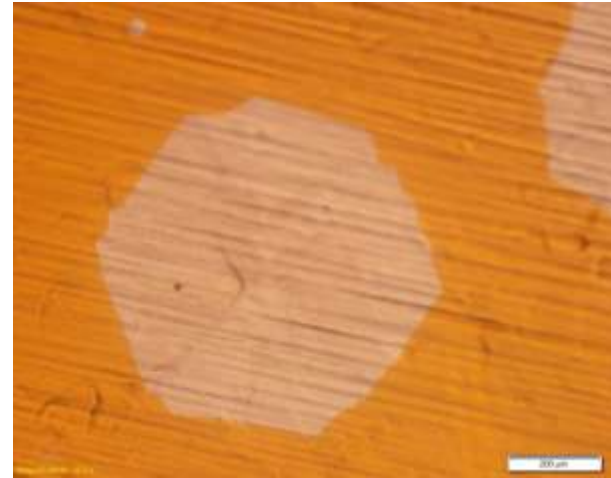
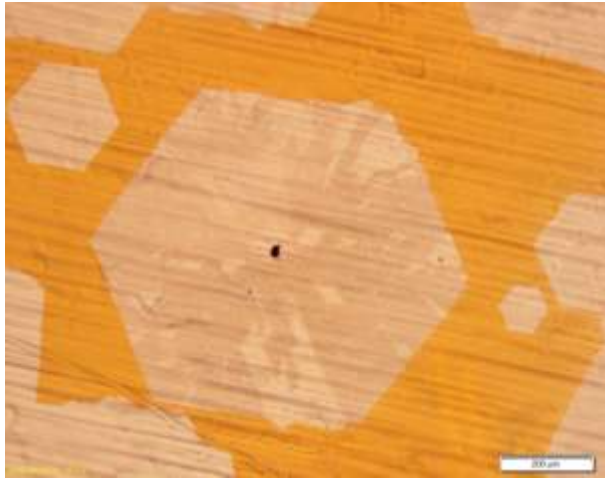


SG : Slow growth
PA : Pre Anneal
GT : Growth time in
hours

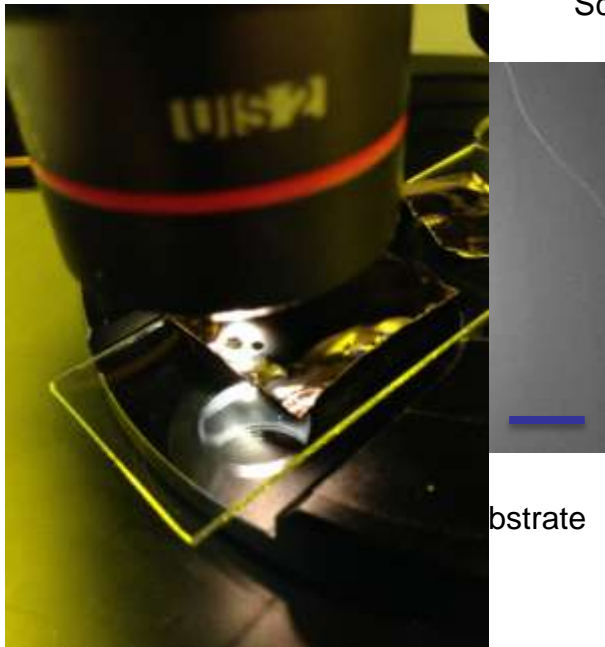


Optical images of graphene crystals on oxidized Cu substrate. Scale bar a) 50um b) 20 µm, c) 100 µm & d) 200 µm

large homogeneous graphene domains

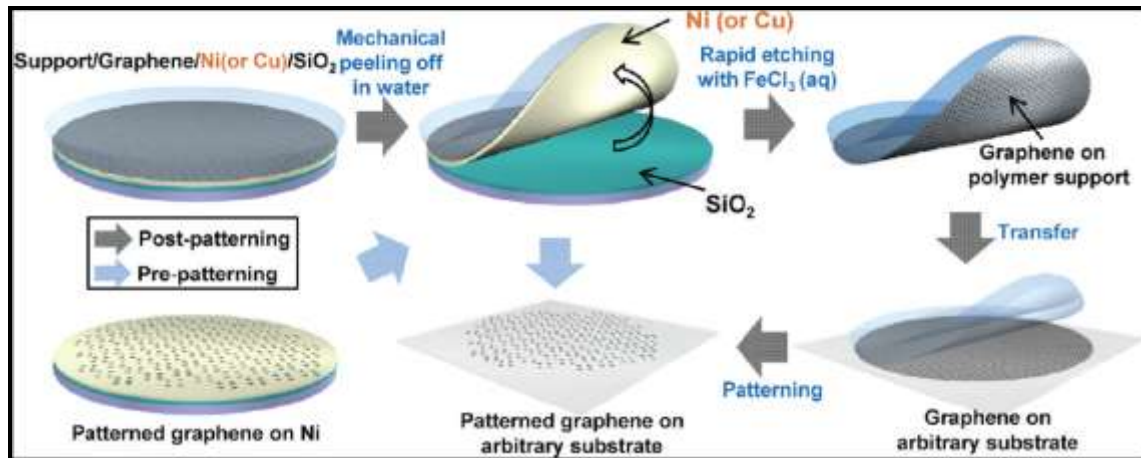
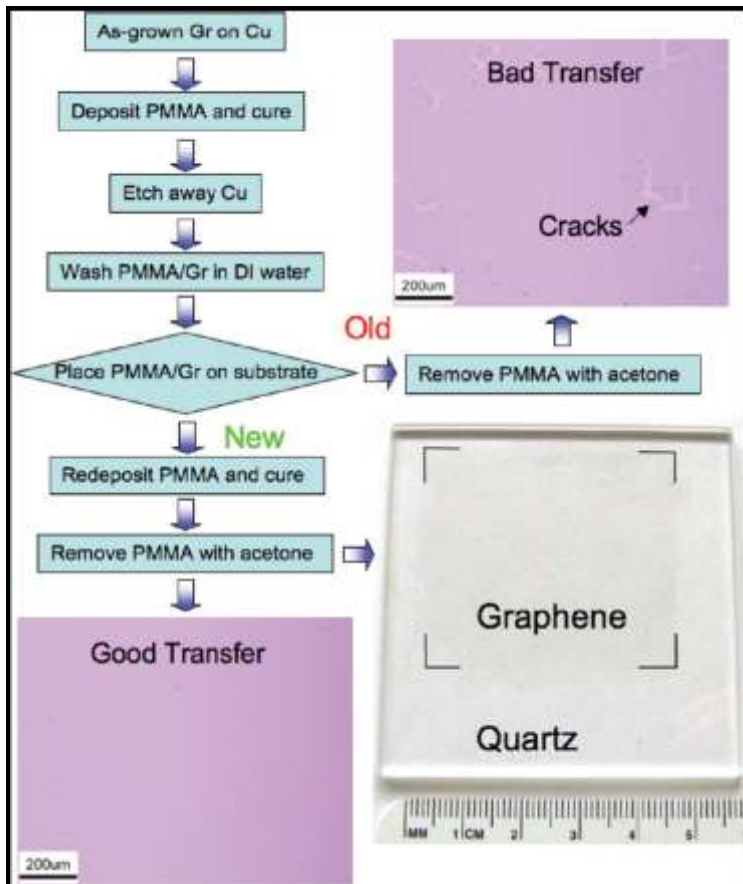


Optical images of graphene on oxidized Cu substrate.
Scale bars: 200 μm



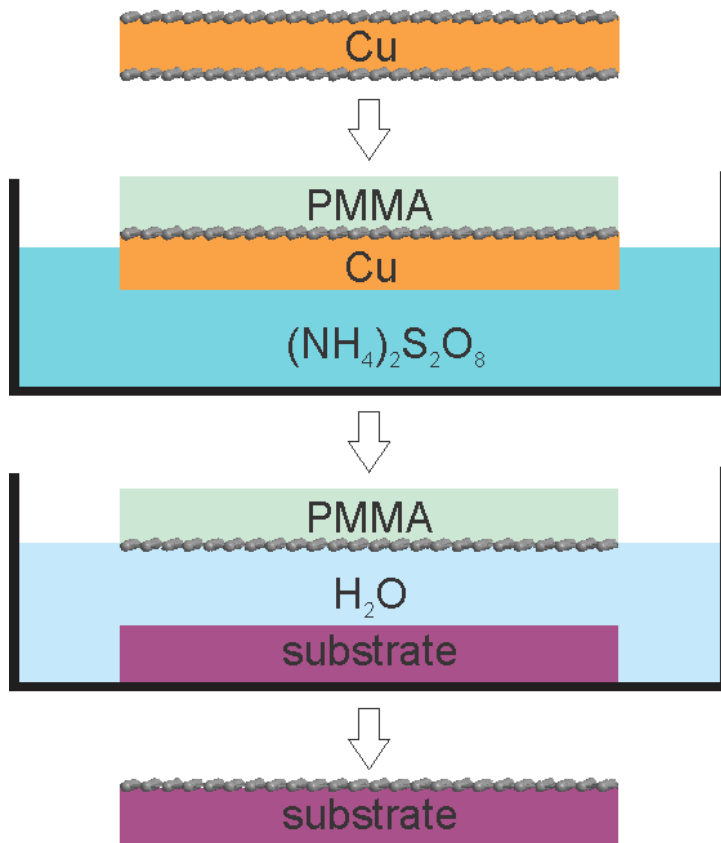
Optical Image of graphene after transfer to SiO₂
Scale bar: 400 μm

graphene transfer



- PMMA or PDMS used as support
- Cu etched in an aqueous solution of iron nitrate or iron chloride
- Transfer to almost any substrate possible
- Transfer free processes possible, by direct pre-patterning and underetching (Park, *NANO LETTERS*)

graphene transfer in our lab



- CVD graphene on Cu foil 25 μm
- Spin coating of PMMA and cure
- Etch back side in Ar/O_2 plasma
- Etching of Cu in 0.1M $(\text{NH}_4)_2\text{S}_2\text{O}_8$ in H_2O (ca. 4 h)
- Wash PMMA/graphene in several H_2O bathes
- Substrate is cleaned in Ar/O_2 plasma
- Substrate is placed below the PMMA/graphene and the water is removed with a syringe
- Substrate/graphene/PMMA is dried over night at ambient conditions
- PMMA is dissolved in warm acetone

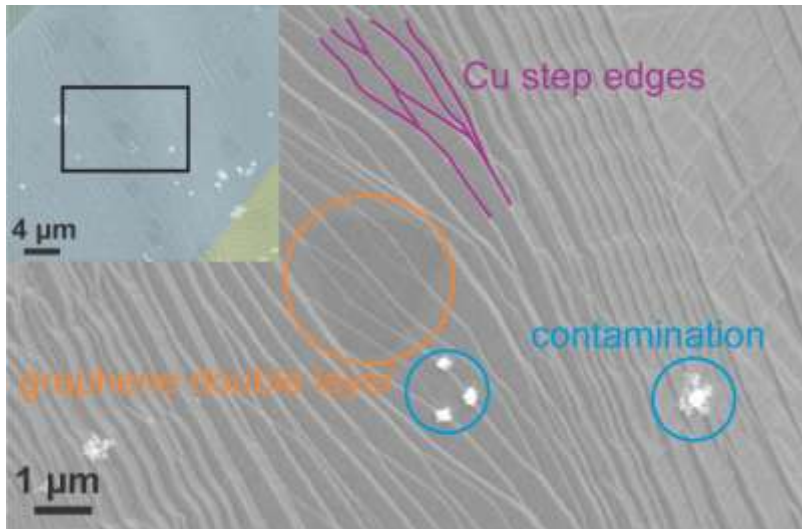
X. Li, R. S. Ruoff et al., *Nano Letters* **2009**, 9(12), 4359-4363

Y. Lee, J-H. Ahn et al., *Nano Letters* **2010**, 10, 490-493

C. Nef et al.

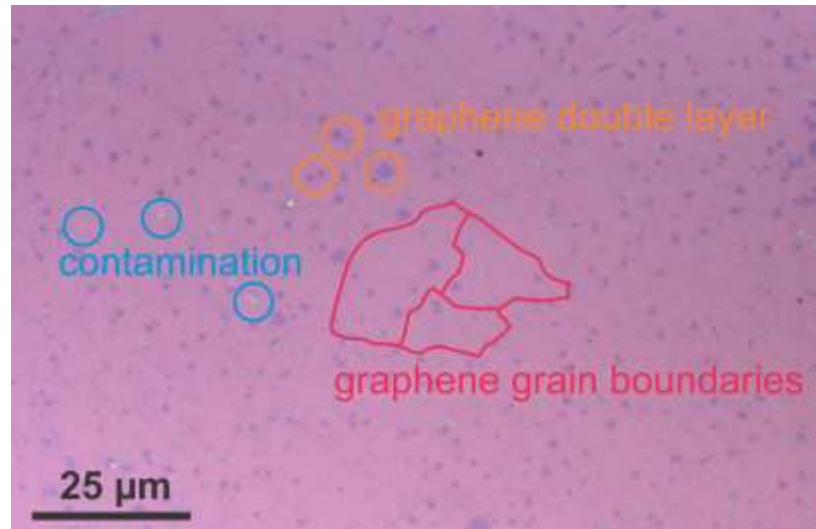
graphene imaging

Electron Microscopy on Cu



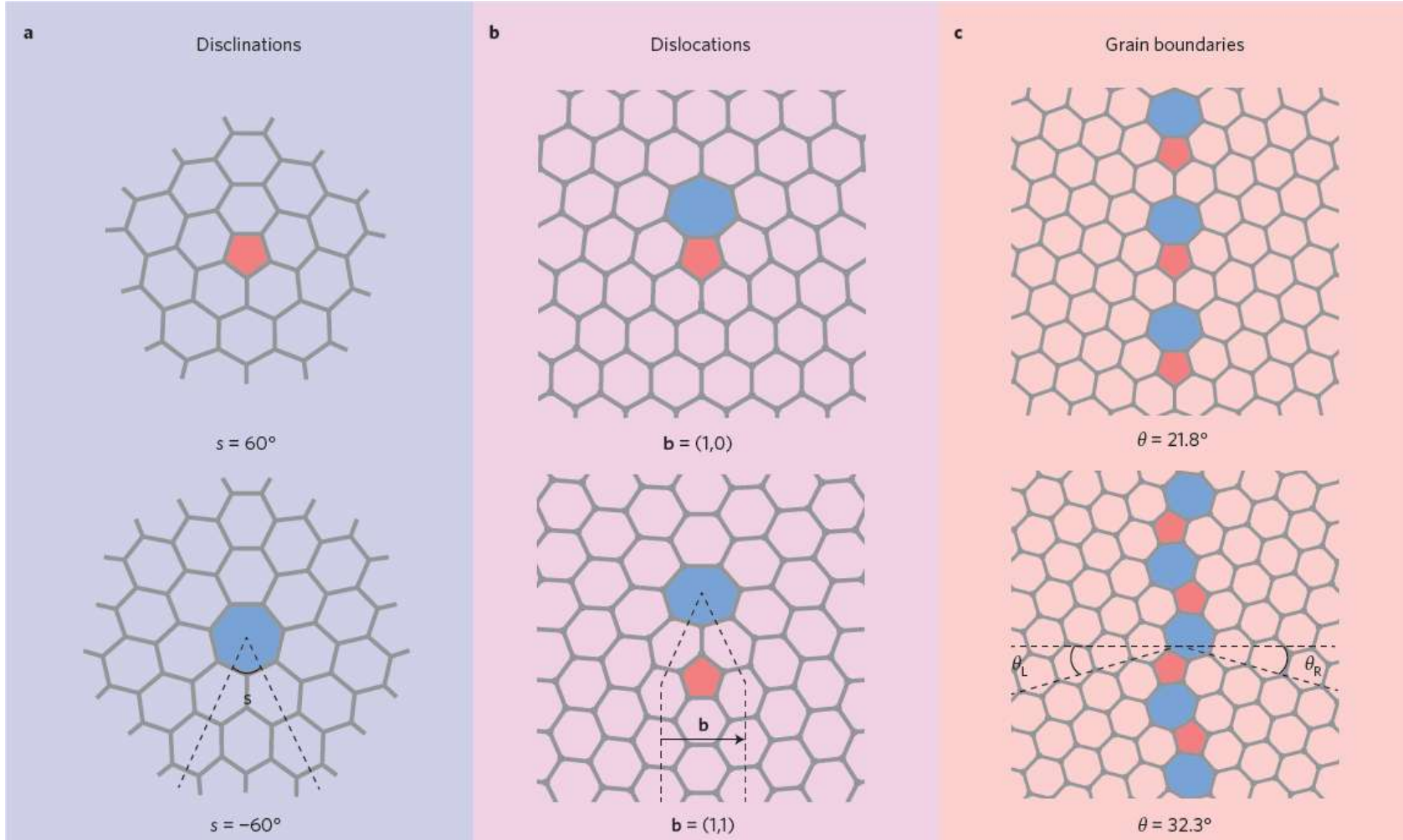
- Full coverage with graphene
- Small bi- and tri-layer flakes
- Cu grains (marked in different colors)

Optical Microscopy on SiO₂



- PMMA residues from transfer
- Graphene is polycrystalline

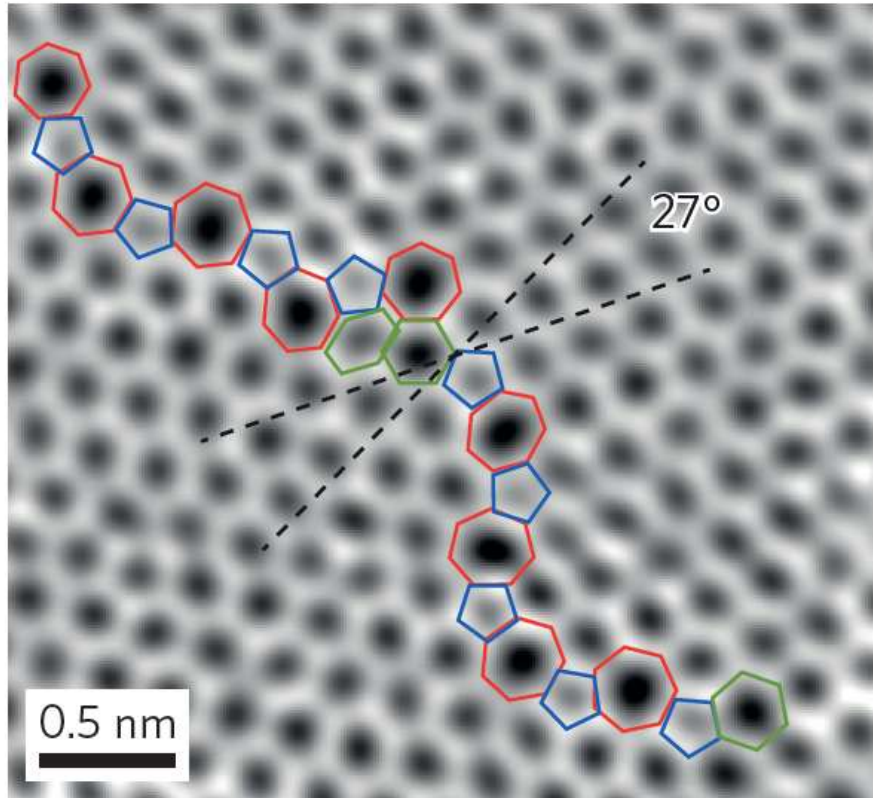
graphene defects



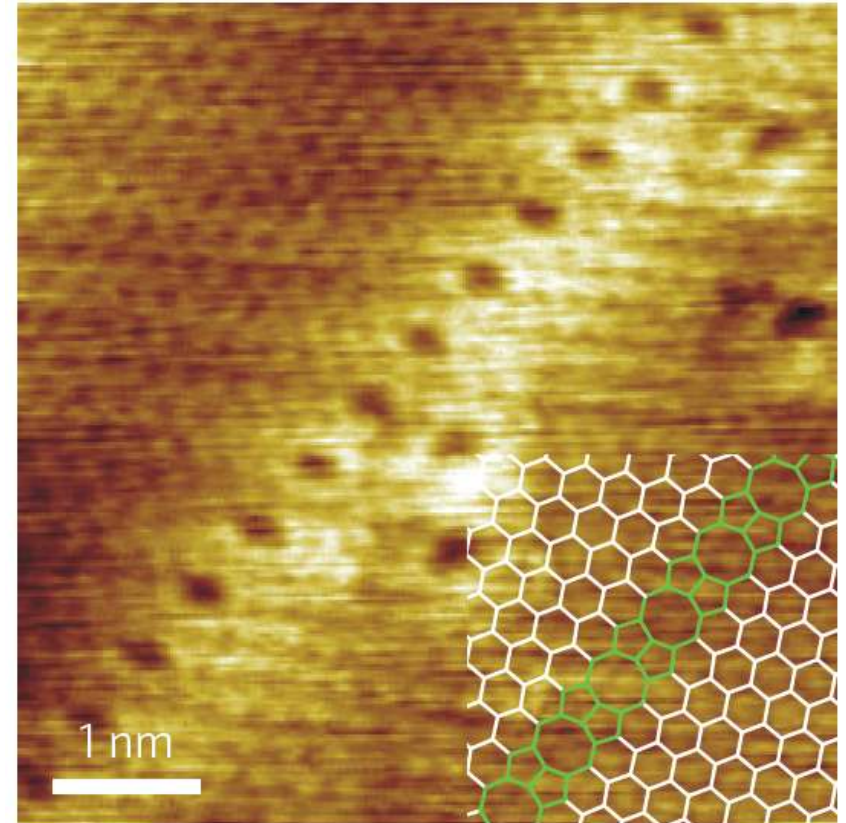
The presence of isolated disclinations in graphene is unlikely as it inevitably results in highly non-planar structures.

grain boundary (in 2D) = 1D chain of aligned dislocations

graphene defects



Aberration-corrected annular dark-field scanning **TEM** (ADF-STEM) image of a grain boundary stitching two graphene grains with lattice orientations rotated by $\sim 27^\circ$ with respect to each other. **The dashed lines outline the lattice orientations of the two domains.** The structural model of the interface highlighting **heptagons (red)**, **hexagons (green)** and **pentagons (blue)** is overlaid on the image.



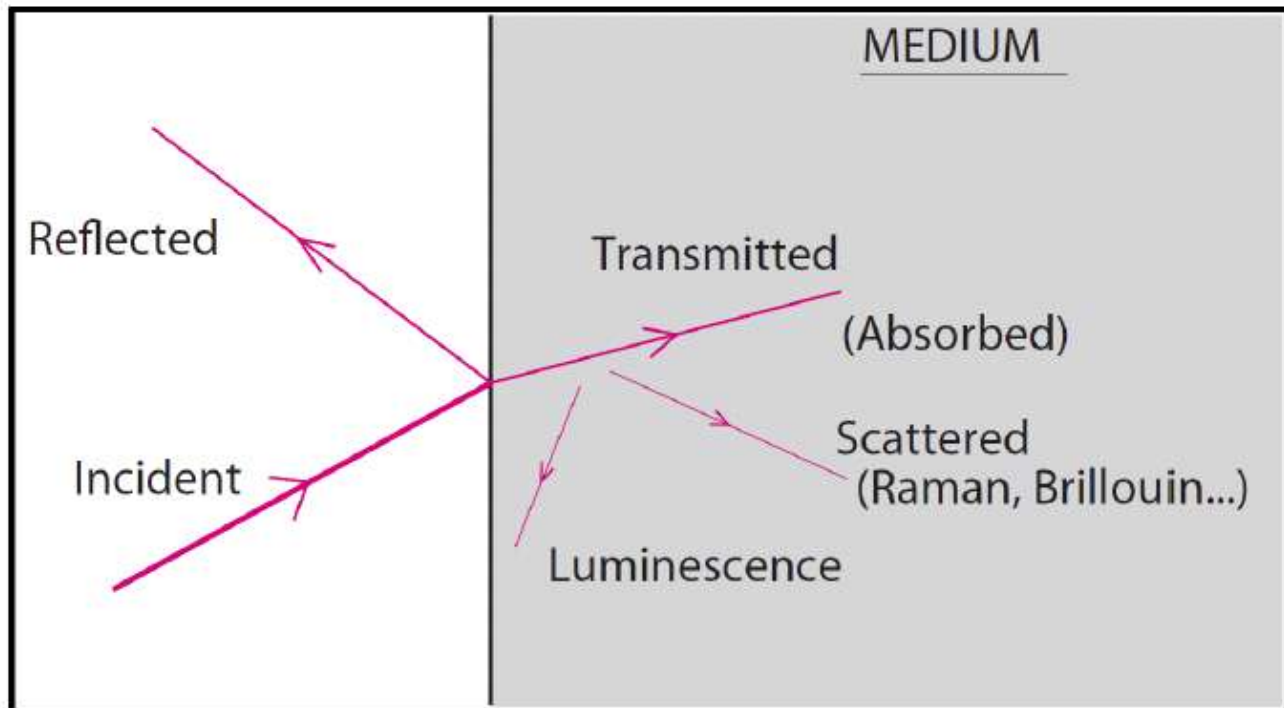
STM image of a **regular line defect in graphene** grown on Ni(111) substrate. The inset shows the structural model.

- graphene structure
- fabrication and CVD growth
- characterization: Raman spectroscopy

Examples

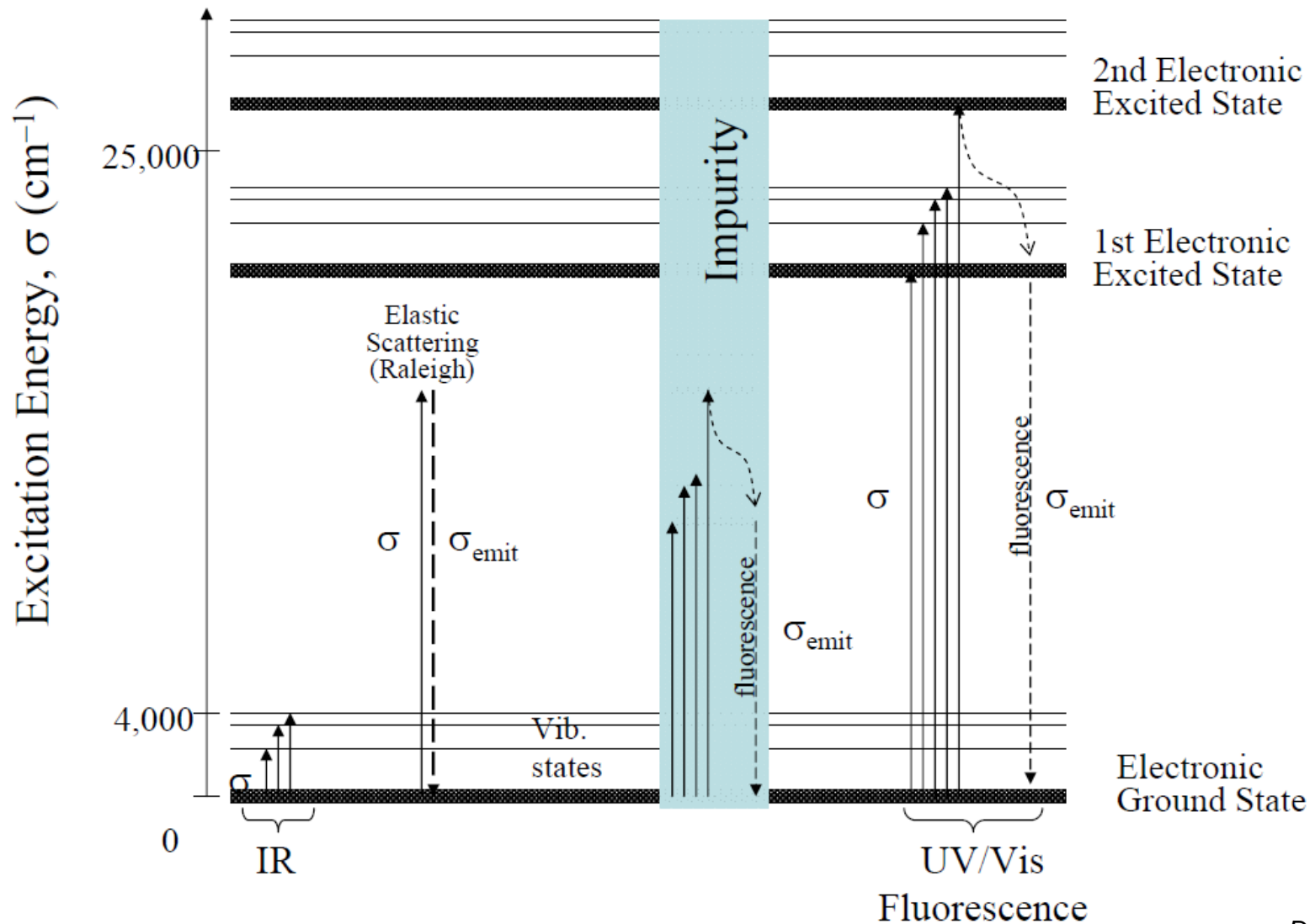
- graphene electroburning for molecular junctions
- Quantum Hall Effect

light matter interaction



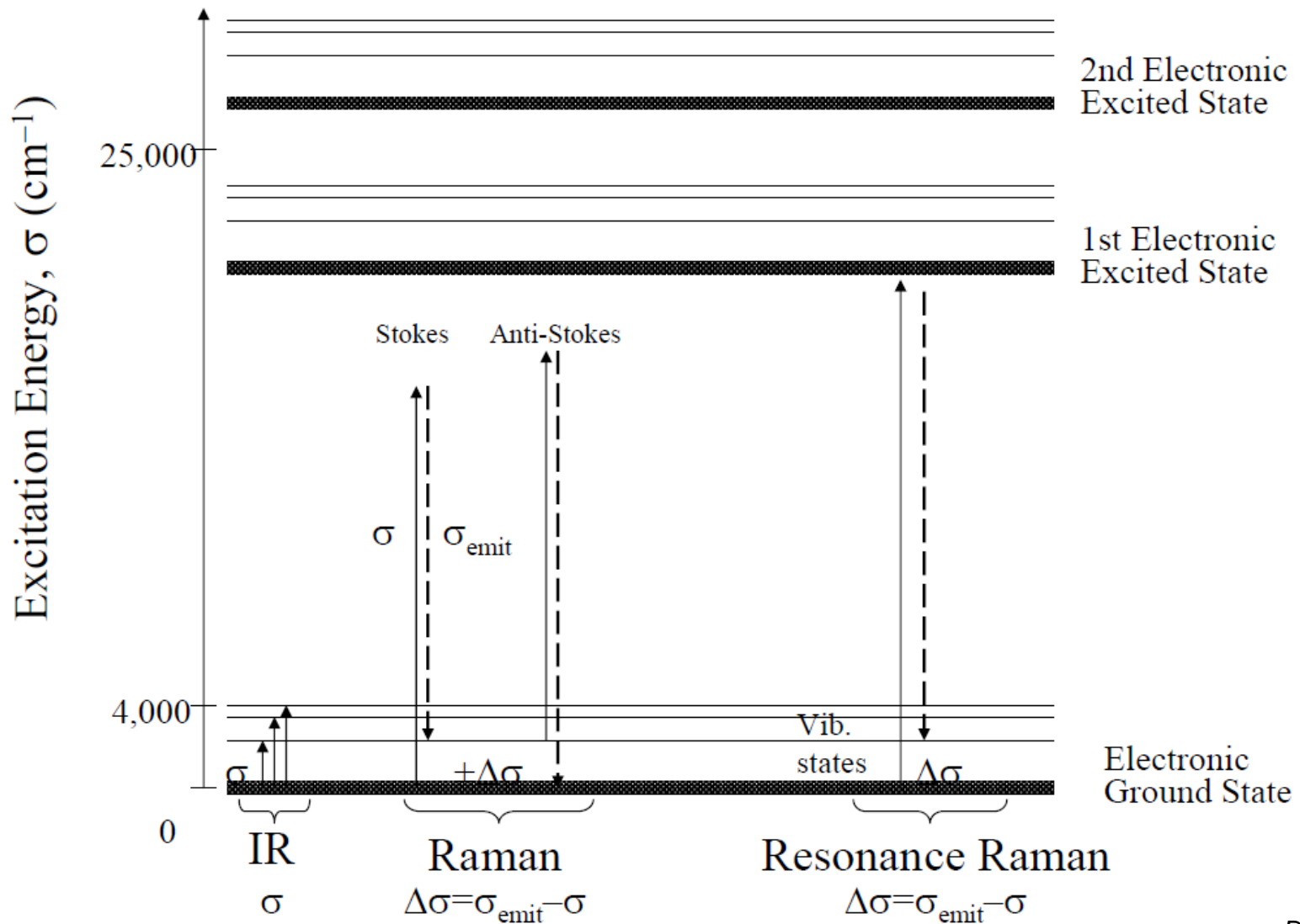
optical spectroscopy

Absorption, Scattering, and Fluorescence

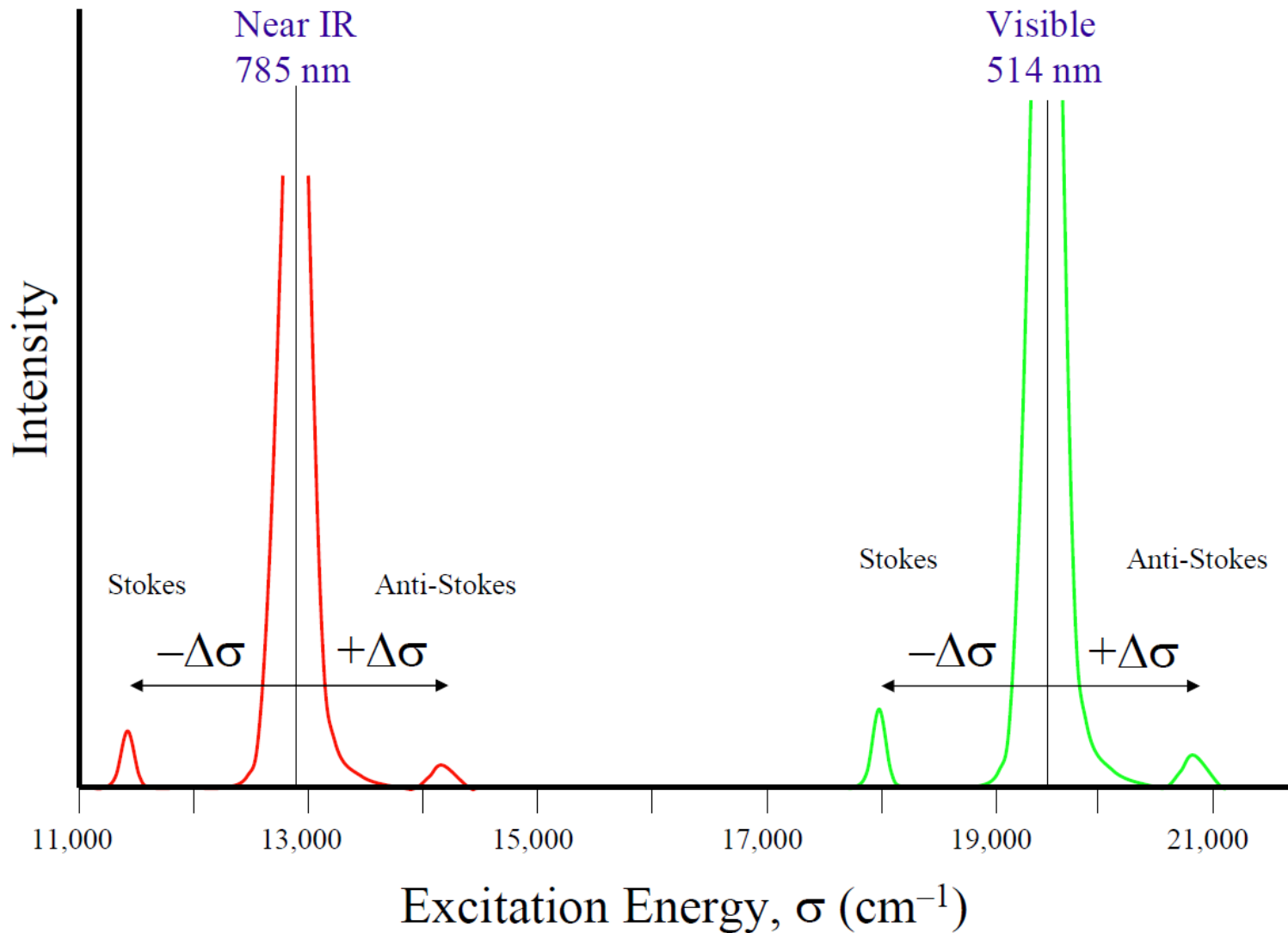


optical spectroscopy

Absorption, Scattering, and Fluorescence



Raman spectroscopy



Raman: Effect



incoming light:

$$\vec{E} = \vec{E}_0 \sin 2\pi\nu t$$

induced dipole moment (C·m):

$$\vec{\mu} = \alpha \vec{E} = \alpha \vec{E}_0 \sin 2\pi\nu t$$



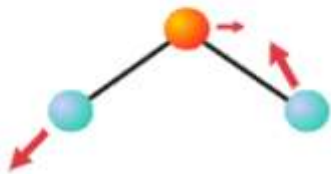
polarisability:
C · m²/V

$$\alpha = \alpha_0 + \beta \sin 2\pi\nu_v t$$

hence

$$\vec{\mu} = (\alpha_0 + \beta \sin 2\pi\nu_v t) \vec{E}_0 \sin 2\pi\nu t$$

ν_v : vibrational freq. of molecule



$$\vec{\mu} = \underbrace{\alpha_0 \vec{E}_0 \sin 2\pi\nu t}_{\text{Rayleigh}} - \frac{1}{2} \beta \vec{E}_0 \left[\underbrace{\cos 2\pi(\nu + \nu_v)t}_{\text{Anti-Stokes}} - \underbrace{\cos 2\pi(\nu - \nu_v)t}_{\text{Stokes}} \right]$$

IR & Raman: selection Rules

Raman active
IR active

requires α change upon vibrational motion
requires dipole change upon vibrational motion

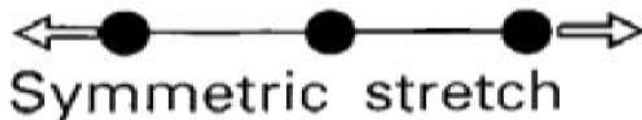
Raman inactive:
 $\beta \propto \frac{\delta\alpha}{\delta q_v} = 0$

CO₂ molecule

Raman

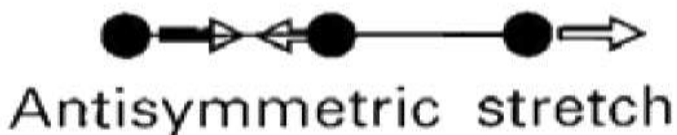
Infrared

no net dipole change



active

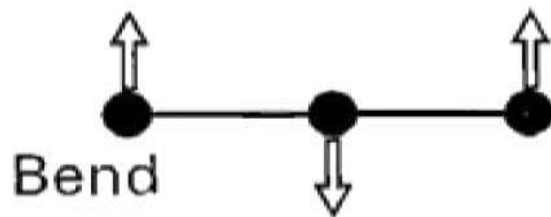
inactive



inactive

active

dipole change

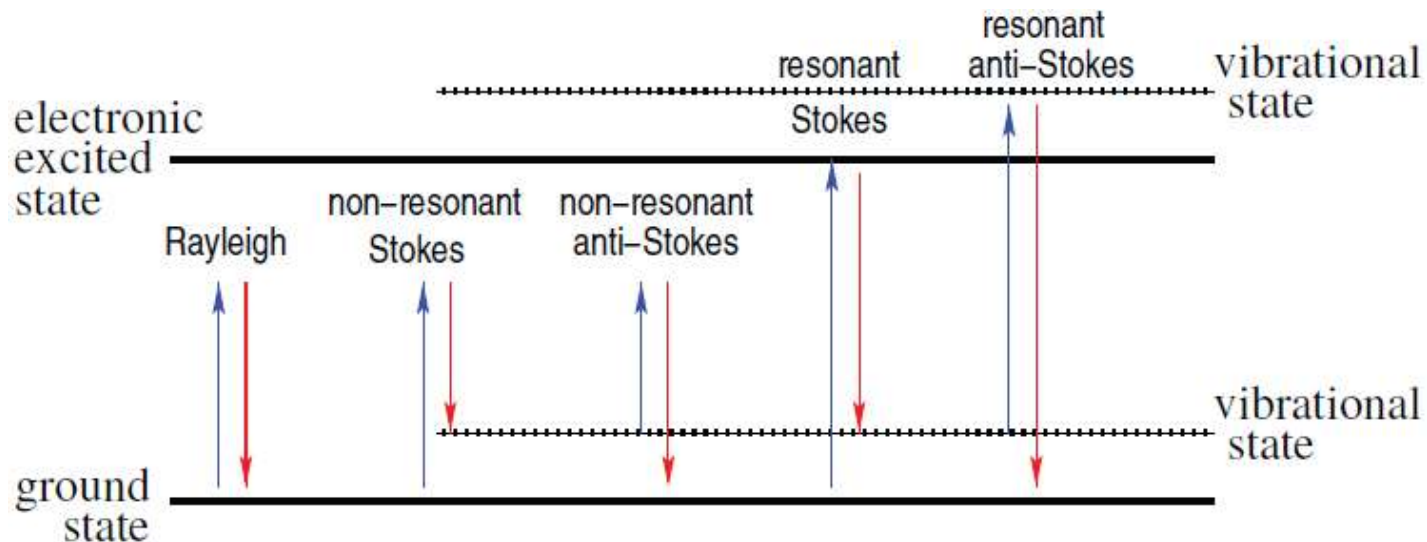


inactive

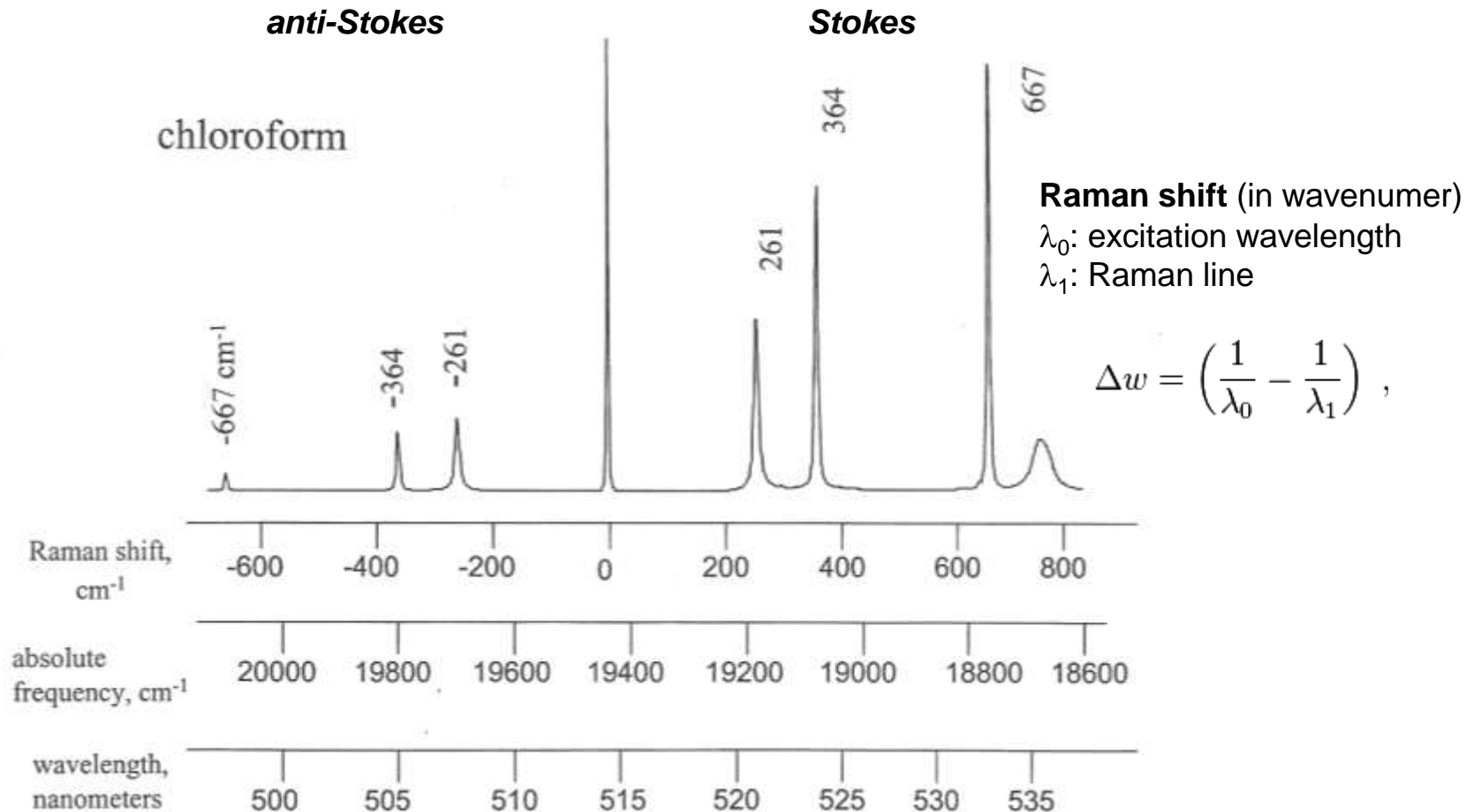
active

Raman spectroscopy

- Main drawback of Raman cross section 10^{-30} cm^2
- Compare
 - UV spectroscopy 10^{-18} cm^2
 - IR spectroscopy 10^{-20} cm^2
 - Fluorescence 10^{-18} cm^2
 - Rayleigh 10^{-26} cm^2
- Enhanced Raman:
 - Resonant Raman
 - Surface Enhanced Raman

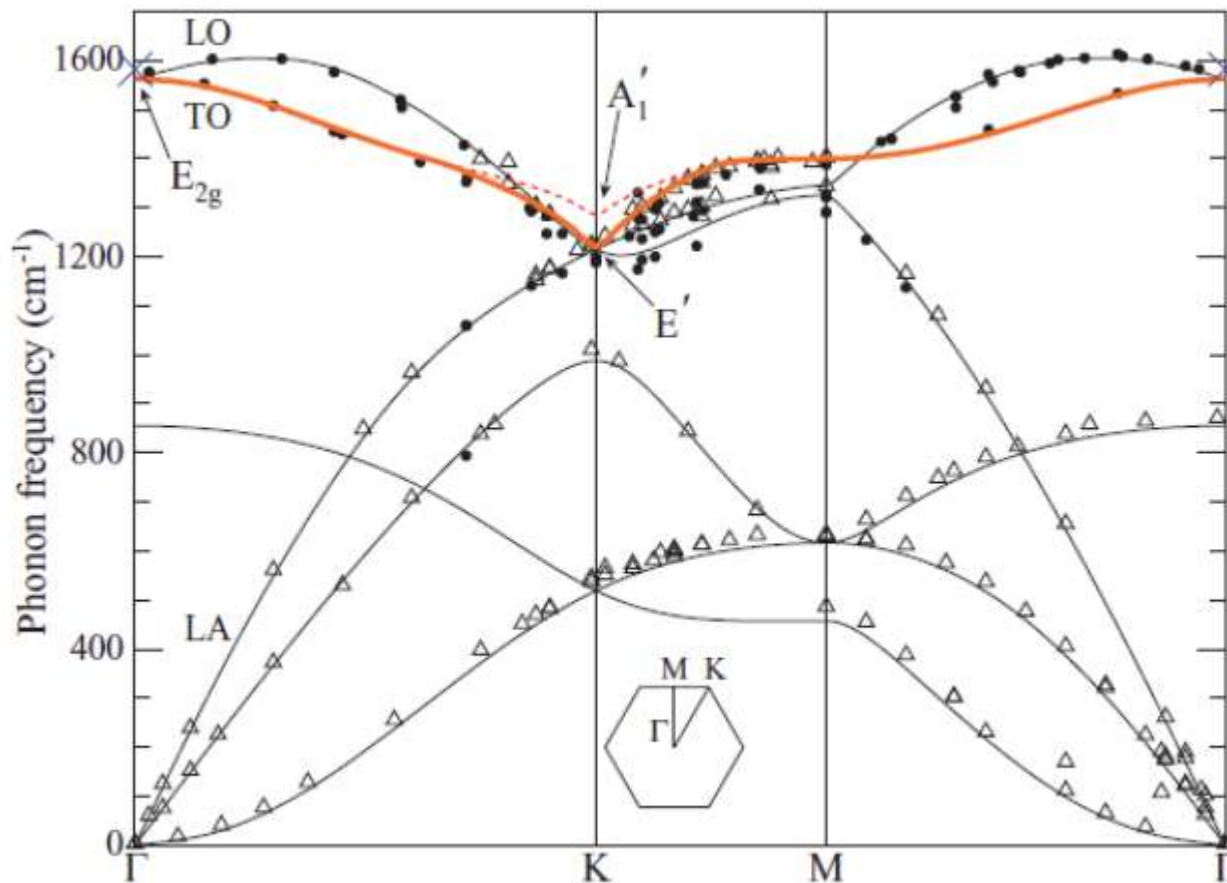


Raman example: chloroform



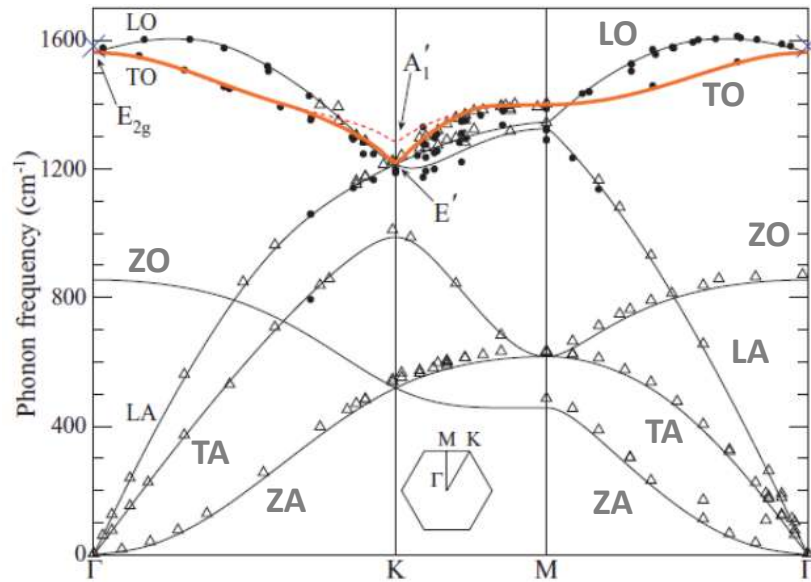
NB: only molecules that are vibrationally excited (phonon population) prior to irradiation can give rise to the anti-Stokes line \Rightarrow Stokes line more intense

graphene phonon dispersion

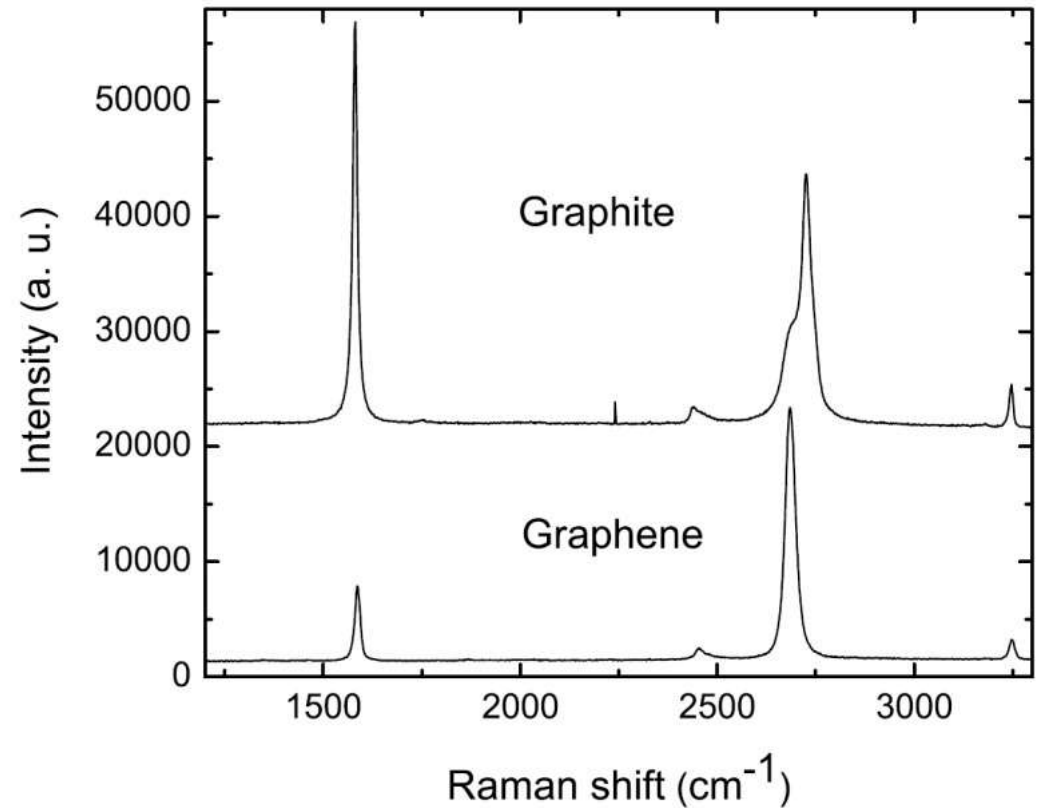


- 2 atoms per unit cell
- 6 phonon branches: 3 acoustic and 3 optical
- maximum frequency $\approx 1600 \text{cm}^{-1}$

Raman spectroscopy: graphene phonon dispersion

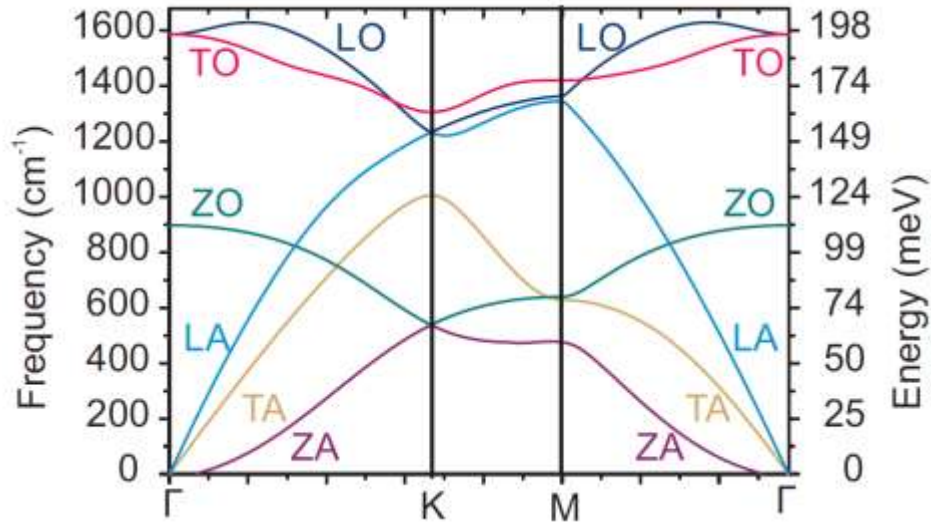


LA: Longitudinal acoustic
TA: Transverse acoustic
ZA: Out-of-plane acoustic

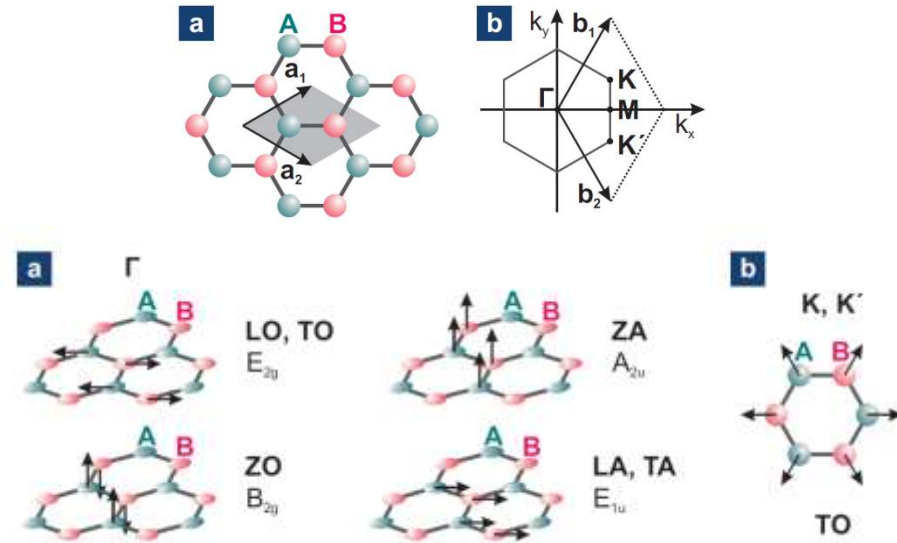


- more phonon frequencies than Raman lines
- Raman lines beyond 1600cm^{-1}
- no Raman lines below 1500cm^{-1}
no signal from acoustic phonons

graphene phonon dispersion & Raman



C. Nef, adapted from Yan et al., PRB (2008)

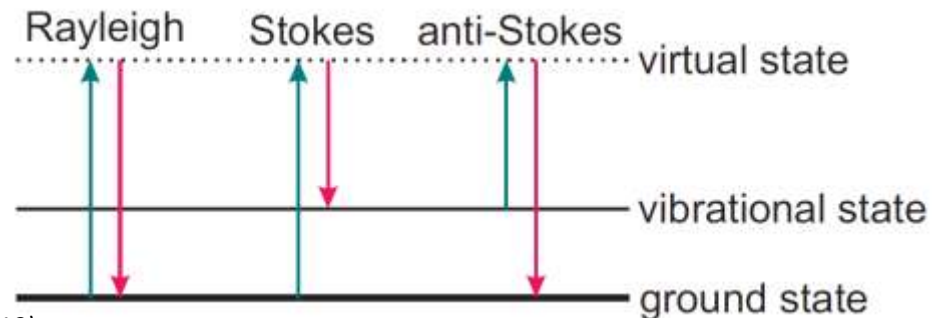


L: longitudinal; T: transverse; Z: out-of-plane
A: acoustic; O: optic

2 atoms per unit cell, 6 phonon branches

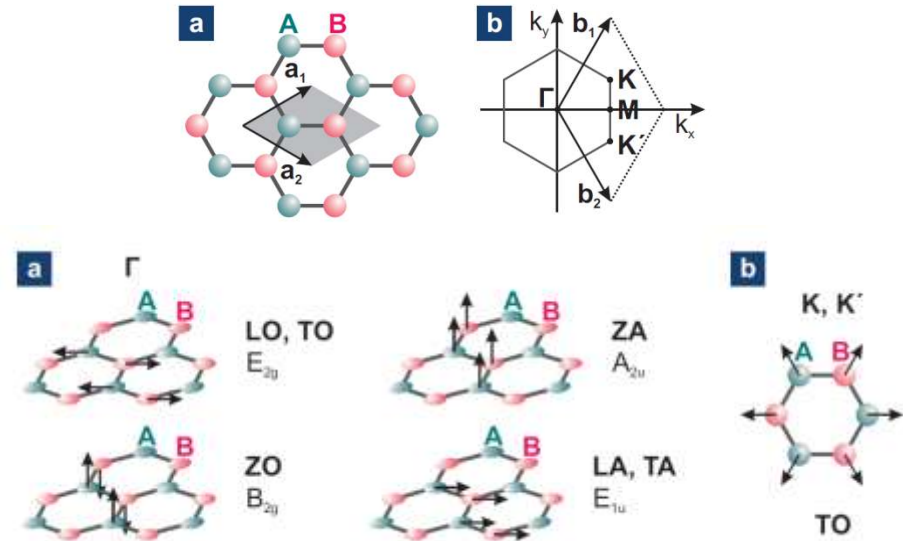
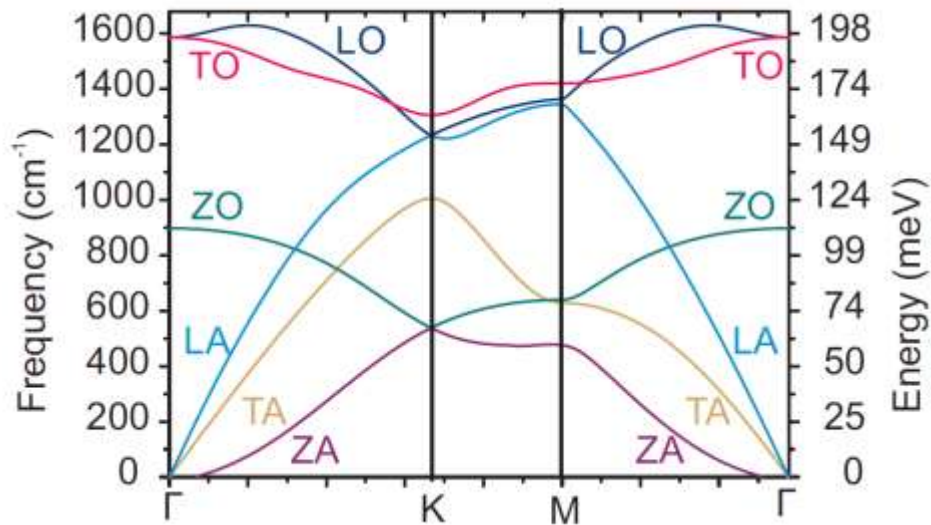
Raman spectroscopy

- inelastic light scattering
- for graphene, always resonant
gapless linear dispersion relation
- 1st order Raman near Γ point
 $k \approx 0$, momentum conservation



see e.g. Dresselhaus et al., Ann. Rev. Cond. Matt. Phys (2010)

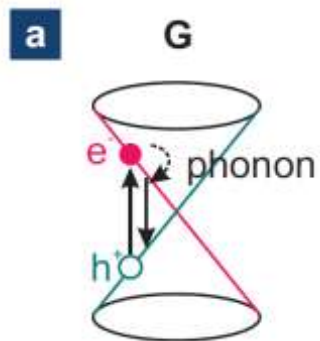
graphene Raman spectroscopy



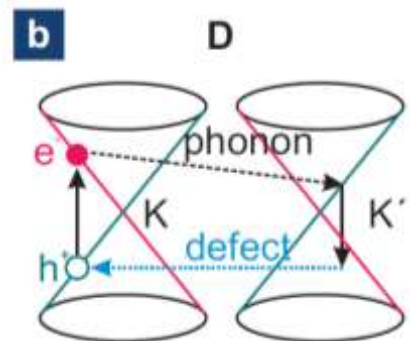
NB: amorphous C has no rings, hence no breathing mode/D band

Raman active modes in graphene

see e.g. Ferrari, Basko, Nat. Nano (2013)

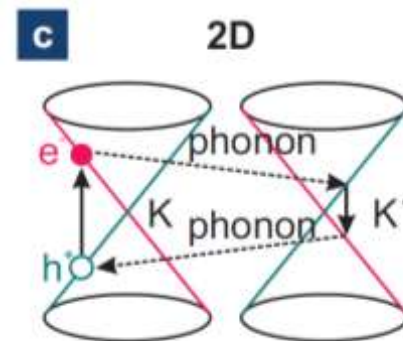


LO, TO modes
G-Band $\approx 1580 \text{ cm}^{-1}$
stretching of C-C bond



breathing mode (TO phonon at K point)
needs a defect/phonon activation
D-band $\approx 1350 \text{ cm}^{-1}$

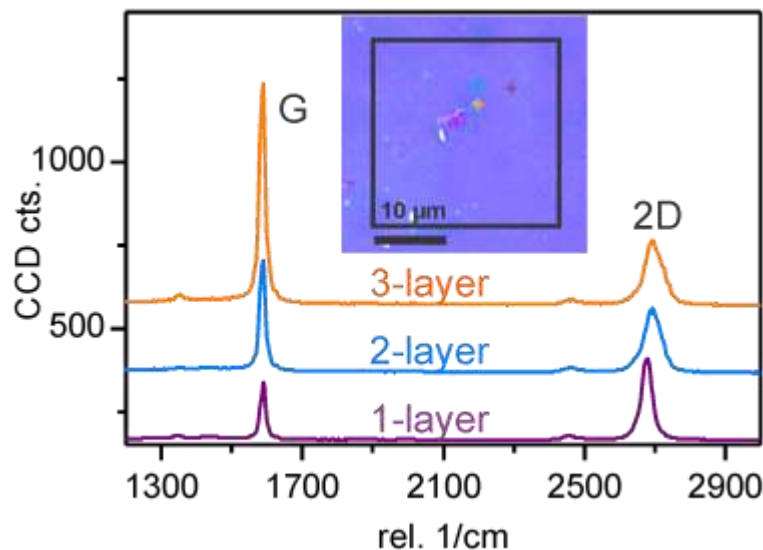
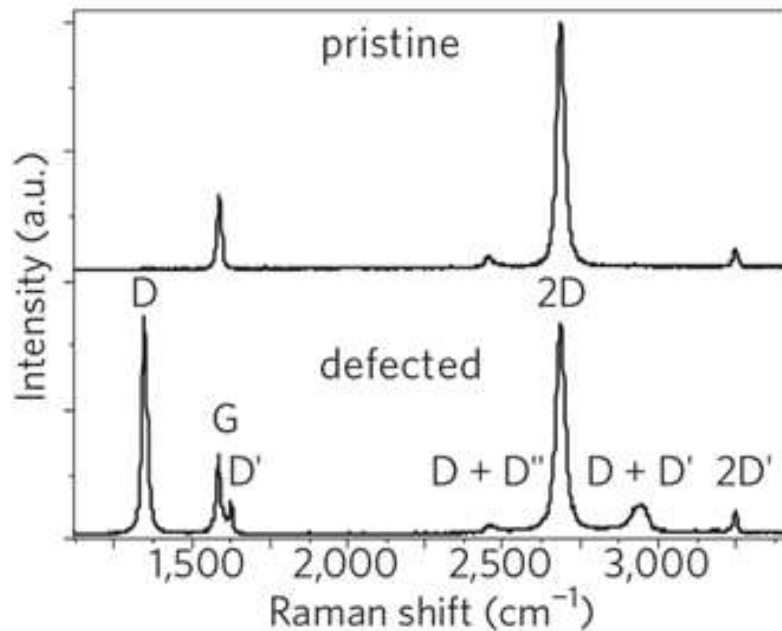
Intervalley
scattering on
defect



2-phonon scattering process of TO
breathing mode
2D-band $\approx 2700 \text{ cm}^{-1}$

Intervalley
two-phonon
process

graphene Raman spectroscopy



Additional contributions with lower intensity

- D'-band: $\approx 1620 \text{ cm}^{-1}$ LO phonons
- D''-band $\approx 1100 \text{ cm}^{-1}$ LA phonons
+ combination with D-band
- D, D' peak develop in presence of defects **D-band: defects**
- double-resonant overtones: 2D & 2D'
2 phonons processes
- positions of D, 2D peaks shifts to higher wavenumber for increasing laser energy
- 2D/G band ratio gives an idea over the number of layers

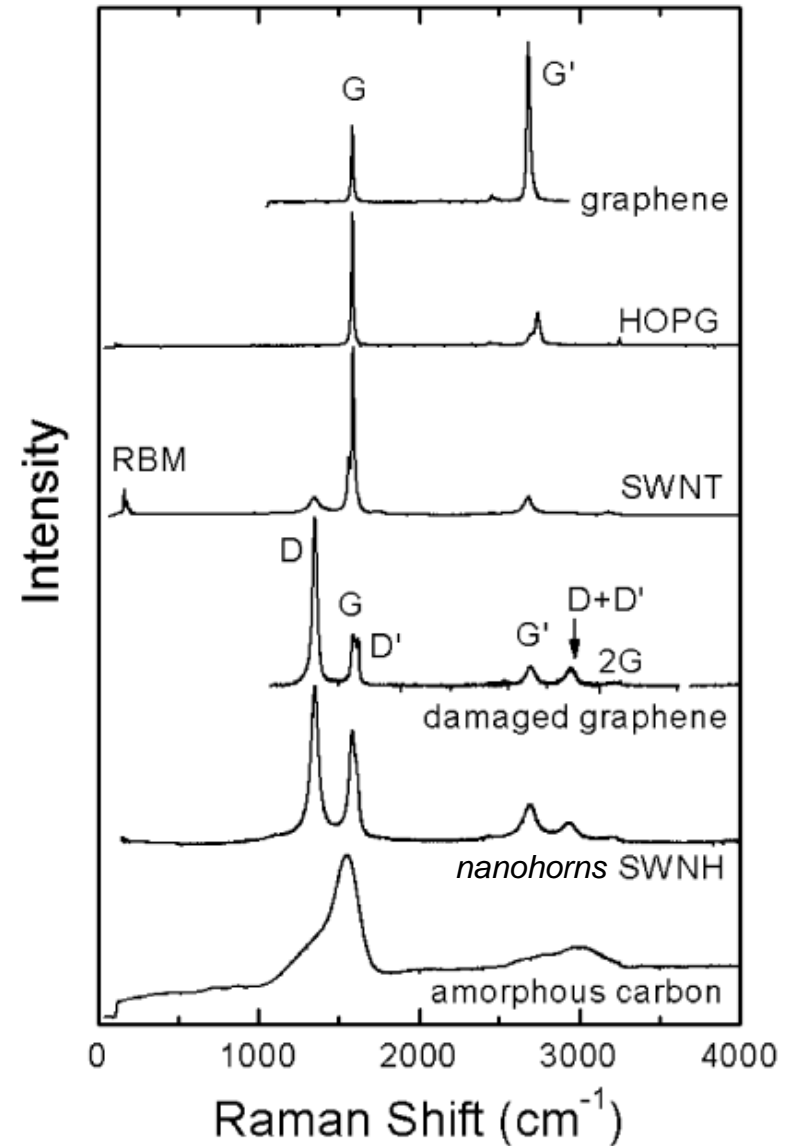
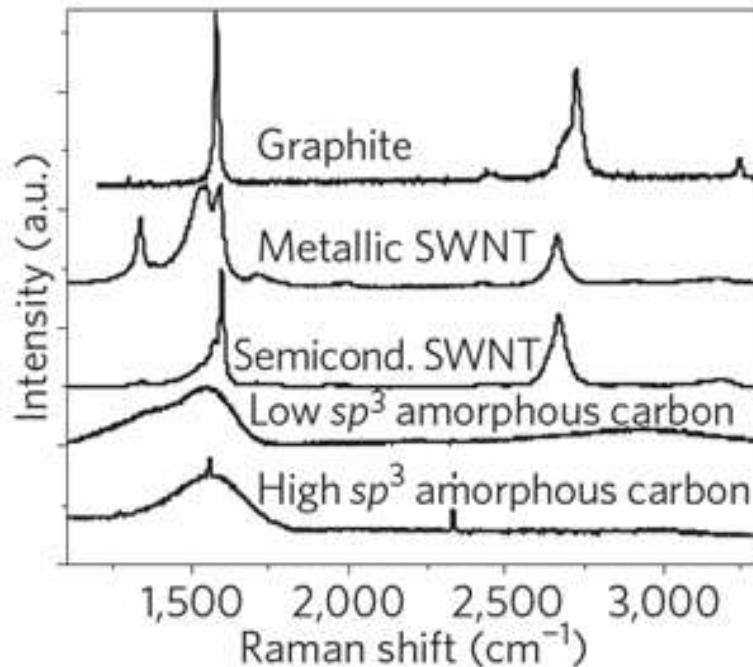
C. Nef, M. El Abbassi, K. Thodkar et al.

Malard et al., Phys. Rep. (2009)
Ferrari & Basko, Nat. Nano. (2013)

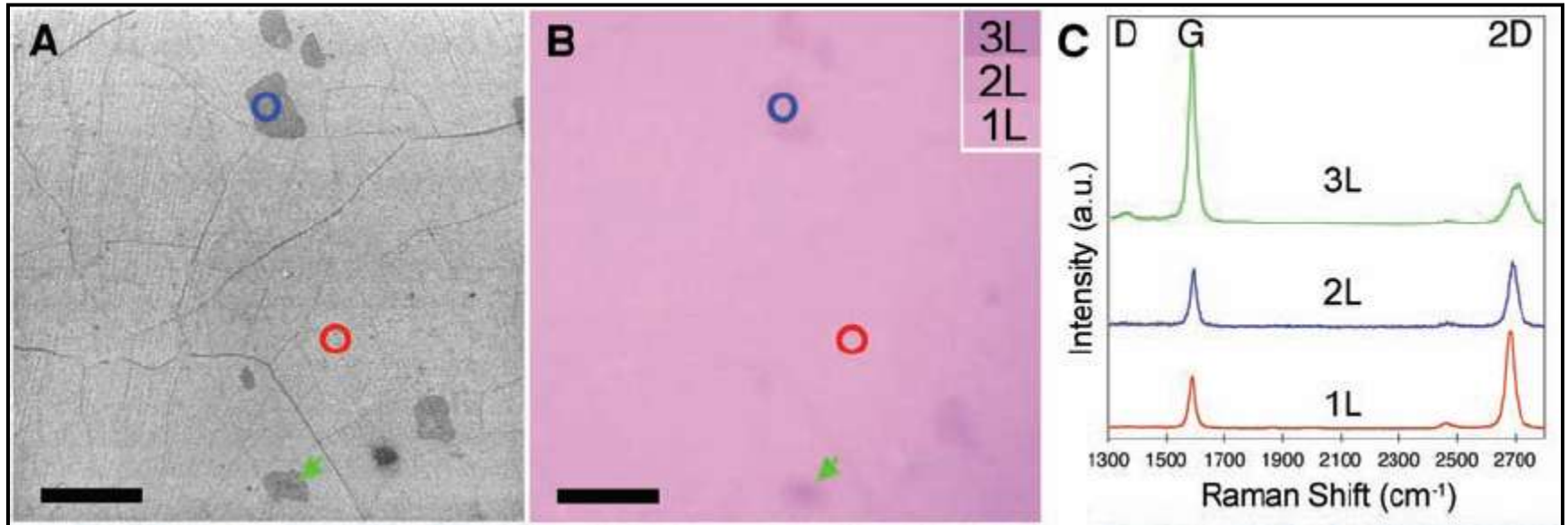
graphene Raman spectroscopy

Raman spectra for different types of sp² nanocarbons and carbon allotropes

- **G band:** C-C bond stretching, common to all sp² carbon materials
- sensitive to strain, curvature (CNTs)

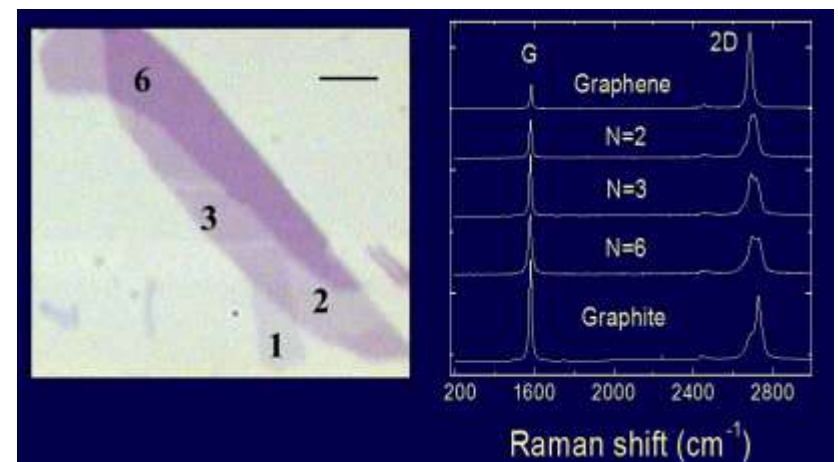


Raman spectra



X. Li, R. S. Ruoff et al., *Science* **2009**, 324, 1312-1314

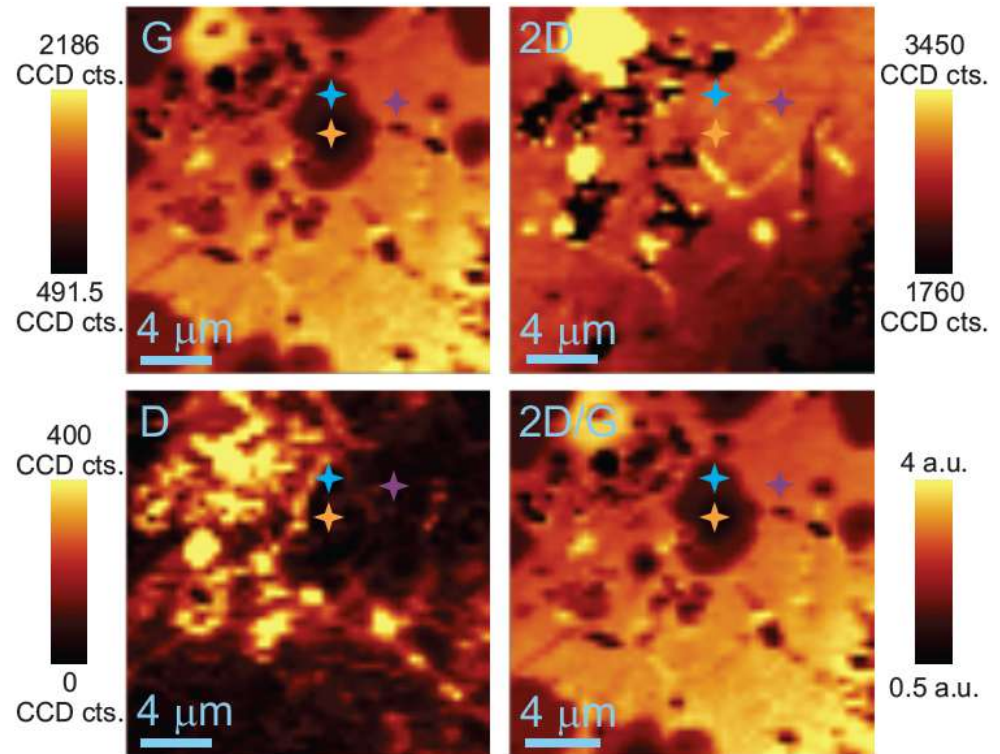
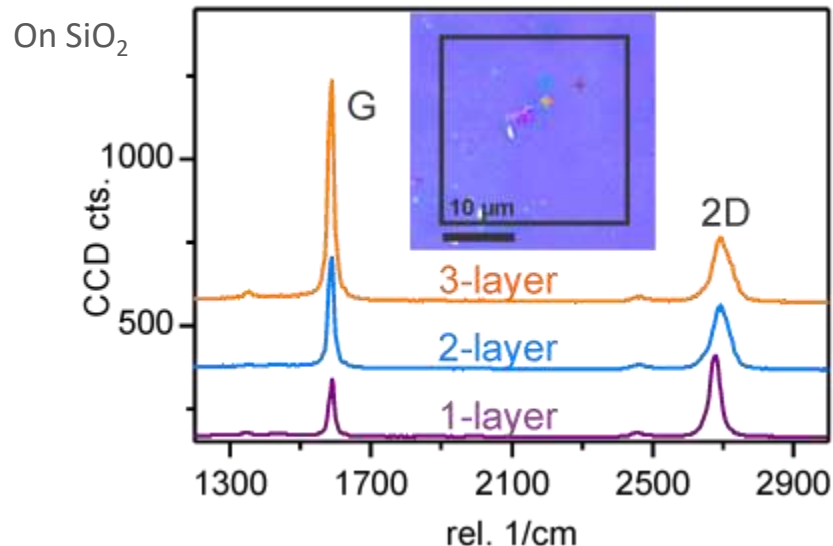
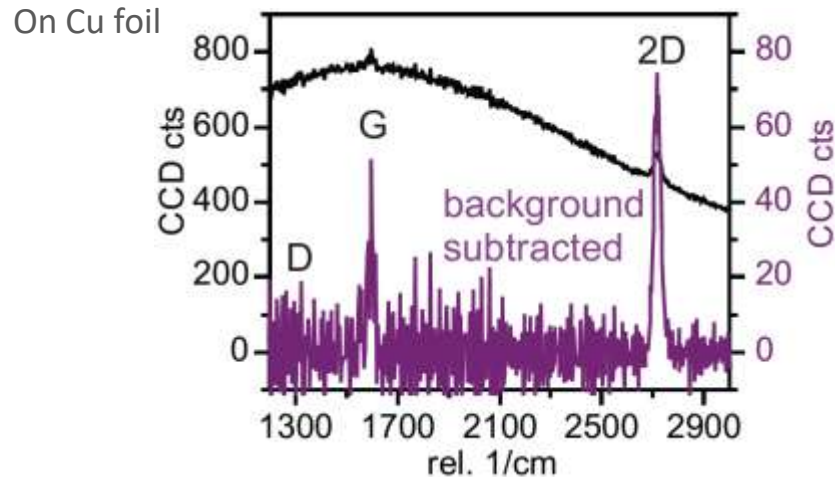
- Ratio between G and 2D bands is an (indicative) measure for the number of layers
a change in the electronic structure (multiple layers) leads to a change in resonance condition



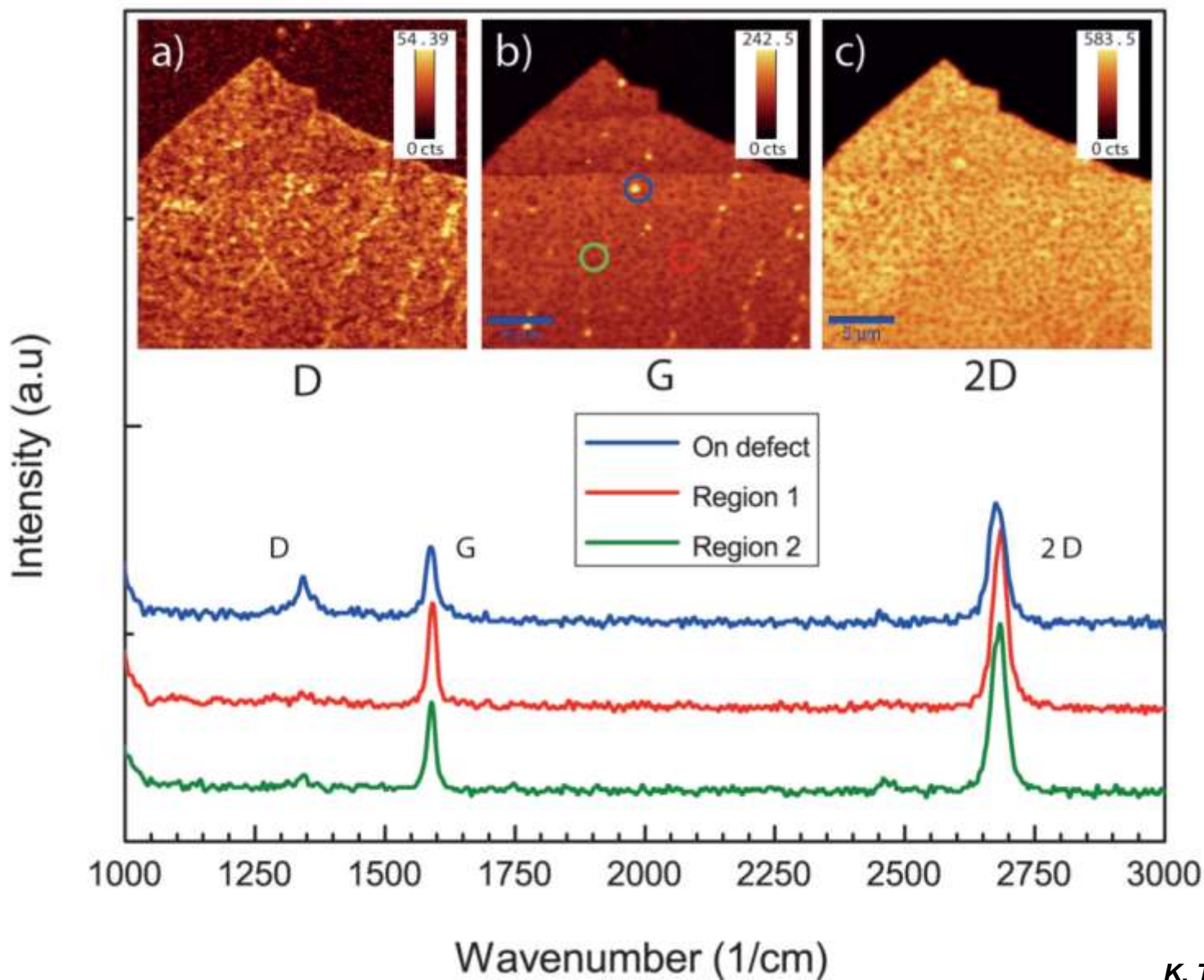
Casiraghi (2008)

Raman spectroscopy: our graphene

- D-band is a measure of defects and edges
- 2D/G band ratio gives an idea over the number of layers



Raman maps for large domains CVD graphene



scale bar
5 μm

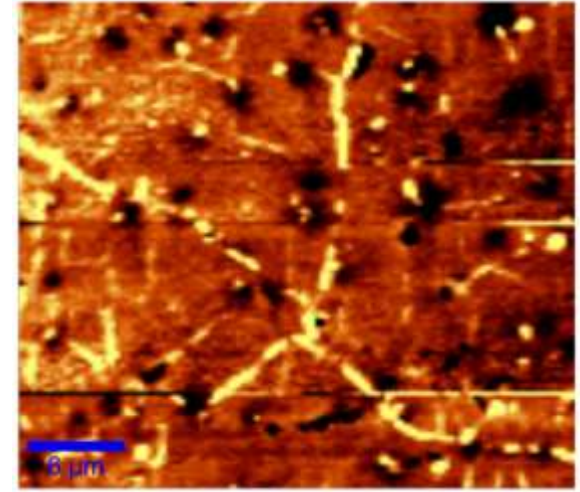
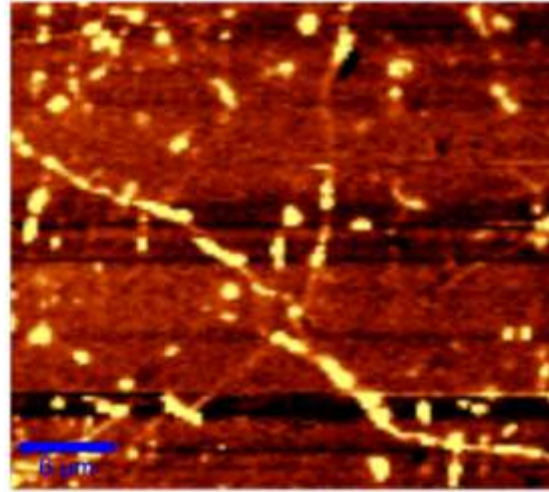
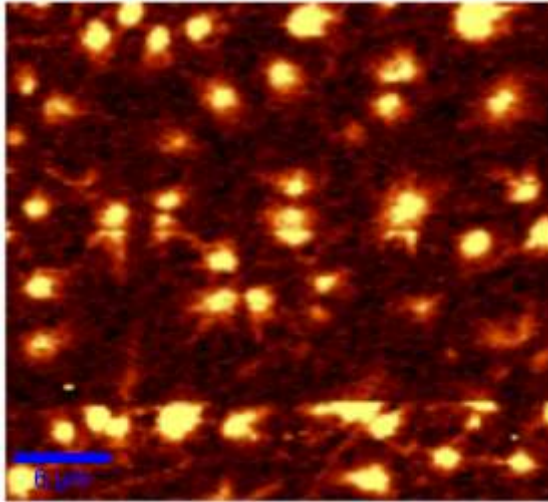
Raman maps for small & large domains CVD graphene

D

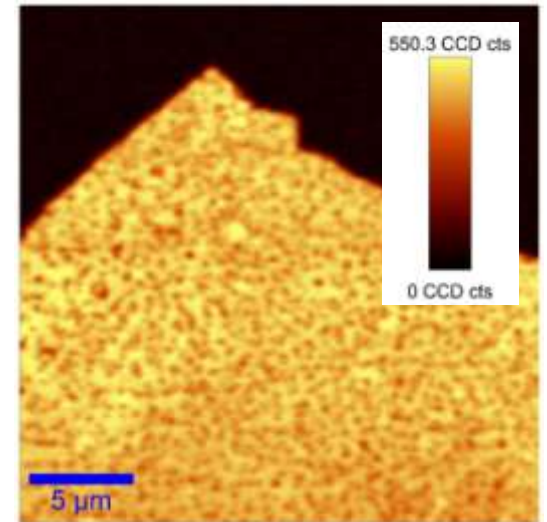
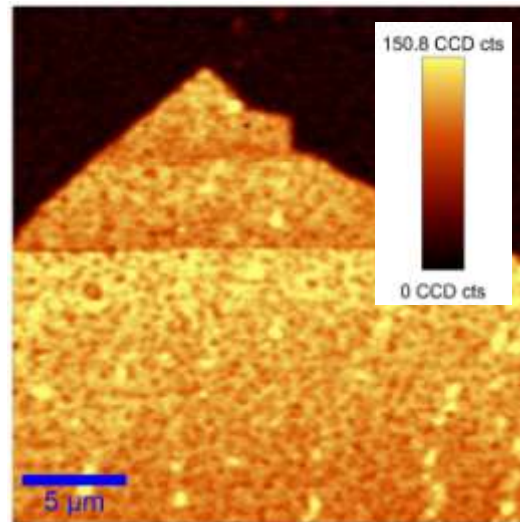
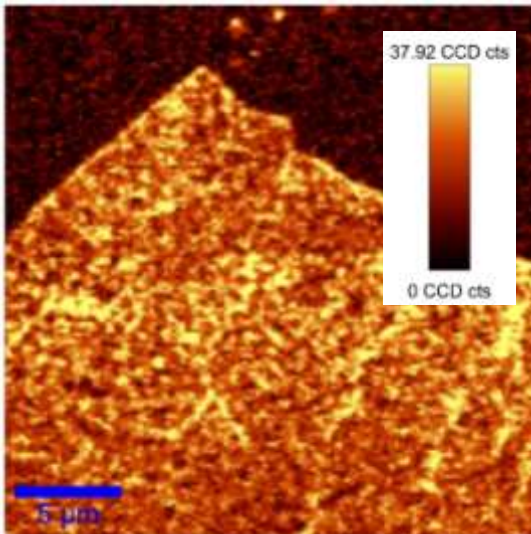
G

2D

Small grain



Large grain



⇒ homogeneous, low-defects large domains

K. Thodkar et al.

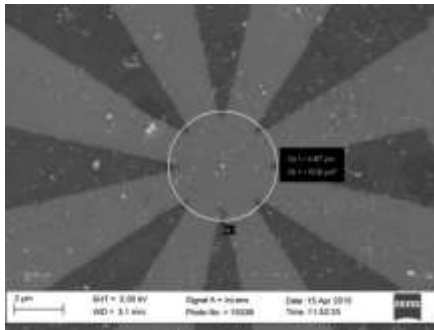
- graphene structure
- fabrication and CVD growth
- characterization: Raman spectroscopy

Examples

- graphene electroburning for molecular junctions
- Quantum Hall Effect

graphene patterning

e-beam & etch *A. Vadyka et al.*



direct writing: scanning probe (AFM, thermal AFM)

Machida et al., 2015; Stampfer, Ensslin et al.

e-beam induced etching

Geller et al., Sci. Rep. 2015

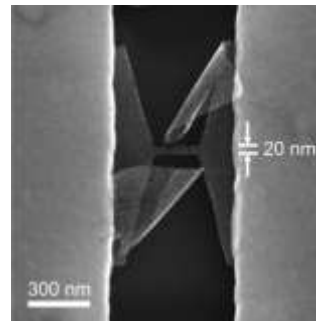
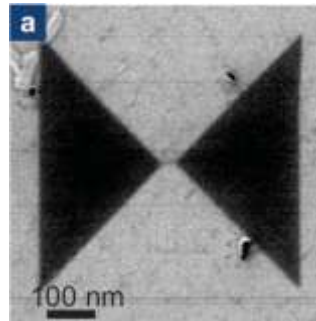
optical pulses

Lacerda et al., APL 2015

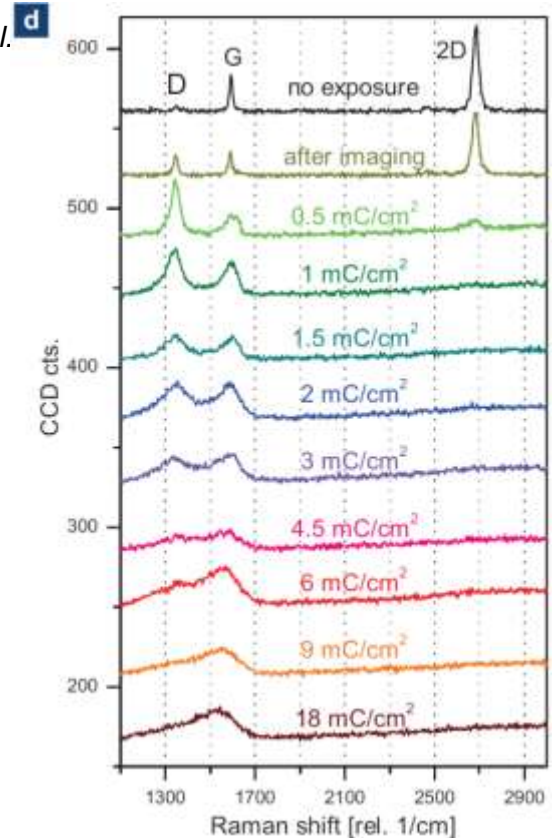
wish list

- resist-free (avoid local doping)
- no additional defects or doping (implantation) induced by patterning
- controlled edges
- upscalable
- ...

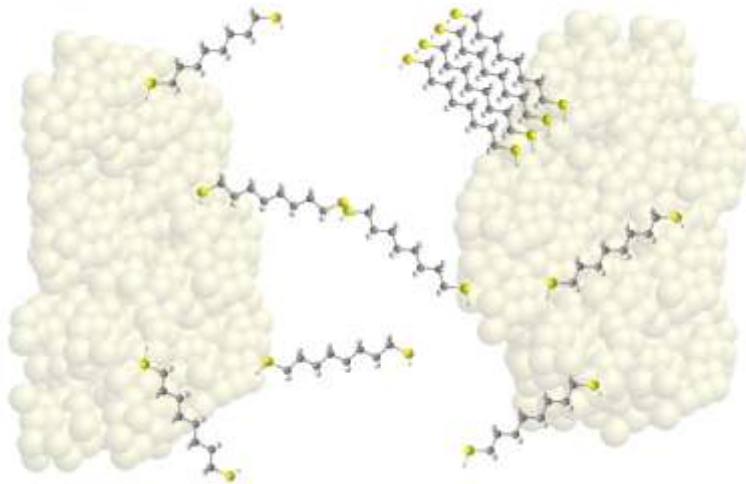
direct writing: He FIB *C. Nef et al.*



Geller et al., Sci. Rep. 2015



Molecular and carbon-based electronic systems



*drifting molecules,
stochastic anchoring,
clustering*

⇒

*undefined junction
geometry &
conductance*

*drifting surface
atoms, metal
protrusions*

⇒

*undefined
electrostatic
landscape*

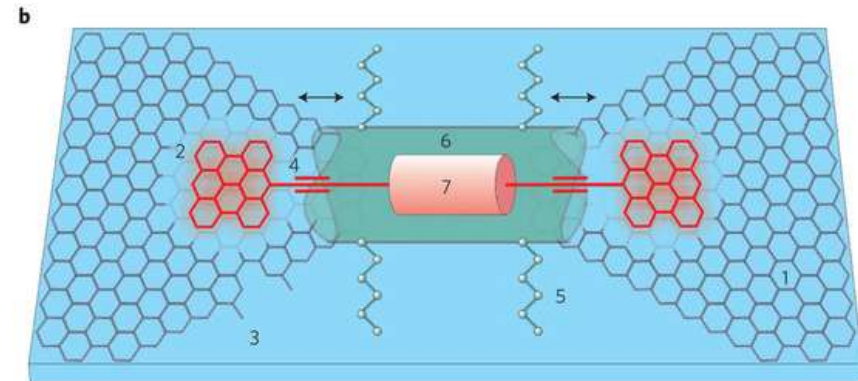
⇒ **variability, low-yield and lack of control in
key electrical parameters**

Carbon-based contact materials as electrodes:

FLG	vd Zandt et al., Nano Lett. 2011
SWNT	Krupke et al., Nat. Nanotech. 2010
C-fiber tips	Agrait et al., Nanoscale Res. Lett. 2012

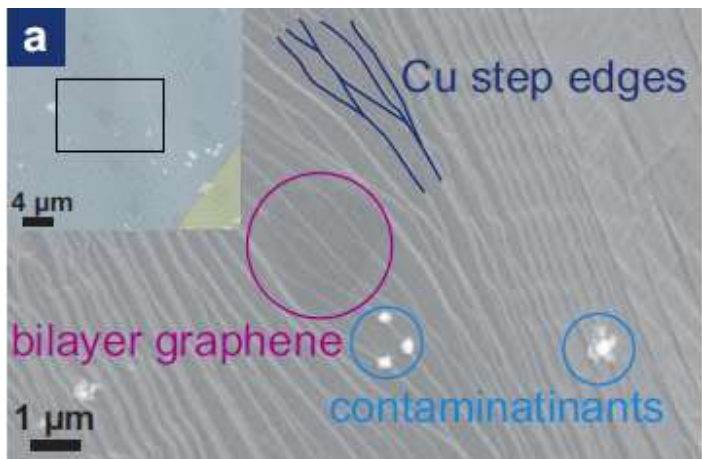
⇒ **monolayer graphene ...?**

paradigm shift for molecular electronics



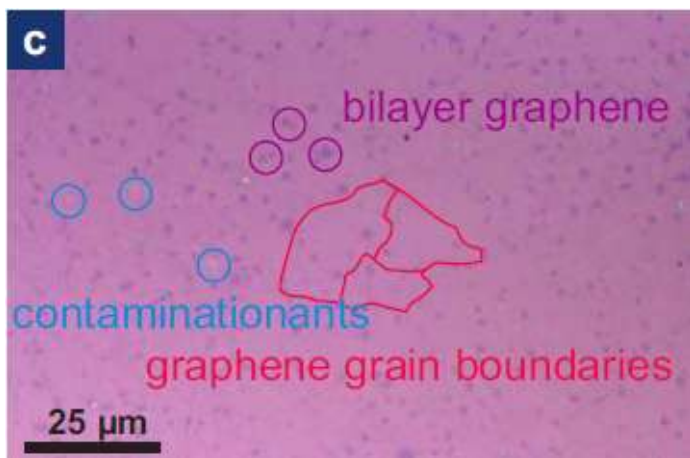
Lörtscher, Nat. Nano 2013

transfer & optical characterization



**CVD
growth**

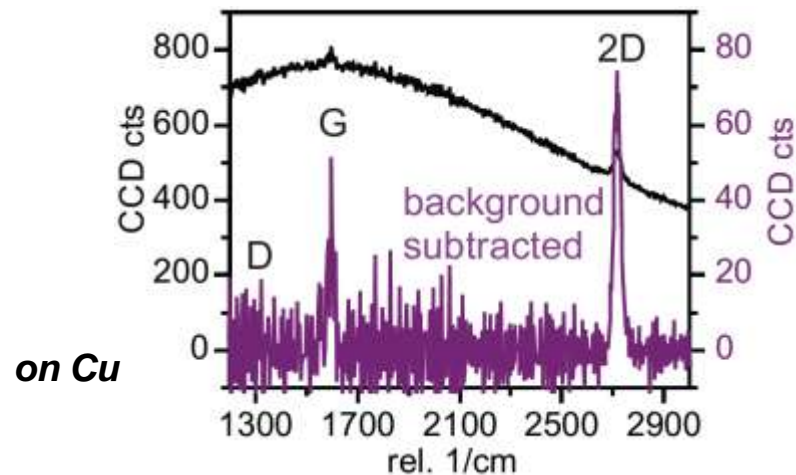
SEM after growth on Cu (LPCVD, CH₄, ~1000°C)



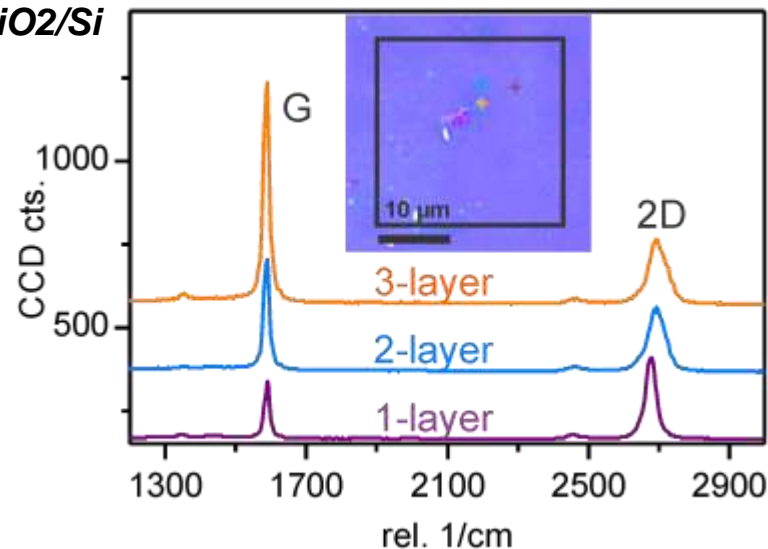
transfer

Optical image after transfer on SiO₂/Si

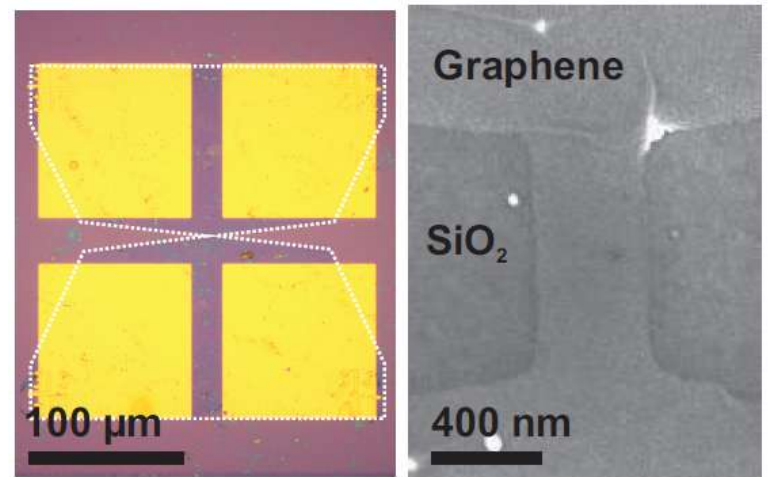
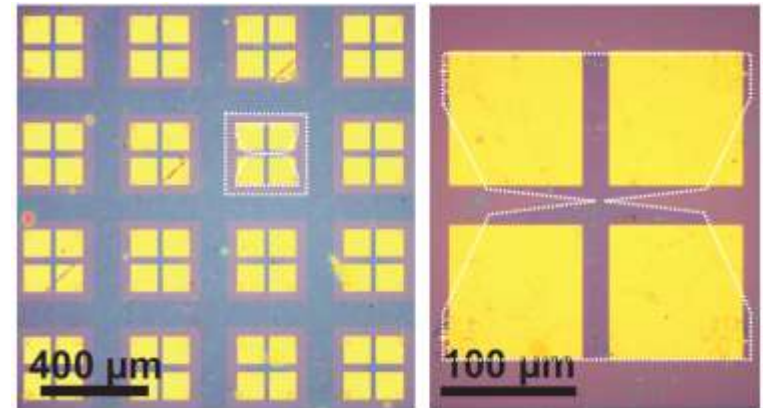
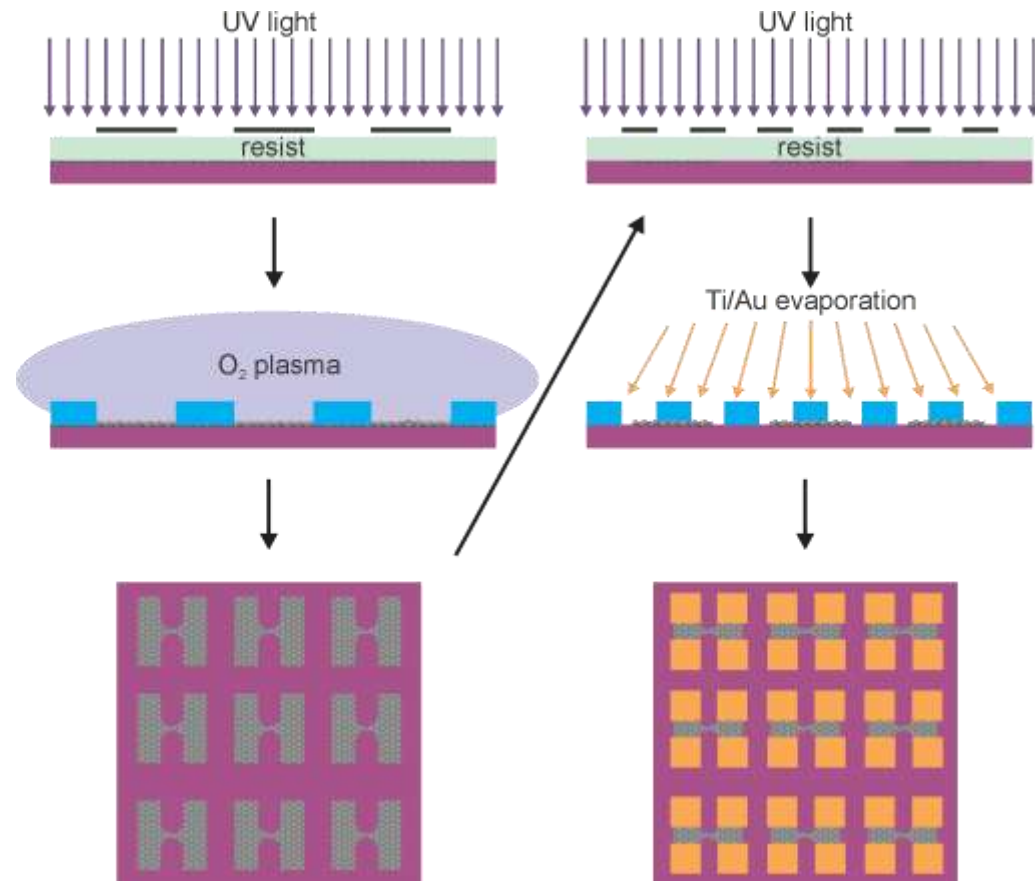
Raman spectroscopy



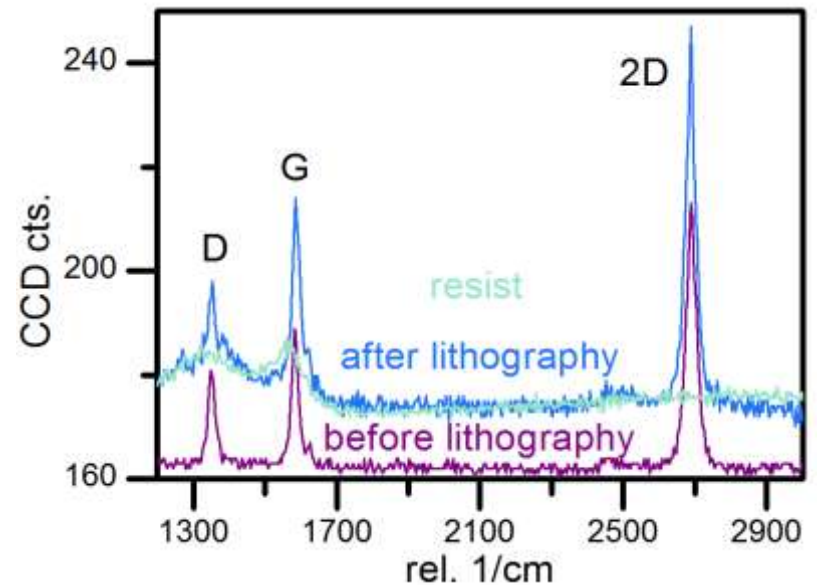
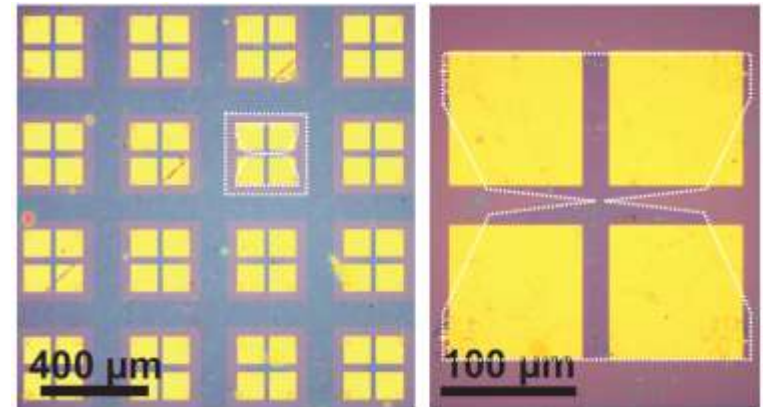
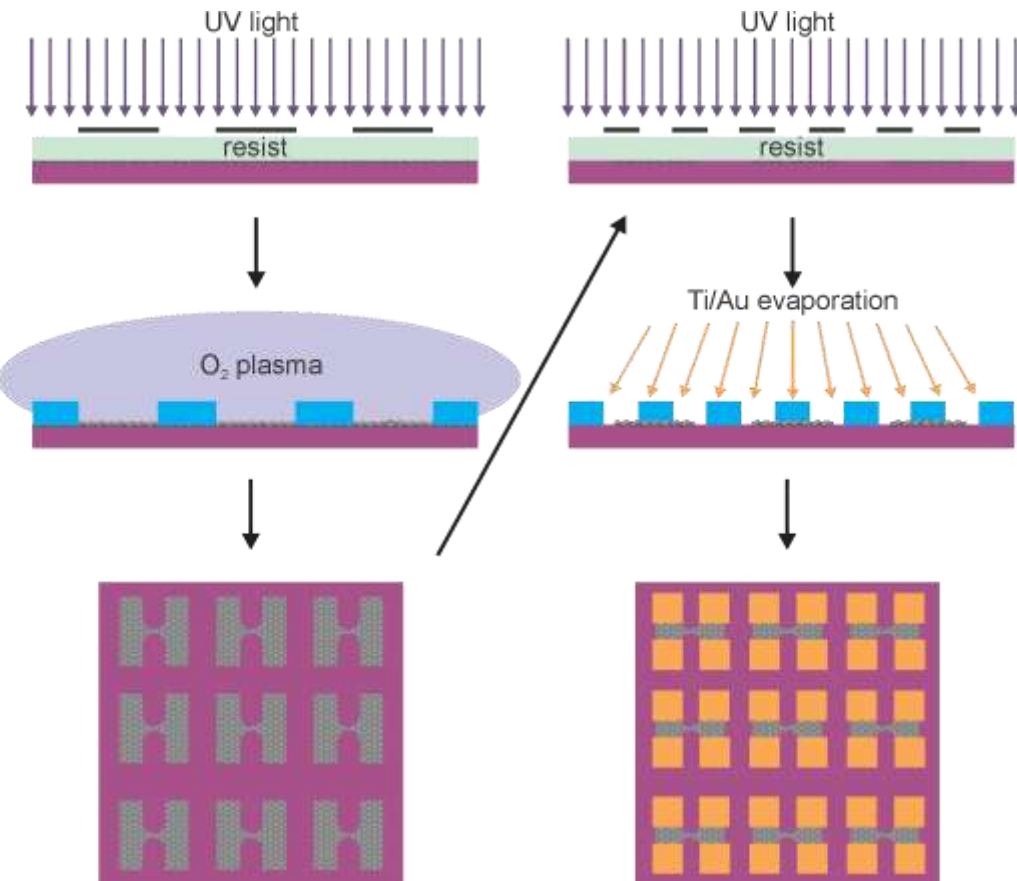
on SiO₂/Si



Sample fabrication



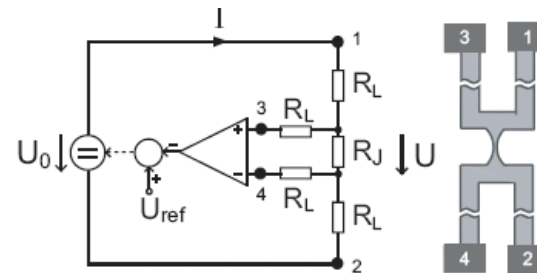
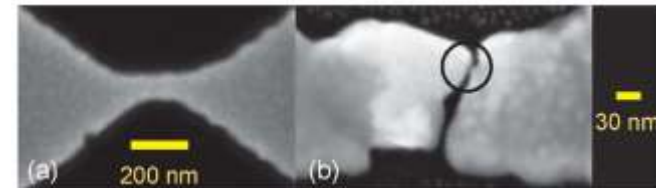
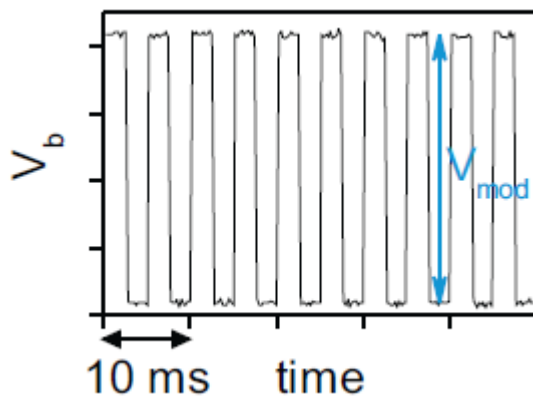
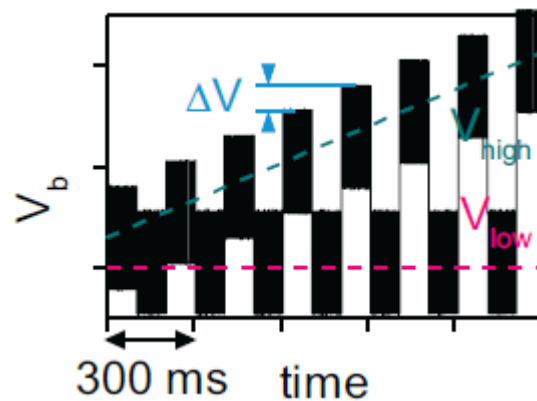
Sample fabrication



electroburning process

Applied voltage

similar approach as *electromigration* in metal contacts



Z.-M. Wu et al., APL (2007); PRB (2008)

graphene

FLG: Prins et al., *Nano Lett.* 2011

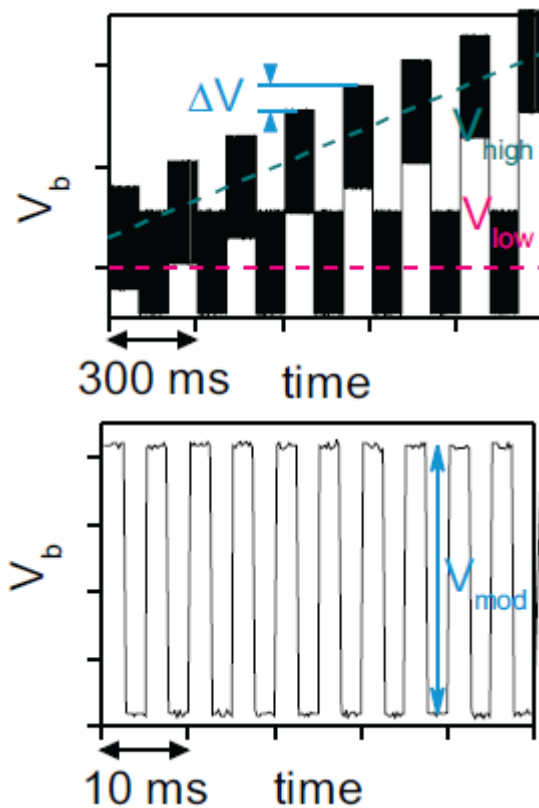
MLG: Nef, Posa et al., *Nanoscale* 2014

Lau et al., *PCCP* 2014

electroburning process

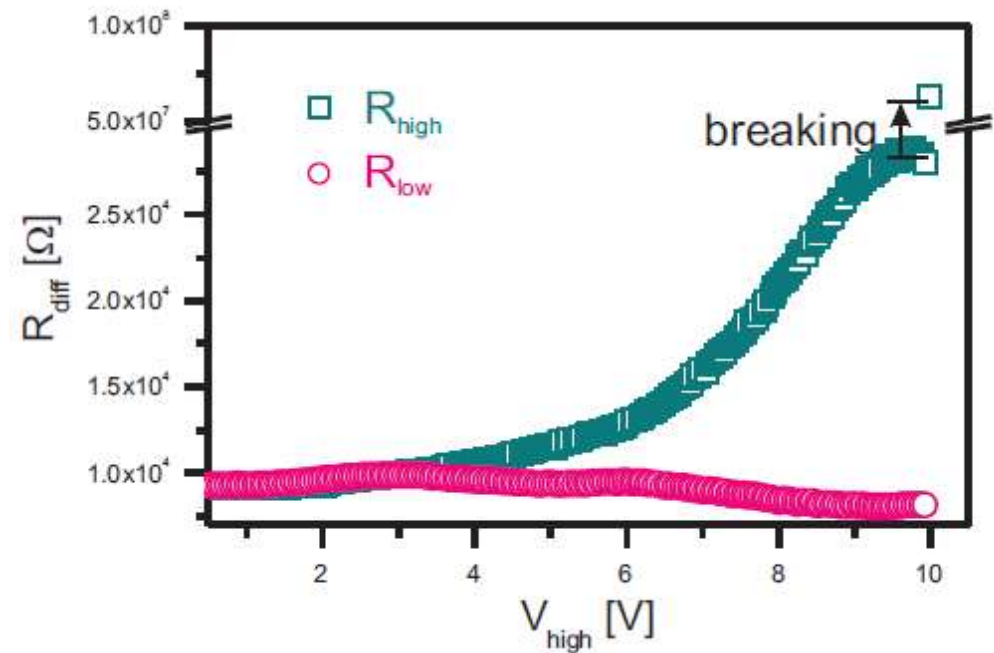
Applied voltage

similar approach as electromigration in metal contacts



Differential resistance

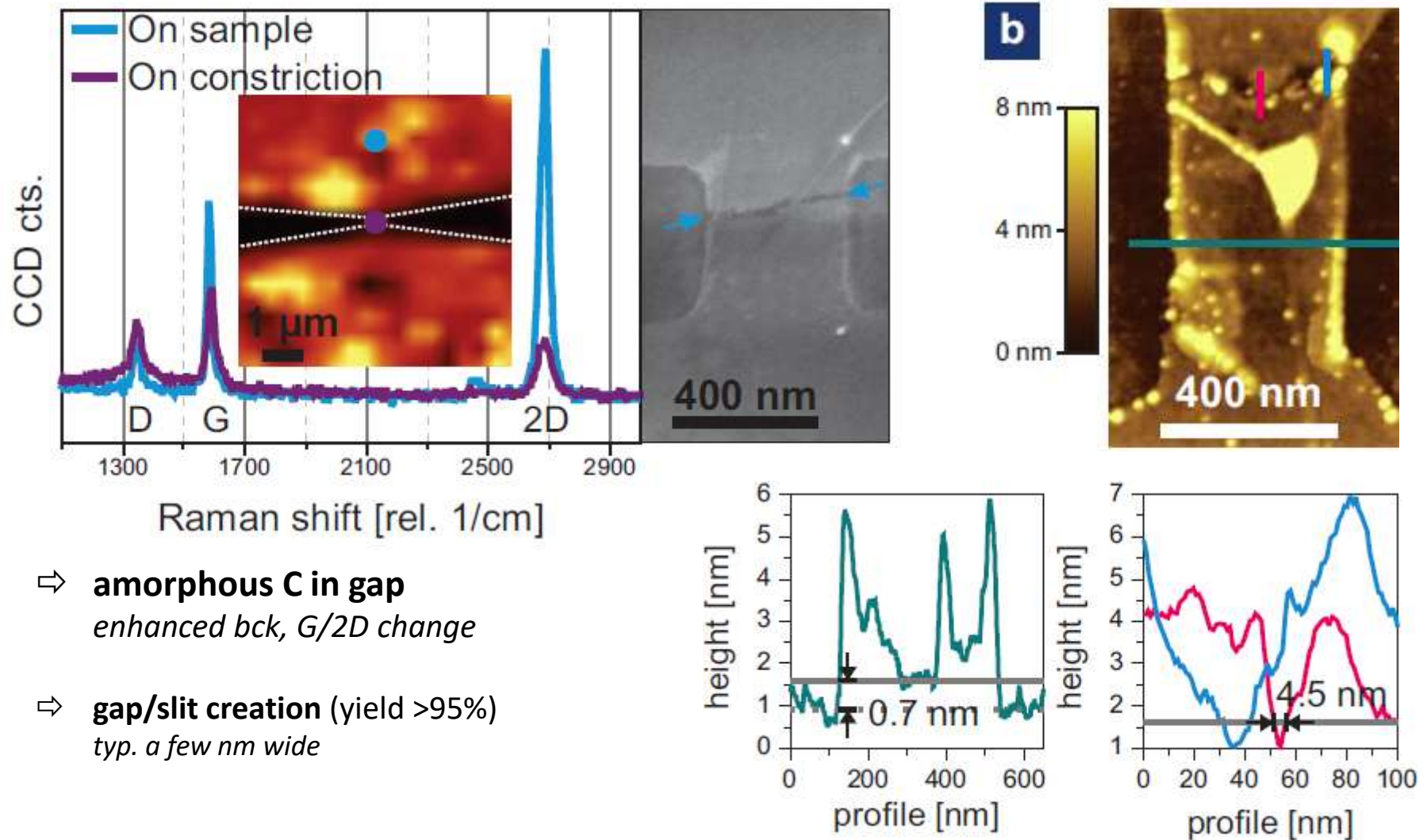
$R = \Delta I / V_{mod}$, at high and low bias vs time



- Joule heating seen as a difference between R_{high} and R_{low}
 - Junction breaks after a certain V_b is reached

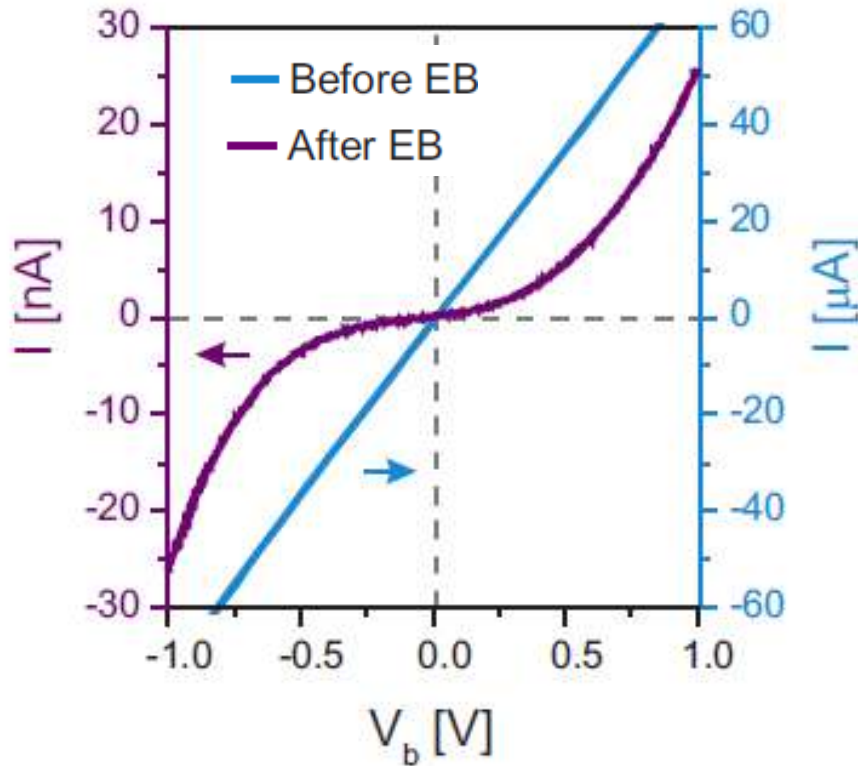
NB: EB performed on annealed devices

nanoscale gaps in graphene



- ⇒ **amorphous C in gap**
enhanced bck, G/2D change
- ⇒ **gap/slit creation** (yield >95%)
typ. a few nm wide

nanoscale gaps in graphene: tunneling behavior



- A and Φ are not robust, but d changes by max 50%
- fitting of junctions with lower R leads not to a shorter d , but a lower Φ

Gap width estimates (Simmons fitting)

$$\Rightarrow 0.3\text{nm} \leq d \leq 2.2\text{nm}$$

$$I = Ac_1 \left(\frac{\Phi - eV}{2} e^{-c_2 \sqrt{\frac{\Phi - eV}{2}}} - \frac{\Phi + eV}{2} e^{-c_2 \sqrt{\frac{\Phi + eV}{2}}} \right)$$

$$c_1 = \frac{e}{2\pi h d^2}; \quad c_2 = \frac{4\pi d}{h} \sqrt{2m}$$

A : Junction area

d : Gap width

Φ : Barrier height

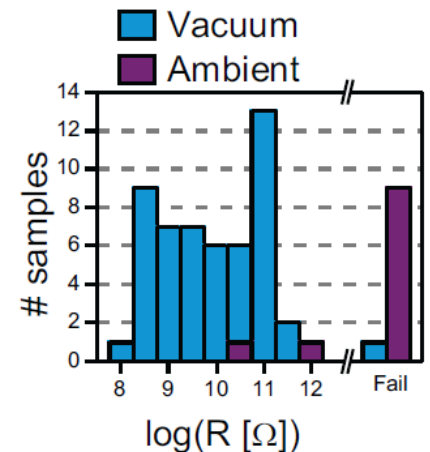
breakdown mechanism

burning ? ($p=10^{-5}\text{mbar}$)

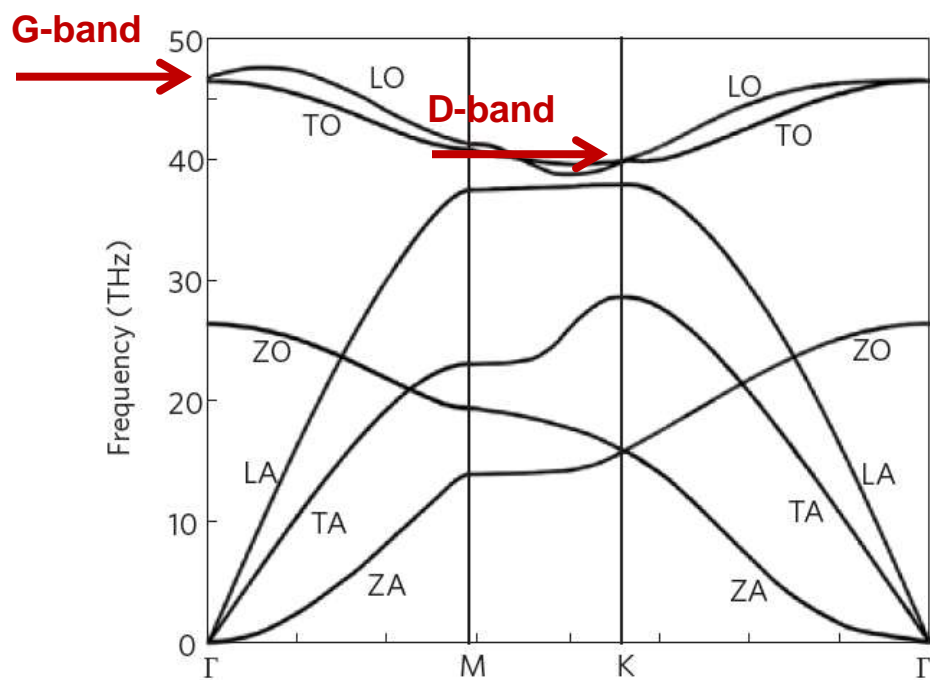
NB: carbon sublimation

A. Barreiro et al., NL 2012

F. Börrnert et al., NL 2012



phonons in graphene

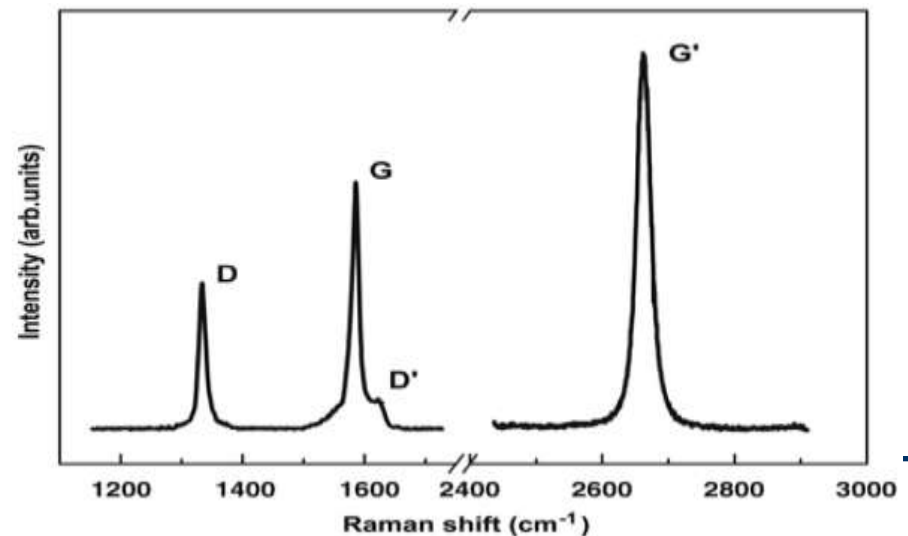


At room temperature:

$$\omega \sim \frac{k_B T}{\hbar} \sim 6 \text{ THz}$$

Phonon branches carrying heat:

- Longitudinal acoustic (LA)
- Transverse acoustic (TA)
- Out-of-plane acoustic (ZA)



temperature calibration

Raman peak shift as thermometer

- increasing T leads to softening of phonon modes

NB: 2D peak (Intervalley 2-phonon process) shift more marked, see e.g. Balandin et al., APL 2007

shifts for Si (520 cm^{-1}), D & 2D peaks

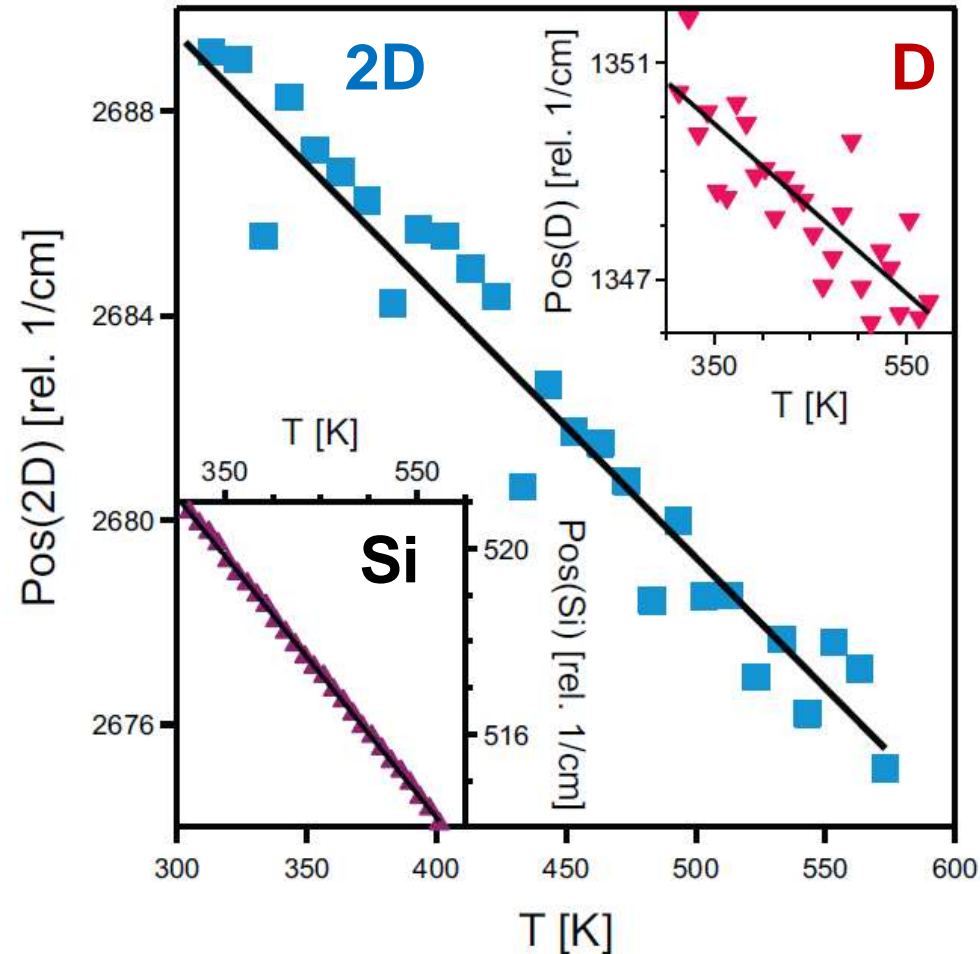
NB: G peak and FWHM peaks depend on carrier concentration n and $n=n(T)$

\Rightarrow 2D peak shift $-0.051 \text{ cm}^{-1}\text{K}^{-1}$

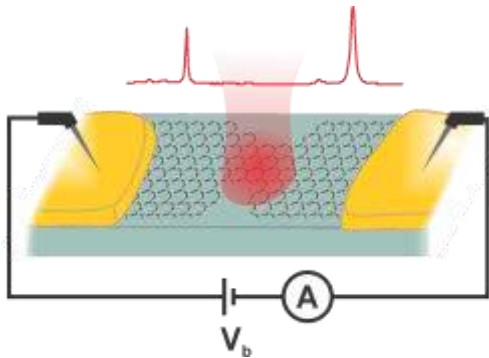
Si: inelastic phonon scattering model

$$\text{Pos}(Si) = \omega_0 + \gamma \left(1 + \frac{2}{e^x - 1} \right)$$
$$x = \hbar\omega_0/k_B T$$

\Rightarrow calibration of Raman peaks shift (heating stage)

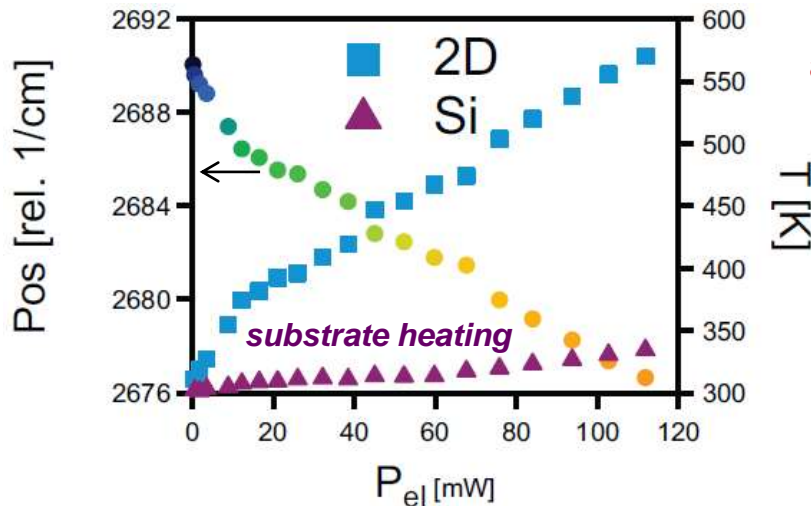


temperature during electroburning



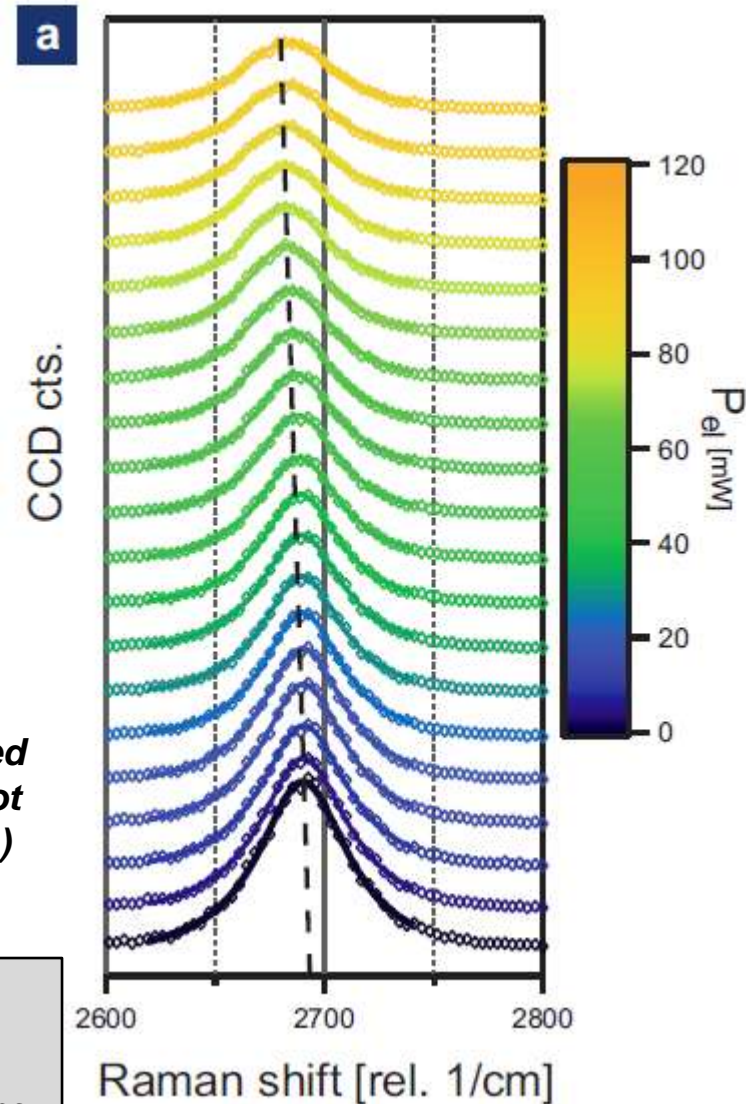
Raman spectroscopy at
constriction during EB
⇒ 2D peak shift

using T dep. observed $-0.051 \text{ cm}^{-1}\text{K}^{-1}$



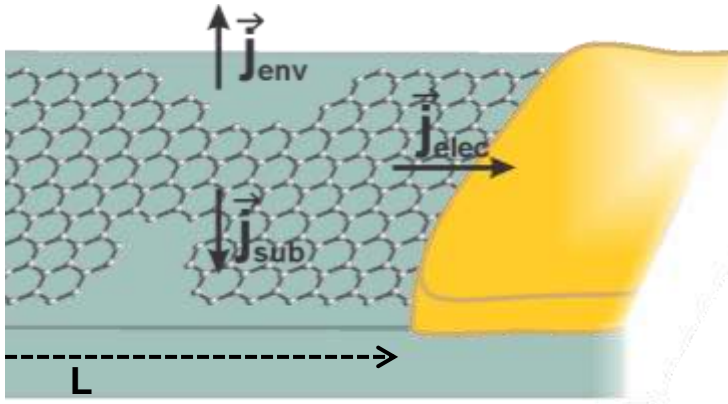
~600K
at breakdown

NB: T averaged
over laser spot
size ($\approx 400\text{nm}$)



470K	graphene oxidation	}	<i>Liu et al., Nano Lett. 2008</i>
720K	spontaneous etch pits		
1'000K	breakdown, supported	}	<i>Freitag et al., Nano Lett. 2009</i> <i>Dorgan et al., Nano Lett. 2013</i>
2'000K	breakdown, suspended		

temperature dependence of the resistance



heat dissipation

- **diffusive** at RT

mfp: $\lambda_{ph} \approx 100\text{nm}$, $\lambda_e \approx 20\text{nm}$; $L = 20\mu\text{m} \gg \lambda_e, \lambda_{ph}$
(supported graphene)

- $J_{sub} \gg J_{env}, J_{elec}$

vacuum, remote electrodes

Joule heating: e-ph scattering

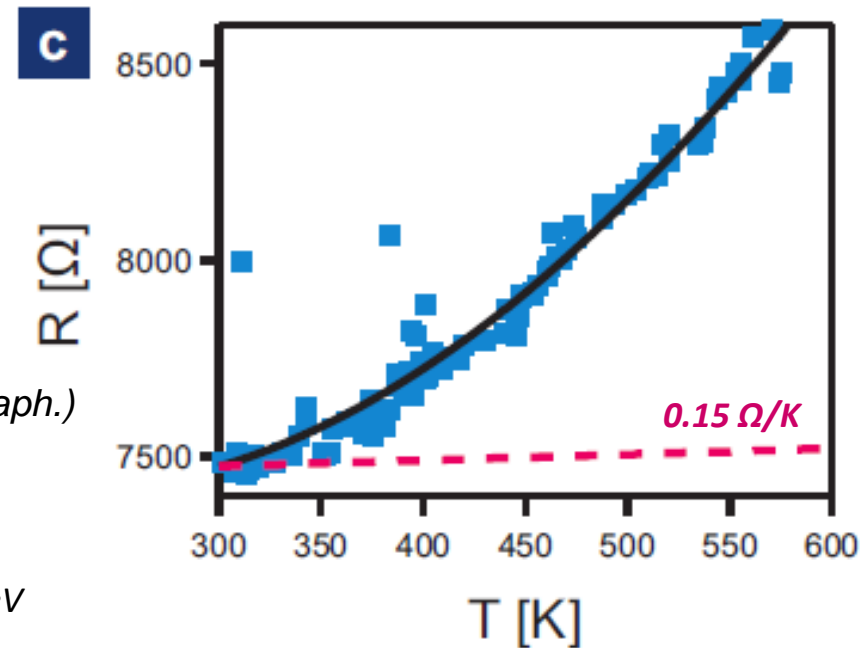
$$\rho(T) = \underbrace{\rho_0 + \alpha T}_{\rho_A} + \underbrace{\beta \left(\frac{1}{e^{E_0/k_B T} - 1} \right)}_{\rho_B}$$

acoustic ph

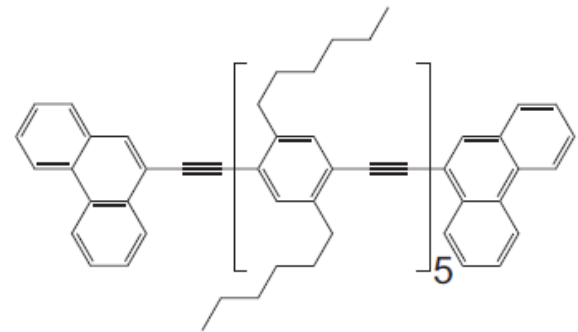
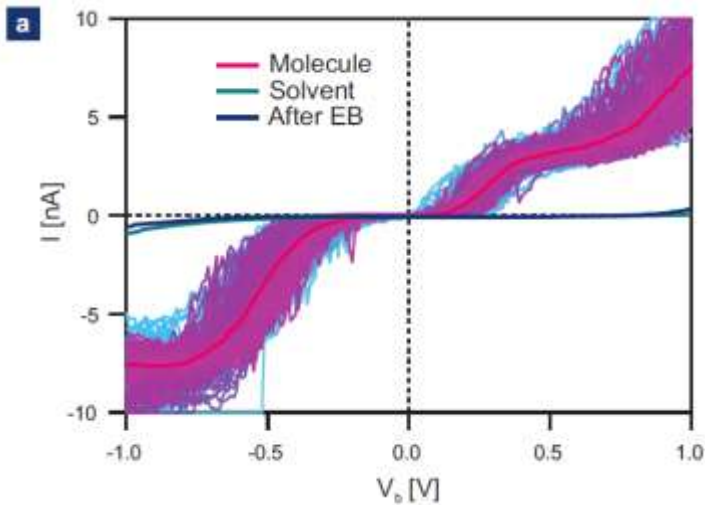
optical ph & remote interface ph (SiO₂-graph.)

$\rho_A \ll \rho_B$ $\alpha \sim 0.15 \text{ } \Omega/\text{K}$ (linear fit: $3.9 \text{ } \Omega/\text{K}$)

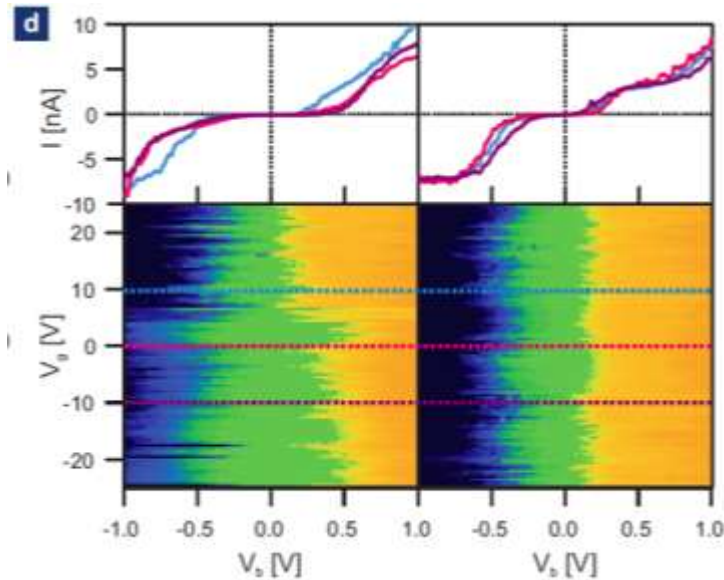
Fit $E_0 = 141 \text{ meV}$
SiO₂ surface phonons at 59 meV and 155 meV
Graphene optical phonons $\sim 149 \text{ meV}$



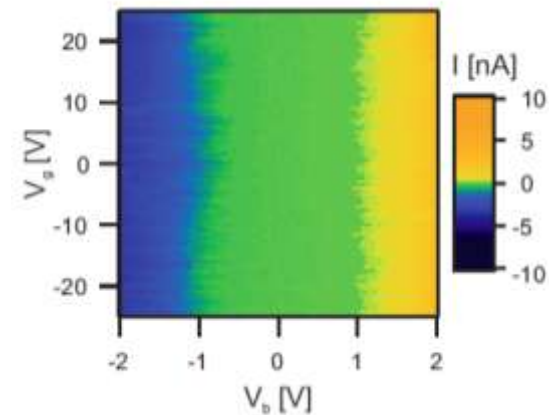
preliminary hints of molecular conductance



molecule: M. Mayor et al.



gating: solvent only



simple one-level model

Analytical expression for the current

$$I(E, V) = \frac{2e}{h} \int_{-\infty}^{\infty} T(E, V) [f(E - \mu_2) - f(E - \mu_1)] dE$$

At low T , Fermi functions \approx Heaviside step functions, and

$$I(V) = \frac{2e}{h} \int_{-\frac{eV}{2}}^{\frac{eV}{2}} T(E, V) dE$$

Using the expressions

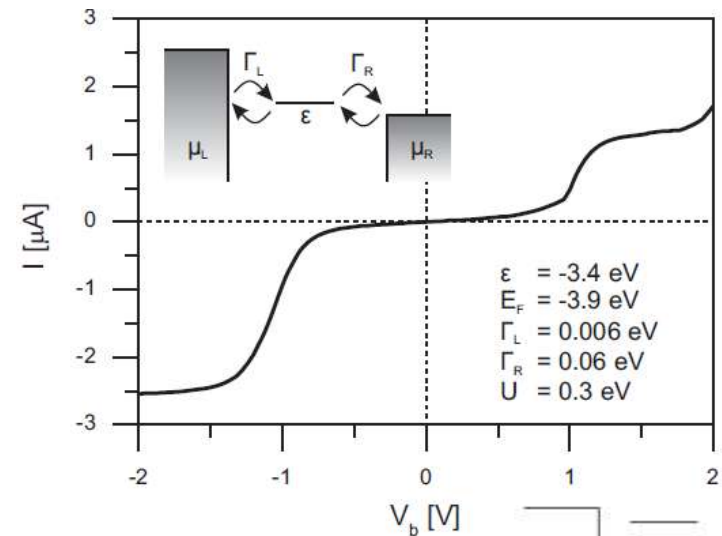
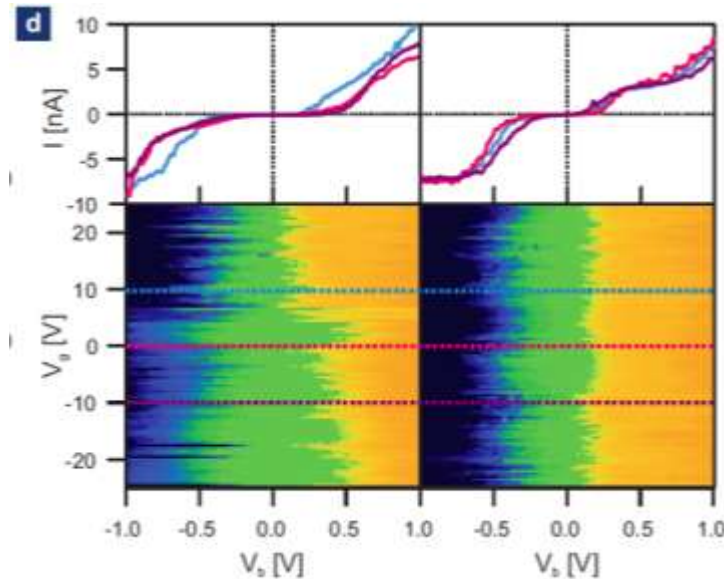
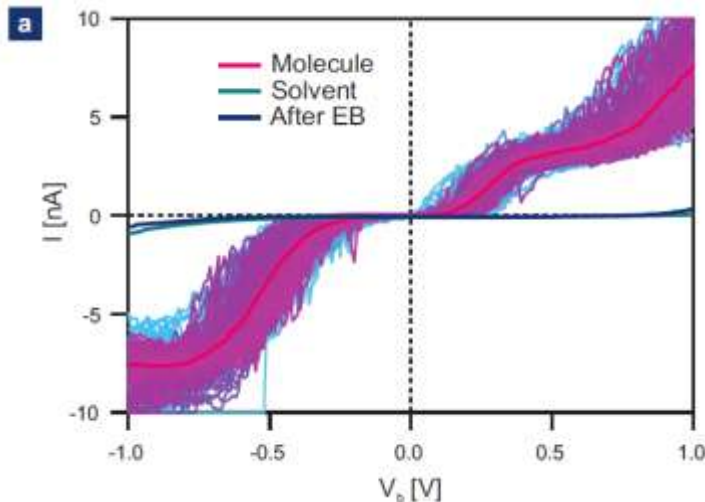
$$T(E, V) = \frac{4\Gamma_1\Gamma_2}{(E - E_0(V))^2 + (\Gamma_1 + \Gamma_2)^2}$$
$$E_F(V) = \frac{eV}{2} \cdot \frac{\Gamma_1 - \Gamma_2}{\Gamma_1 + \Gamma_2}$$

we can write

$$I(V) = \frac{8e}{h} \cdot \frac{\Gamma_L\Gamma_R}{\Gamma_L + \Gamma_R} \left[\arctan \left(\frac{2E_0 + eV \left(\frac{\Gamma_L - \Gamma_R}{\Gamma_L + \Gamma_R} + 1 \right)}{2(\Gamma_L + \Gamma_R)} \right) - \arctan \left(\frac{2E_0 + eV \left(\frac{\Gamma_L - \Gamma_R}{\Gamma_L + \Gamma_R} - 1 \right)}{2(\Gamma_L + \Gamma_R)} \right) \right]$$

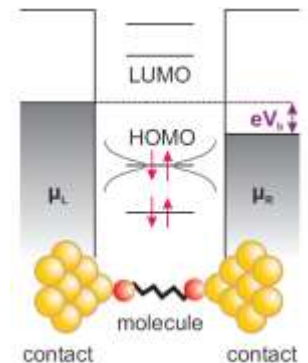
3 fit parameters $\Gamma_1, \Gamma_2, E_0 = E_0(V)$

preliminary hints of molecular conductance



qualitative behavior using simple 1 level model

including CB and level broadening
(Datta et al. Nanotech. 2004)



$$I = \frac{2e}{\hbar} \int_{-\infty}^{\infty} D(E) \frac{\Gamma_L \Gamma_R}{\Gamma_L + \Gamma_R} [f_L(E, \mu_L) - f_R(E, \mu_R)] dE$$

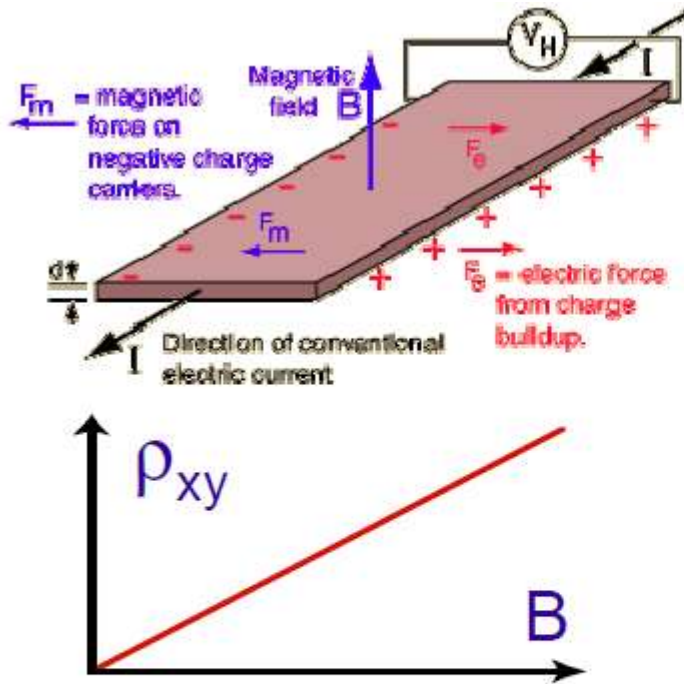
$$D(E) = \frac{1}{2\pi} \frac{\Gamma_L + \Gamma_R}{(E - \epsilon)^2 + ((\Gamma_L + \Gamma_R)/2)^2}$$

- graphene structure
- fabrication and CVD growth
- characterization: Raman spectroscopy

Examples

- graphene electroburning for molecular junctions
- Quantum Hall Effect

classical Hall effect



Force: $\vec{F} = \vec{F}_e + \vec{F}_m = q(\vec{E} + \vec{v} \times \vec{B})$

Electric Field ($F_y=0$): $E_y = v_x B_z$

Current density: $J_x = nq v_x$

q = charge of carrier

n = carrier density

Hall Conductivity

$$\rho_{xy} = \frac{E_y}{J_x} = \frac{B}{nq}$$

The Hall conductivity measures

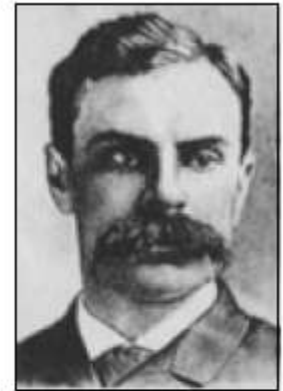
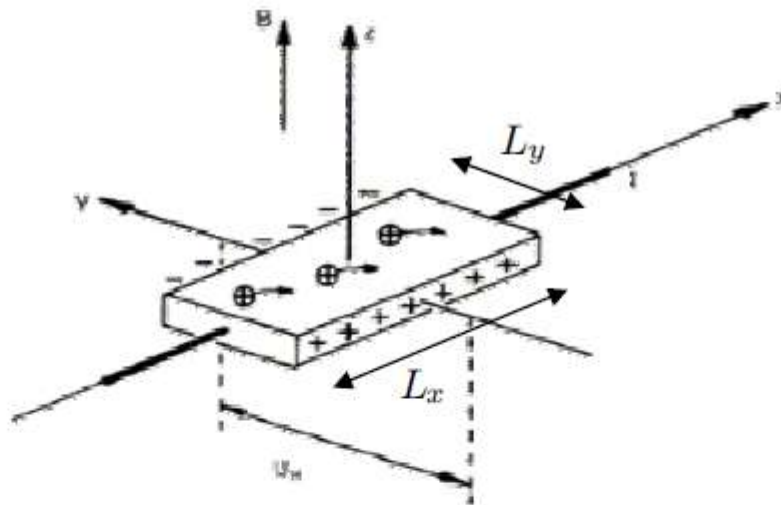
- The density of the mobile charge carriers
- The sign of the charge carriers ($e < 0$!)

Hall effect

klassisch

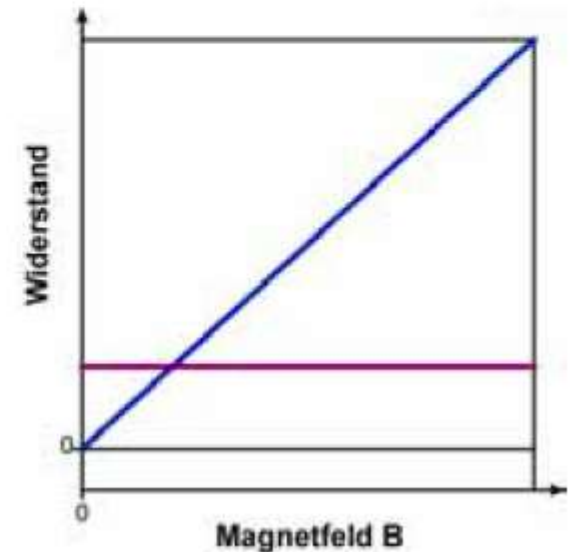
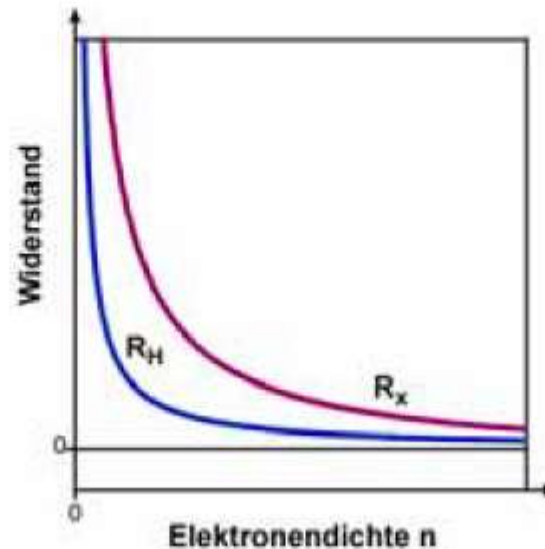
E. H. Hall:

„On the New Action of Magnetism on a
Permanent Electric Current“,
PhD-thesis,
The Johns Hopkins University, 1880



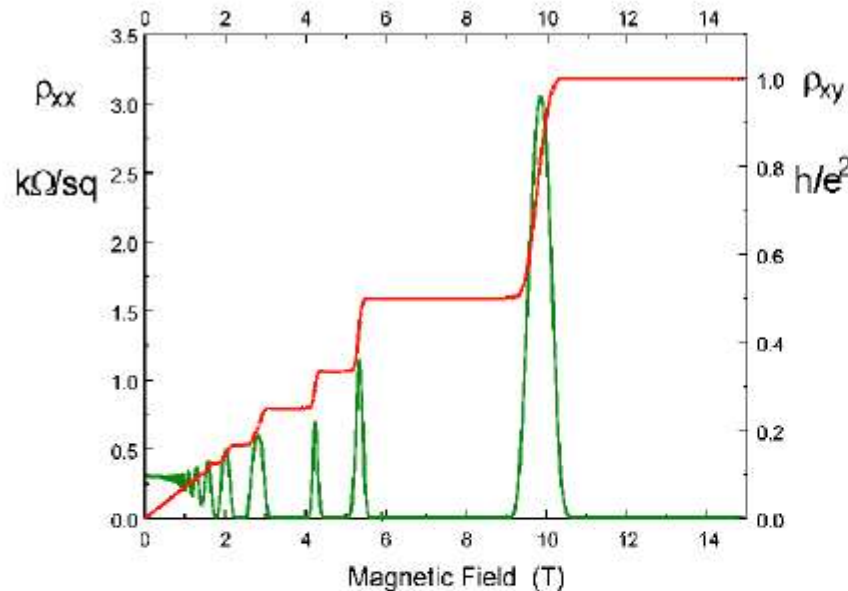
$$R_x = \frac{1}{en\mu} \frac{L_x}{L_y}$$

$$R_H = \frac{U_H}{I_x} = \frac{B}{en} \quad (1)$$



quantum Hall effect

Quantum Hall effect in 2D MOSFET



Von Klitzing, 1981 (Nobel 1985)



- Quantization: $\rho_{xy} = R_Q / n$ $n = \text{integer}$ accurate to 10^{-9} !
- Quantum Resistance: $R_Q = h / e^2 = 25.812\,807\, k\Omega$
- Explained by quantum mechanics of electrons in a magnetic field

quantum Hall effect

Quanten-H.E.

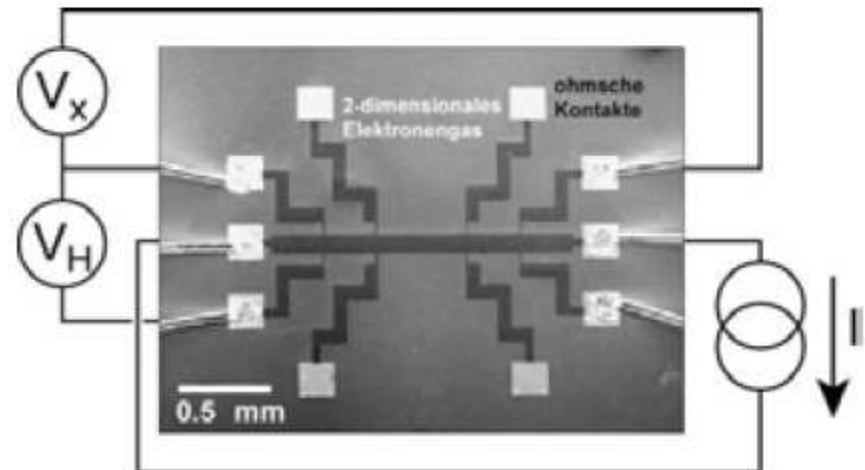
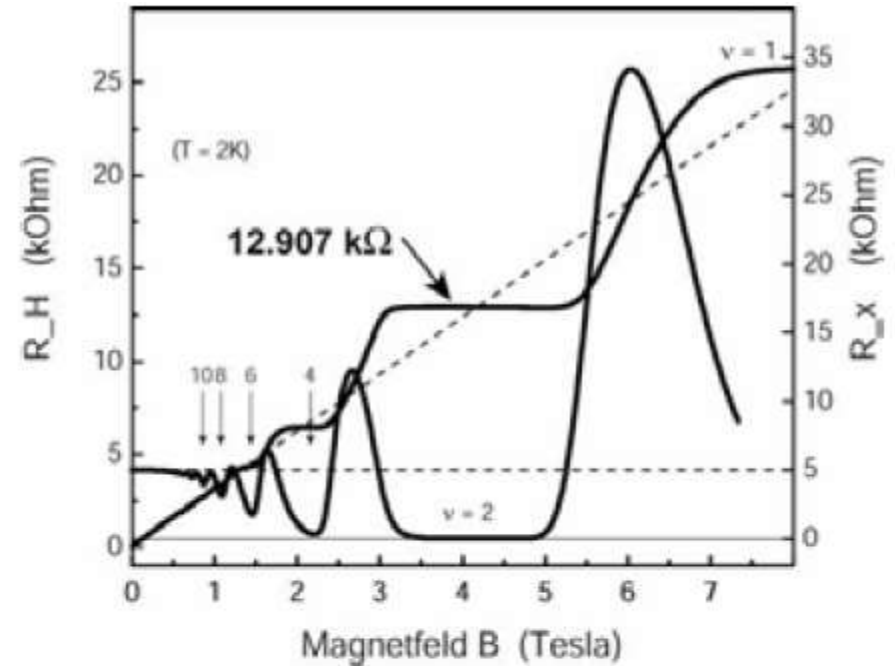
Phänomenologisch:

- Plateaus im Hall-Widerstand

$$R_H = \frac{1}{\nu} \frac{h}{e^2}, \quad \nu = 1, 2, 3 \dots$$

- Longitudinaler Widerstand wird Null:

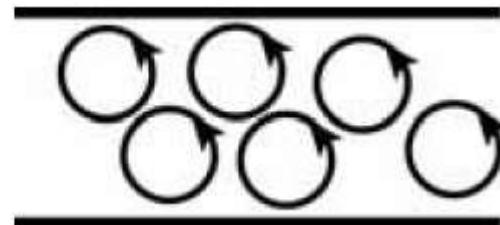
$$R_x = 0 \quad \text{für} \quad \nu = 1, 2, 3 \dots$$



quantum Hall effect

Klassisch:

Zyklotron-Bahnen mit Kreisfrequenz $\omega_C = \frac{eB}{m}$



Bohr-Sommerfeld-Quantisierung:

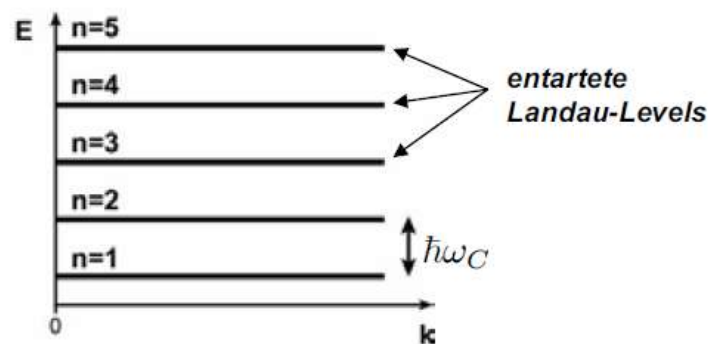
$$2\pi r_C = n\lambda_B = n \left(\frac{h}{mv} \right)$$

$$r_C^2 = \frac{\hbar}{m\omega_C}$$

$$\epsilon_n = \frac{mv^2}{2} = \frac{m\omega_C^2 r_C^2}{2} = n \frac{\hbar\omega_C}{2}$$

Landau-Niveaus (levels) (LL):
(magnetische Sub-bänder)

$$\epsilon_n = \hbar\omega_C(n+1/2) \quad n: \text{integer}$$



effect becomes relevant once $\omega_C\tau > 1$

i.e.: once electrons perform at least one complete circular motion without collision

critical field

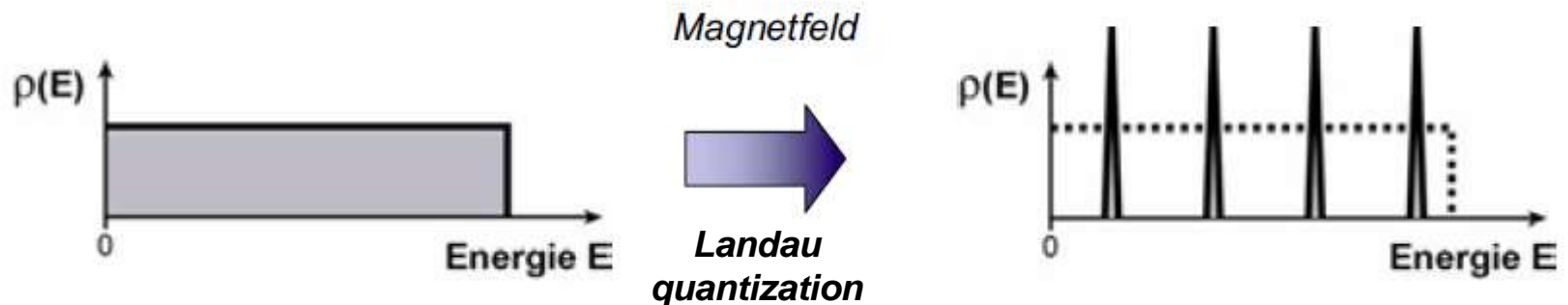
$$B_c \simeq m_b / e\tau = \mu^{-1}$$

for $B > B_c$, ρ_{xx} starts to oscillate; high mobility \Leftrightarrow low B_c
Shubnikov-de Haas

quantum Hall effect

Landau-Quantisierung

Die 2-dimensionale Zustandsdichte geht von einer Stufenform im Nullfeld in eine Sequenz von Peaks über bei genügend starkem Magnetfeld:



Boltzmann transport eq. \Rightarrow

Einstein relation
conductivity as diffusion eq.

$$\sigma_L = e^2 D \rho(E_F)$$

density of states (DOS) at E_F

$$\rho(E_F)$$

Landau quantisation

DOS: sequence of
delta peaks

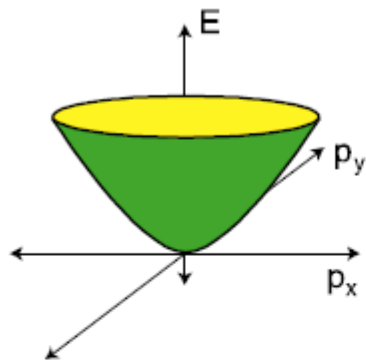
$$\rho(\epsilon) = \sum_n g_n \delta(\epsilon - \epsilon_n)$$

g_n : degeneracy of level n

$$\epsilon_n = \hbar \omega_C (n + 1/2)$$

quantum Hall effect

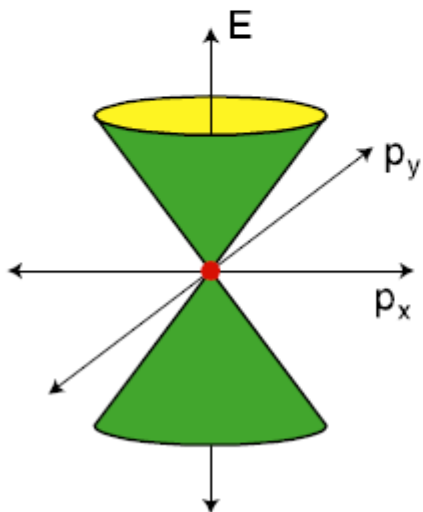
Landau levels for classical particles



$$E_n = \left(n + \frac{1}{2}\right) \frac{\hbar e B}{m}$$

for $n=0, 1, 2, \dots$

Landau levels for relativistic particles



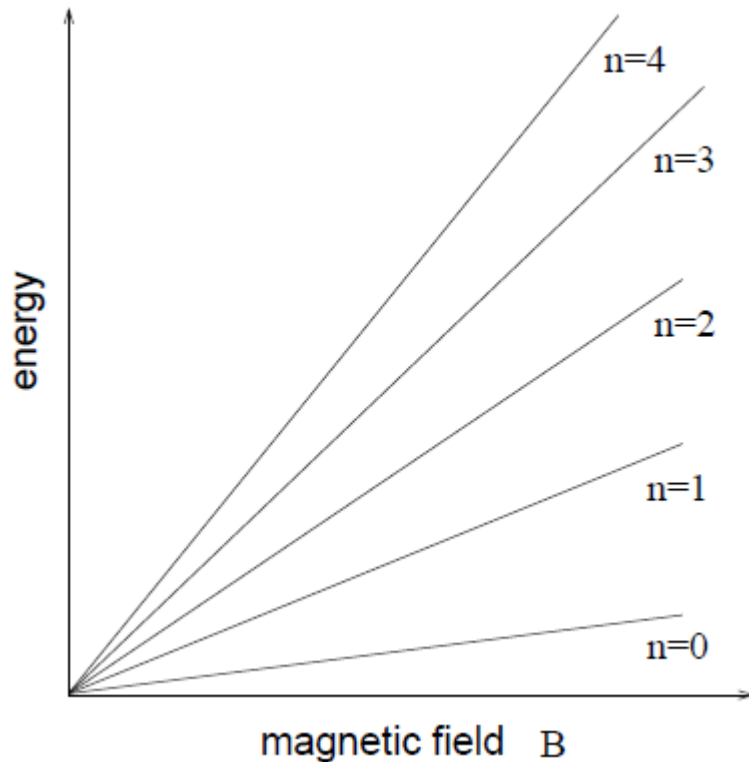
$$E_n = \pm \sqrt{e \hbar v_F^2 B n}$$

for $n=0, 1, 2, \dots$

Existence of Landau level at 0 is deeply related to spin in Dirac Eq.

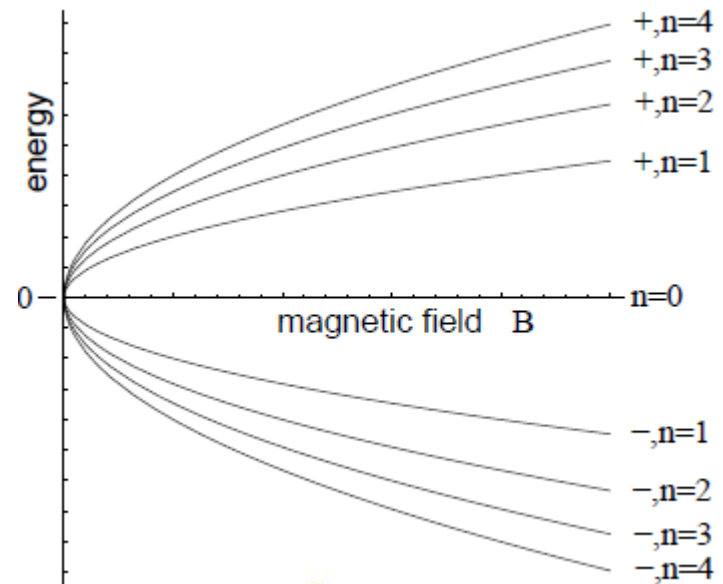
quantum Hall effect

non-relativistic case



$$\epsilon_n = \hbar\omega_C(n + 1/2) \propto B(n + 1/2)$$

relativistic case



$$\epsilon_{\lambda,n} = \lambda \frac{\hbar v_F}{l_B} \sqrt{2n}$$

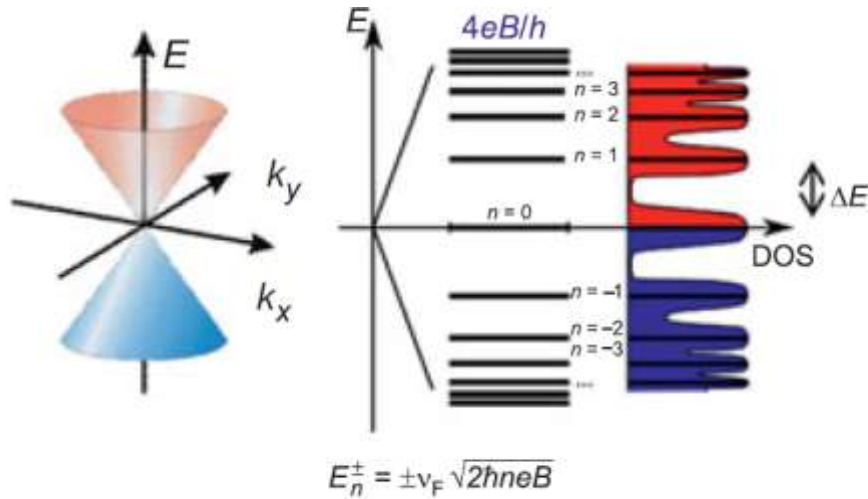
$$\hbar v_F / l_B \simeq 36 \text{ meV} \sqrt{B[\text{T}]}$$

magnetic length

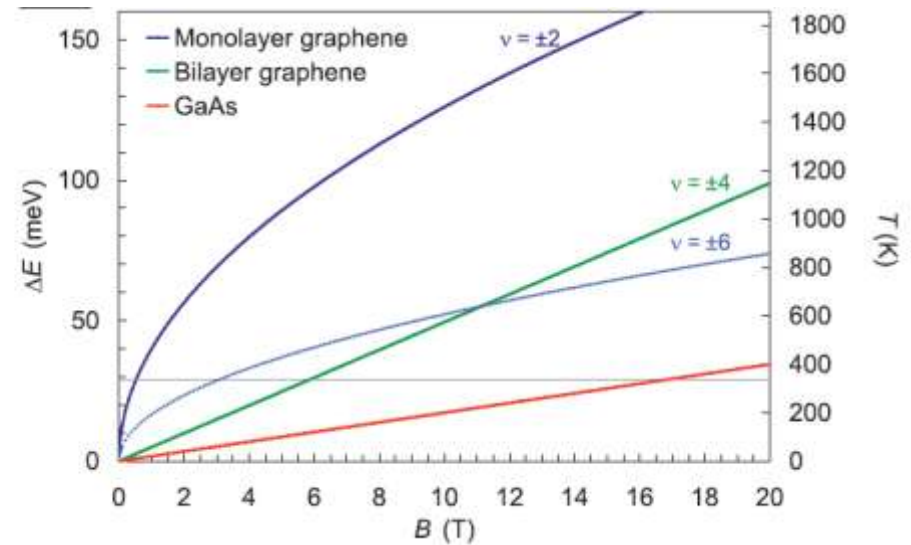
$$l_B = \sqrt{\hbar / eB} \simeq 26 \text{ nm} / \sqrt{B[\text{T}]}$$

λ : band index, + (CB) or – (VB)

quantum Hall effect in graphene



Sequence of Landau levels (LLs), indexed by the integer n , with energies E_n^\pm and energy gaps ΔE , formed at high magnetic field

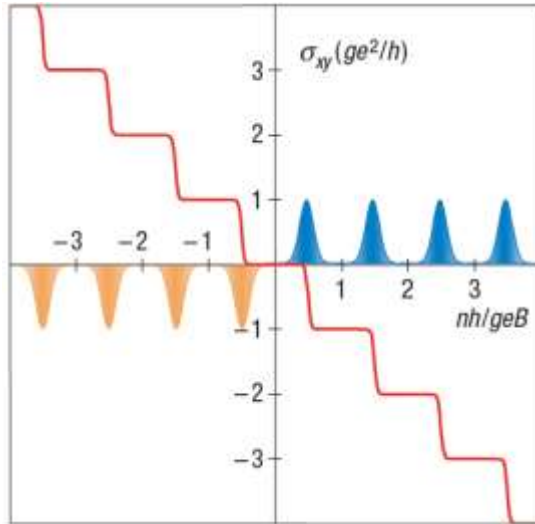


Magnetic-field dependence of the energy gaps (ΔE , left scale) and equivalent temperatures (T , right scale)

NB: The value of the energy gap in monolayer graphene at $\nu = 2$ is much larger than that in GaAs at low magnetic field.

QHE graphene

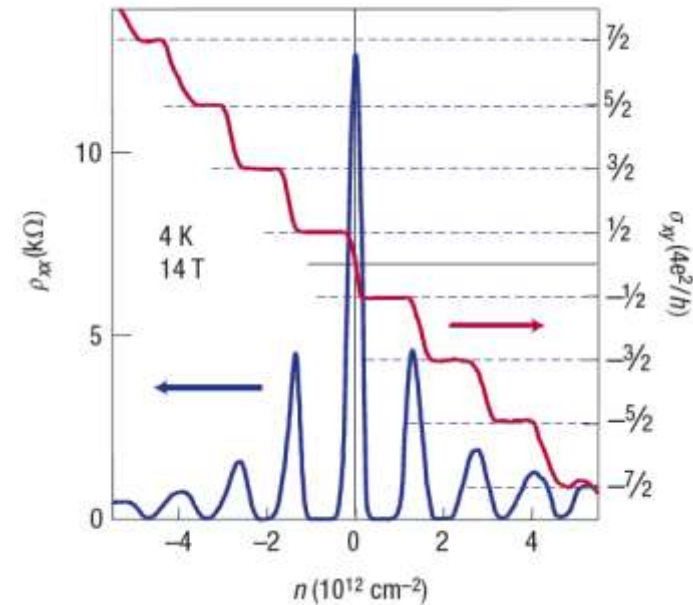
2D semiconductor



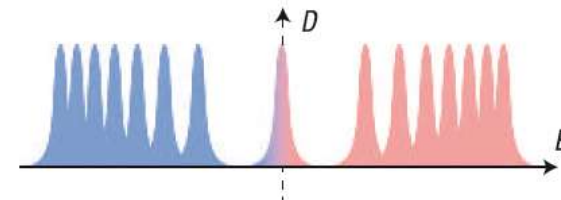
Schematic illustration of the conventional integer QHE found in 2D semiconductor systems

Landau levels as a function of carrier concentrations n are shown in blue and orange for electrons and holes, respectively

Graphene



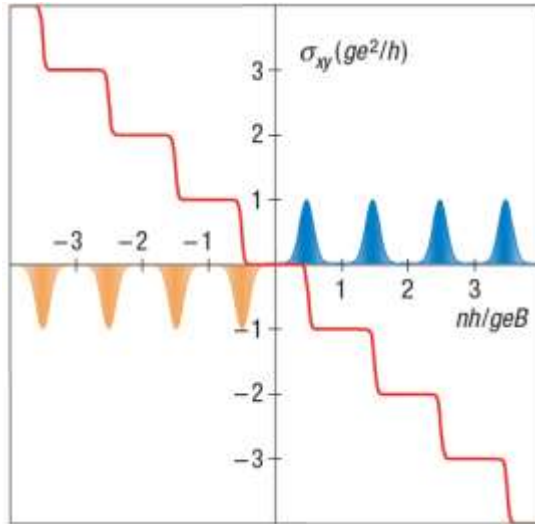
Hallmark of massless Dirac fermions:
QHE plateaux in σ_{xy} at half integers of $4e^2/h$



Landau quantization in graphene. The sequence of Landau levels in the density of states D is described by $E_N \propto \sqrt{N}$ for massless Dirac fermions in single-layer graphene

QHE graphene

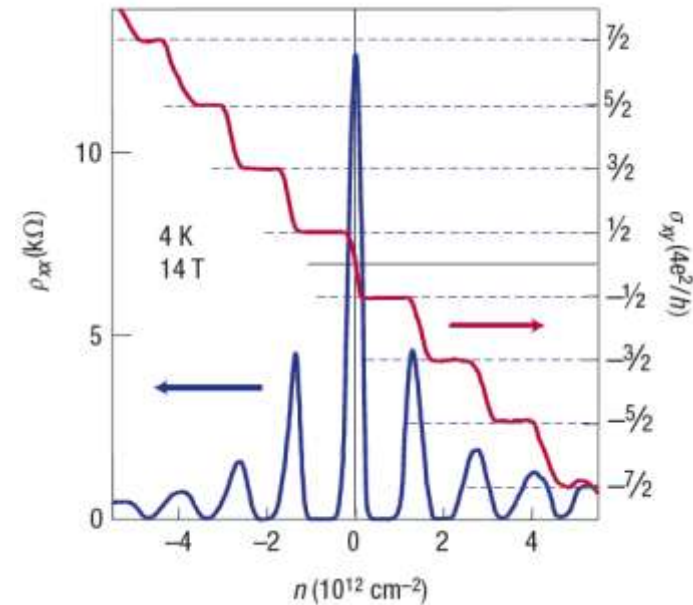
2D semiconductor



Schematic illustration of the conventional integer QHE found in 2D semiconductor systems

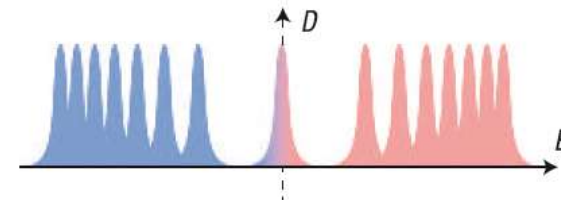
Landau levels as a function of carrier concentrations n are shown in blue and orange for electrons and holes, respectively

Graphene



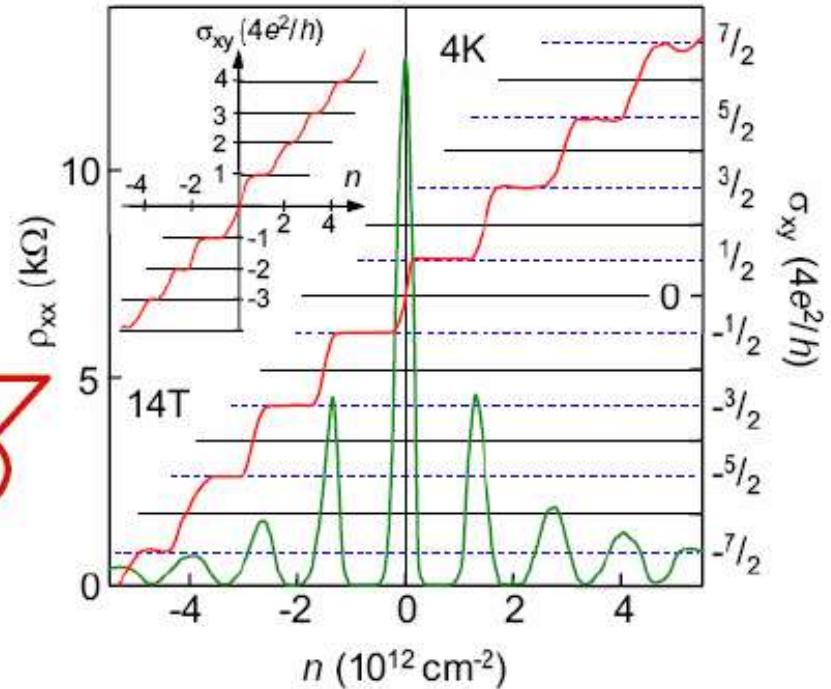
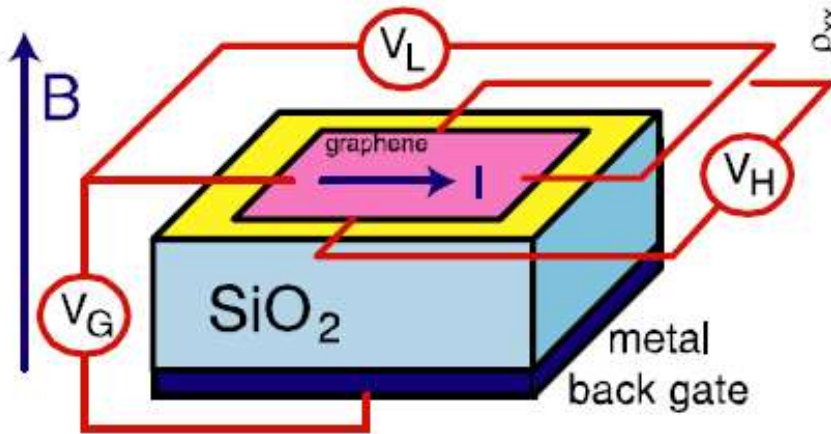
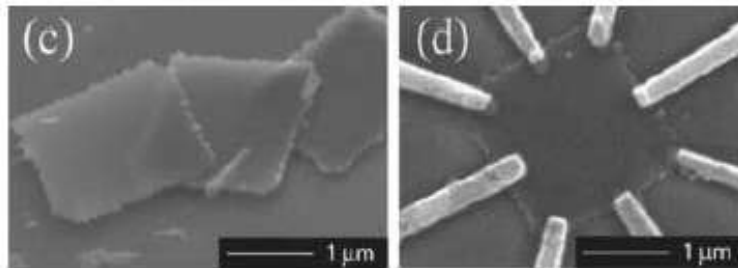
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Landau quantization in graphene. The sequence of Landau levels in the density of states D is described by $E_N \propto \sqrt{N}$ for massless Dirac fermions in single-layer graphene

QHE graphene



- Gate voltage controls charge n on graphene (parallel plate capacitor)

$\frac{1}{2}$ integer quantum hall effect showing massless nature of charge carriers in graphene ($c \Leftrightarrow v_F$)

Geim, Novoselov and Kim, Zhang (2005)

ambipolar behavior
(FET geometry)

Novoselov et al.

